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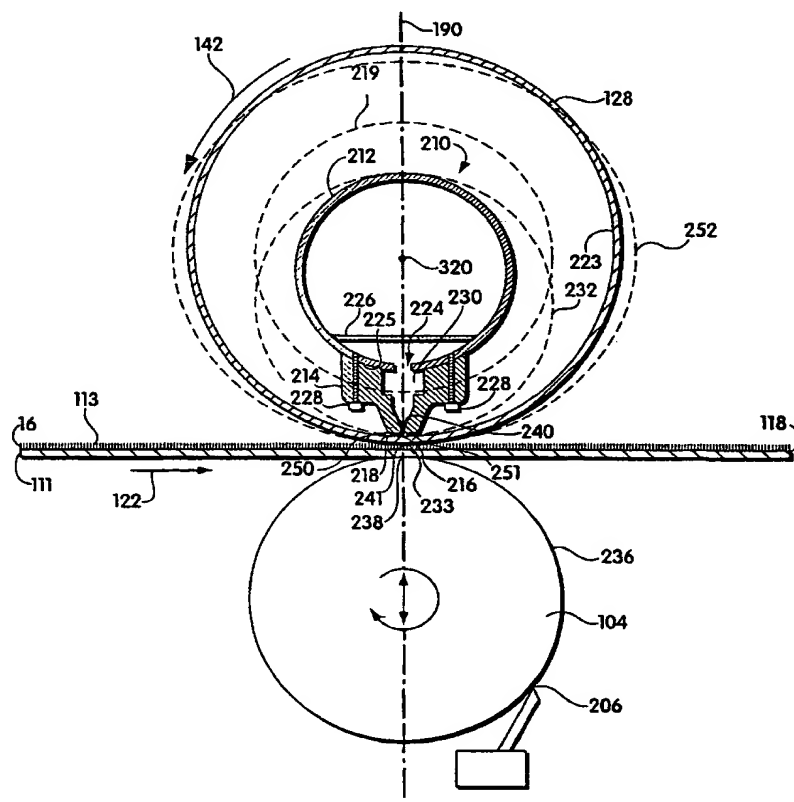
(74) Agent: **POMIANEK, Michael, J.**; Wolf, Greenfield & Sacks, P.C., 600 Atlantic Avenue, Boston, MA 02210 (US).

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[Continued on next page]

(54) Title: **SYSTEMS AND METHODS FOR STABILIZING THE ROTATING STENCILS USED FOR AIR EMBOSsing FABRICS**



(57) Abstract: Improved air embossing systems, improved air lances, and improved methods of air embossing fabrics, which are able to produce an unprecedented level of fine detail, crisp transition between unembossed and embossed regions, lack of undesired embossing artifacts, and a high degree of uniformity across the width of an embossed fabric, when compared to the performance of typical, conventional air embossing systems are disclosed. The disclosed air embossing systems utilize generally cylindrical, rotating stencils (128) with air lances (210) positioned therein for directing a stream of air through apertures in the stencil (128) and onto the embossable surface (113) of a fabric. The systems also include at least one stencil stabilizer (250, 251) that is constructed and positioned within the system to apply a force to the stencil (128) during operation that is sufficient to reduce, and preferably essentially eliminate, variations in the distance separating the surface (113) of the fabric being embossed by the system and the portion of the fabric-facing surface of the stencil (128) directly adjacent thereto during rotation of the stencil (128).



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INTERNATIONAL SEARCH REPORT

Applicant's Name
PCT/US 01/24266

A. CLASSIFICATION OF SUBJECT MATTER
IPC 7 D06C23/04

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)
IPC 7 D06C D06B

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, PAJ, WPI Data

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	US 3 916 823 A (J.B. HALLORAN) 4 November 1975 (1975-11-04) cited in the application column 4, line 10 -column 5, line 33 ---	1,25,30, 37-39, 42,45
A	US 5 122 219 A (V. LUDWIG) 16 June 1992 (1992-06-16) column 3, line 11 - line 37 ---	3,4,7
A	DE 34 19 367 A (M. MITTER) 29 November 1984 (1984-11-29) page 9, line 30 -page 10, line 32 page 13, line 16 - line 21 page 15, line 13 -page 16, line 5 -----	3,4,7

☐ Further documents are listed in the continuation of box C.

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Date of the actual completion of the international search

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INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No

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Patent document cited in search report		Publication date		Patent family member(s)	Publication date
US 3916823	A	04-11-1975	AR	201120 A1	14-02-1975
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PATENT COOPERATION TREATY

PCT

NOTICE INFORMING THE APPLICANT OF THE
COMMUNICATION OF THE INTERNATIONAL
APPLICATION TO THE DESIGNATED OFFICES

(PCT Rule 47.1(c), first sentence)

From the INTERNATIONAL BUREAU

1FD

To:

POMIANEK, Michael, J.
Wolf, Greenfield & Sacks, P.C.
600 Atlantic Avenue
Boston, MA 02210
ETATS-UNIS D'AMERIQUE

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Date of mailing (day/month/year) 14 February 2002 (14.02.02)		DOCKETED	
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Applicant MICROFIBRES, INC. et al			

IMPORTANT NOTICE

1. Notice is hereby given that the International Bureau has communicated, as provided in Article 20, the international application to the following designated Offices on the date indicated above as the date of mailing of this notice:
KP, KR, US

In accordance with Rule 47.1(c), third sentence, those Offices will accept the present notice as conclusive evidence that the communication of the international application has duly taken place on the date of mailing indicated above and no copy of the international application is required to be furnished by the applicant to the designated Office(s).

2. The following designated Offices have waived the requirement for such a communication at this time:
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The communication will be made to those Offices only upon their request. Furthermore, those Offices do not require the applicant to furnish a copy of the international application (Rule 49.1(a-bis)).

3. Enclosed with this notice is a copy of the international application as published by the International Bureau on 14 February 2002 (14.02.02) under No. WO 02/12608

REMINDER REGARDING CHAPTER II (Article 31(2)(a) and Rule 54.2)

If the applicant wishes to postpone entry into the national phase until 30 months (or later in some Offices) from the priority date, a demand for international preliminary examination must be filed with the competent International Preliminary Examining Authority before the expiration of 19 months from the priority date.

It is the applicant's sole responsibility to monitor the 19-month time limit.

Note that only an applicant who is a national or resident of a PCT Contracting State which is bound by Chapter II has the right to file a demand for international preliminary examination (at present, all PCT Contracting States are bound by Chapter II).

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If the applicant wishes to proceed with the international application in the national phase, he must, within 20 months or 30 months, or later in some Offices, perform the acts referred to therein before each designated or elected Office.

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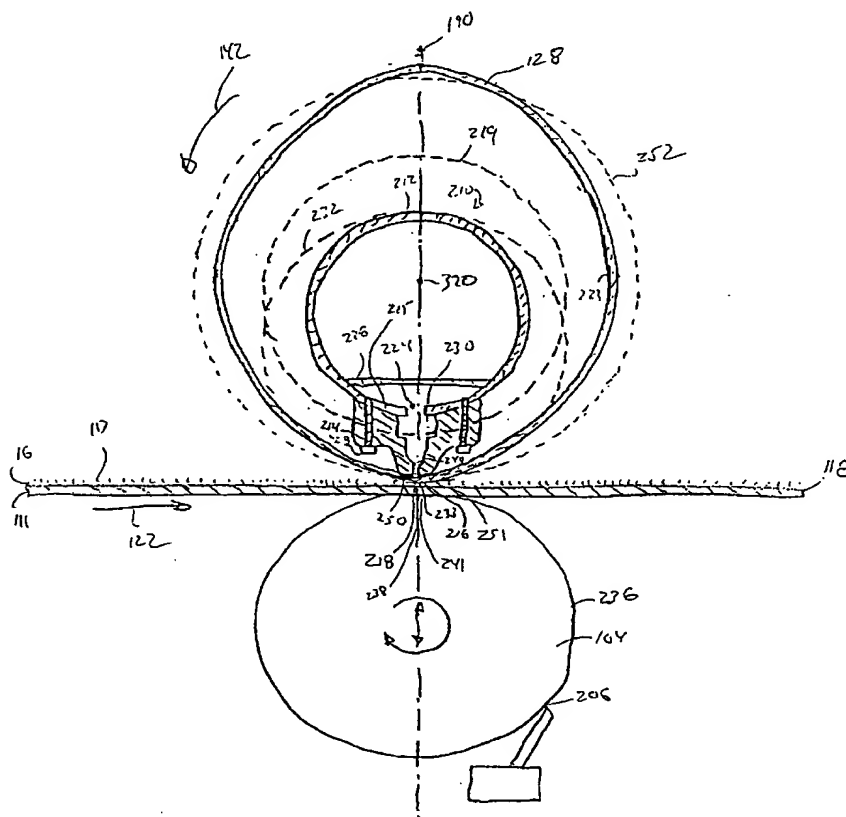
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(72) Inventors; and

(75) Inventors/Applicants (for US only): **LAIRD, William**

[Continued on next page]

(54) Title: SYSTEMS AND METHODS FOR STABILIZING THE ROTATION OF EMBOSsing STENCILS USED FOR AIR EMBOSsing FABRICS



(57) Abstract: Improved air embossing systems, improved air lances, and improved methods of air embossing fabrics, which are able to produce an unprecedented level of fine detail, crisp transition between unembossed and embossed regions, lack of undesired embossing artifacts, and a high degree of uniformity across the width of an embossed fabric, when compared to the performance of typical, conventional air embossing systems are disclosed. The disclosed air embossing systems utilize generally cylindrical, rotating stencils with air lances positioned therein for directing a stream of air through apertures in the stencil and onto the embossable surface of a fabric. The systems also include at least one stencil stabilizer that is constructed and positioned within the system to apply a force to the stencil during operation that is sufficient to reduce, and preferably essentially eliminate, variations in the distance separating the surface of a fabric being embossed by the system and the portion of the fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil.



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**SYSTEMS AND METHODS FOR STABILIZING THE ROTATION OF
EMBOSSING STENCILS USED FOR AIR EMBOSSING FABRICS**

FIELD

5 The present application relates to systems and methods for embossing a surface of an embossable fabric with a stream of air or other gas, and embossed flocked fabrics made thereby, and more specifically to systems and methods for stabilizing the rotation of a cylindrical embossing stencil utilized for embossing a surface of an embossable fabric with a stream of air or other gas.

BACKGROUND

10 In manufacturing flocked fabric it is conventional to deposit a layer of flock on an adhesive coated substrate and to emboss the surface of the flocked fabric during this process with selected designs. Conventionally, the embossing process may be achieved
15 by one of several processes using specialized equipment for such purposes. Among these embossing processes is air embossing. In the air embossing process a substrate is coated with an adhesive. While the adhesive is still wet it is covered with a layer of flock fibers forming the flocked layer. The adhesive coated substrate with the flocked fibers is then carried beneath a stencil while the adhesive is not yet set. The stencil under
20 which the assembly moves typically comprises an elongated cylinder having perforations arranged in a desired pattern to be formed in the flocked surface. This embossing stencil typically is rotated at the same speed as the flocked layer moves beneath it. Air introduced within this cylindrical stencil is directed downwardly through the perforations forming the pattern onto the upper surface of the flocked layer. By choosing a particular
25 arrangement of perforations in the screen, and by the selective application of air flow through the perforations, air jets are directed downwardly from the stencil and onto the surface of the flocked fabric. Since the flocked fabric has not yet set in the adhesive, the stream of air changes the angle of or substantially flattens the flock fibers forming the flock in selected areas, thus forming a pattern as the stencil rotates and the flocked fabric
30 moves.

 A variety of prior art systems are available for performing air embossing of flocked fabrics. Many such systems are generally satisfactory for embossing designs

onto an embossable surface of the fabric that do not require a significant level of fine detail. However, typical prior art systems suffer from a variety of shortcoming which limit their utility for producing finely detailed patterns, and which result in embossed pile fabrics that include embossed regions having undesirable artifacts and visually unappealing surface features. For example, air embossed pile fabrics produced with conventional air embossing equipment are typically not able to produce embossed features having a characteristic size that is very small, thus such equipment is not able to give the embossed fabric an appearance with a fine, detailed surface structure. In addition, typical prior art air embossing systems are not able to direct air towards the embossable surface of the fabric at a controlled, desirable angle (e.g. essentially perpendicular to the fabric surface), and, thus, they tend to produce embossed features having a blurred or imprecise transition region between the embossed features and the unembossed regions of the surface, which results in an associated lack of crispness and definition to the overall appearance of the embossed fabric.

In addition, typical prior art air embossing systems also tend to produce embossed fabrics having embossed features distributed across the width of the fabric that are not uniform in appearance across the width of the fabric. Also, typical prior art air embossing systems have a tendency to direct air towards the surface of the fabric in a direction diagonal to the fabric surface resulting in an embossed surface wherein the pile fibers have an overall directional lay with respect to the substrate, thus creating a distorted, unattractive appearance in the embossed surface, which appearance does not accurately reflect the pattern provided in the stencil used for embossing.

Also, typical prior art air embossing systems utilize embossing stencils which often, because of manufacturing defects/tolerances and/or damage during use, do not rotate "true" (i.e. the distance between the outer surface of the stencil and the rotational axis of the cylinder is not constant around the circumference of the stencil), but rather include a substantial degree of "run out". "Run out" during rotation of many typical prior art air embossing stencils is caused by a deviation from a circular cross-sectional shape of the embossing stencil (taken in a plane perpendicular to its longitudinal axis) and/or a displacement of the rotational axis of the stencil with respect to the longitudinal centerline of the stencil. Such "run out" in prior art air embossing stencils during

rotation causes a deviation in the minimum separation distance between the embossable surface of a fabric being embossed and the portion of the outer surface of the stencil adjacent to the embossable surface through which the air is directed during embossing. Such deviation tends to create undesired variation in the level of definition of the embossed pattern on the fabric surface, and can also cause undesirable artifacts in the embossed pattern due to contact of the embossable surface of the fabric with the outer surface of the cylinder during rotation, thus causing a crushing of the pile fibers of the fabric in such locations. The "run out" in many prior art air embossing stencils also limits the separation distance between the outer surface of the embossing cylinder and the embossable surface of the fabric that is achievable while avoiding artifacts due to contact of the fabric by the outer surface of the embossing stencil during operation.

Some aspects and embodiments of the present disclosure are directed to improved air embossing systems and methods and improved embossed fabrics produced using the systems and methods. The present disclosure describes a variety of air embossing systems utilizing improved air lances for directing air onto and through a patterned stencil of the system and/or including stencil stabilizers to reduce the "run out" in stencils and increase the uniformity of the distance separating the portion of the outer embossing surface of the stencil adjacent to the fabric from the embossable surface of the fabric during rotation. The improved air lances and embossing systems described herein are able, in many embodiments, to solve many of the above-mentioned short comings of prior art air embossing systems and to produce embossed fabrics having an unprecedented level of fine detail, crisp transition between unembossed and embossed regions, lack of undesired artifacts due to non-uniformity in the distance separating the portion of the stencil adjacent the fabric from the fabric during rotation, and uniformity of the pattern across the width of the embossed fabric.

SUMMARY

The present invention involves, in some embodiments, improved air embossing systems, improved air lances, and improved methods of air embossing fabrics, which are able to produce an unprecedented level of fine detail, crisp transition between unembossed and embossed regions, a high degree of uniformity across the width of an

embossed fabric, and a lack of undesired artifacts due to non-uniformity in the distance separating the portion of the stencil adjacent the fabric from the fabric during rotation, when compared to the performance of typical, conventional air embossing systems, air lances, and embossing methods. The air embossing systems disclosed herein, in some
5 embodiments, utilize air lances for directing a stream of air onto the embossable surface of a fabric that have at least one nozzle having a characteristic orifice dimension substantially less than that of conventional air lance nozzles. The disclosed air embossing systems can also include air lances having nozzles positioned in close proximity to the embossable surface of a fabric being embossed, substantially closer than
10 is typical for air lances employed in conventional air embossing systems and in some preferred embodiments, the nozzles can be positioned in direct contact with an inner surface of the air embossing stencil. Air lances, as disclosed herein, can also include one or more nozzles having a characteristic orifice dimension that is substantially less than a characteristic length of the nozzles. Certain air lances disclosed herein can also include
15 one or more nozzles in the shape of an elongated slit oriented, with respect to the air lance, so as to be positioned across essentially the entire width of a fabric being embossed with the air lance. The disclosure also describes air lances for use in embossing fabrics that can include a nozzle-forming component that is separable from the main body of the air lance and that enables the nozzle(s) of the air lance to be
20 positioned within close proximity to the fabric, when the air lance is in operation, and that also can act to redirect air flowing within the air lance such that it is emitted from the nozzle(s) so that a substantial fraction of the air stream is directed essentially perpendicular to the surface of the fabric being embossed. Yet other air lances disclosed include therein one or more baffles or air redirecting elements, which serve to deflect air
25 flowing within the air lance so that it passes through the nozzle(s) and is directed onto the embossable surface of the fabric at an angle that is substantially greater, with respect to the longitudinal axis of the air lance, than the angle of an air stream emitted from a nozzle of an essentially equivalent air lance, except excluding the air redirecting element or baffle. Some of the air lances described can include a combination of several or all of
30 the above described features.

The systems as disclosed herein can also include, in some embodiments, stencil

stabilizing components which are configured to apply a force to a rotating embossing stencil to increase the uniformity in the separation distance between the embossable surface of the fabric and the portion of the outer surface of the stencil directly adjacent to the surface of the fabric being embossed during rotation of the stencil.

5 In one aspect, a system for air embossing a surface of an embossable fabric is disclosed. In one embodiment, the system comprises a cylindrical stencil having an inside surface and a fabric-facing surface. The system further comprises at least one stencil stabilizer that is constructed and positioned to apply force to the stencil during operation of the system. The force applied to the stencil is sufficient to reduce variations
10 in a distance separating the embossable surface of the fabric and a portion of the fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil.

 In another embodiment, a system for air embossing a surface of an embossable fabric is disclosed. The system comprises a cylindrical stencil having an inner surface and a fabric-facing surface. The system further comprises an air lance including at least
15 one nozzle thereon. The nozzle is constructed and positioned to direct a stream of air through at least one opening in the stencil and onto the embossable surface of the fabric. The nozzle is positioned within the system so that at least a portion thereof is in contact with the inner surface of the stencil when the system is in operation.

 In another aspect, an air lance for directing air through a rotating stencil and onto
20 a surface of an embossable fabric for air embossing the fabric is disclosed. The air lance comprises a conduit having at least one opening therein, and at least one orifice forming at least one nozzle. The nozzle is constructed and positioned to direct a stream of air through the stencil and onto the embossable surface of the fabric, when the air lance is in operation. The air lance further includes at least one stencil stabilizer connected to and
25 extending from the conduit. The stabilizer is constructed and positioned to contact an inner surface of the stencil during operation of the system such that a force is applied to the inner surface that is sufficient to reduce variations in a distance separating the embossable surface of the fabric and a portion of the fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil. The stabilizer is further
30 constructed and positioned so that at least a portion of the stencil stabilizer extends, when the stabilizer is not in contact with the inner surface of the stencil, to a location separated

from the longitudinal central axis of the conduit by a first distance, where the first distance exceeds a second distance that separates the nozzle from the longitudinal central axis of the conduit.

5 In yet another aspect, in a system for air embossing an embossable fabric by directing a stream of air through at least one opening in a rotating cylindrical stencil and onto an embossable surface of the fabric, means are disclosed for reducing variations in a distance separating the embossable surface of the fabric and a portion of a fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil.

10 In yet another aspect, a system for air embossing a fabric is disclosed. The system comprises a cylindrical stencil with a plurality of openings formed therein. The system further comprises means for rotating the stencil about a rotational axis parallel to or co-linear with the longitudinal axis of the stencil, and means for supporting a fabric having an embossable surface for movement in a direction forming a non-zero angle with respect to the longitudinal axis of the stencil. The system further comprises means for
15 directing air from within the cylindrical stencil through the openings and towards the embossable surface of the fabric. The system includes at least one stencil stabilizer constructed and positioned to engage an inner surface of the cylindrical stencil to reduce variations in a distance separating the means for supporting the fabric and a portion of an outer surface of the stencil directly adjacent thereto as the stencil rotates.

20 In another aspect, a method for stabilizing the rotation of a cylindrical stencil of an embossing system for air embossing a surface of an embossable fabric is disclosed. In one embodiment, the method comprises positioning a portion of a fabric-facing surface of the stencil directly adjacent to the embossable surface of the fabric and at a first distance from the embossable surface of the fabric. The method further comprises
25 positioning at least a portion of at least one stencil stabilizer at least partially disposed within the cylindrical stencil so that the portion is in direct contact with a surface of the stencil. The method further comprises rotating the stencil.

30 In another embodiment, a method for stabilizing the rotation of a cylindrical stencil of an embossing system for air embossing a surface of an embossable fabric is disclosed. The method comprises applying a force to the stencil sufficient to reduce variations in a distance separating the embossable surface of the fabric and a portion of a

fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil. The method further comprises rotating the stencil.

Other advantages, novel features, and purposes and applications of the disclosed systems, articles, devices, and/or methods will become apparent from the following detailed description when considered in conjunction with the accompanying drawings, which are schematic and which are not intended to be drawn to scale. In the figures, each identical, nearly identical, or closely similar component that is illustrated in various figures is represented by a single numeral. For purposes of clarity, not every component is labeled in every figure, nor is every component of each embodiment shown where illustration is not necessary to allow those of ordinary skill in the art to understand the invention.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1a is a schematic perspective view of an unembossed pile fabric;

FIG. 1b is a cross-sectional schematic illustration of the pile fabric shown in FIG. 1a;

FIG. 2a is a schematic perspective view of an embossed pile fabric produced in accordance with an embodiment of the present invention;

FIG. 2b is a cross-sectional schematic illustration of the embossed pile fabric of FIG. 2a;

FIG. 2c is a cross-sectional schematic illustration of an embossed pile fabric similar to that shown in FIG. 2b, except produced using prior art air embossing technology;

FIG. 3 is a schematic diagram of a process for embossing a pile fabric according to one embodiment of the invention;

FIG. 4a is a schematic perspective view of an air embossing system for producing an embossed pattern on a pile fabric, as viewed from the right, according to one embodiment of the invention;

FIG. 4b is a schematic perspective view of an air embossing system for producing an embossed pattern on a pile fabric, as viewed from the left, according to one embodiment of the invention;

FIG. 4c is a schematic perspective view of an air embossing system for producing an embossed pattern on a pile fabric, as viewed from underneath the fabric, according to one embodiment of the invention;

FIG. 4d is a schematic illustration of an embossing cylinder for producing an embossed pattern on a pile fabric according to one embodiment of the invention;

FIG. 5a is a cross-sectional schematic illustration of certain components of the air embossing system of FIGs. 4a-4c, including an air lance mounted therein;

FIG. 5b is a cross-sectional schematic illustration of certain components of the air embossing system of FIGs. 4a-4c, including an air lance mounted therein, illustrating an embodiment wherein the nozzle of the air lance is in direct contact with the inner surface of the embossing stencil;

FIG. 5c is a cross-sectional schematic illustration of certain components of the air embossing system of FIGs. 4a-4c, including an air lance mounted therein, illustrating an arrangement for providing a stencil stabilizer while maintaining a non-zero separation distance between the nozzle of the air lance and the inner surface of the embossing stencil;

FIG. 5d is a cross-sectional schematic illustration of certain components of the air embossing system as in FIGs. 4a-4c including an unstabilized embossing stencil at a first rotational position in which a portion of the outer surface of the stencil adjacent the embossable surface of the fabric and the embossable surface of the fabric are in contact;

FIG. 5e is a schematic illustration of the air embossing system of FIG. 5d, with the rotating stencil in a rotational position where the portion of the outer surface of the stencil directly adjacent to the surface of the embossable fabric is separated from the surface of the embossable fabric by a maximum distance;

FIG. 5f is a schematic illustration of the components of the air embossing system shown in FIGs. 5d and 5e, wherein the rotating stencil is positioned to be in contact with a stencil stabilizer;

FIG. 6a is a schematic illustration of an air distribution lance for use in an air embossing process according to one embodiment of the invention, as viewed from the bottom;

FIG. 6b is a schematic illustration of the air distribution lance of FIG 6a, as viewed from the side;

FIG. 6c is a cross-sectional view of the air distribution lance of FIG. 6a;

FIG. 6d is a cross-sectional view of a first alternative embodiment of the air
5 distribution lance of FIG. 6a;

FIG. 6e is a cross-sectional view of a first alternative embodiment of the air distribution lance of FIG. 6a;

FIG. 6f is a cross-sectional view of a second alternative embodiment of the air distribution lance of FIG. 6a;

10 FIG. 6g is a cross-sectional view of a second alternative embodiment of the air distribution lance of FIG. 6a;

FIG. 7a is a schematic illustration of an air distribution lance for use in an air embossing process according to another embodiment of the invention, as viewed from the bottom;

15 FIG. 7b is a schematic illustration of the air distribution lance of FIG 7a, as viewed from the side;

FIG. 7c is a cross-sectional view of the air distribution lance of FIG. 7a;

FIG. 7d is a cross-sectional view of the air distribution lance of FIG. 7a;

FIG. 7e is a cross-sectional view of the air distribution lance of FIG. 7a;

20 FIG. 8a is a schematic illustration of an air distribution lance for use in an air embossing process according to yet another embodiment of the invention, as viewed from the bottom;

FIG. 8b is a schematic illustration of the air distribution lance of FIG 8a, as viewed from the side;

25 FIG. 8c is a cross-sectional view of the air distribution lance of FIG. 8a;

FIG. 8d is a cross-sectional view of the nozzle-forming component of the air distribution lance of FIG. 8a;

FIG. 8e is a cross-sectional view of the air distribution lance of FIG. 8a;

FIG. 8f is a cross-sectional view of an alternative embodiment of the air
30 distribution lance of FIG. 8a;

FIG. 8g is a cross-sectional view of the nozzle-forming component of the air distribution lance of FIG. 8e;

FIG. 9a is a schematic illustration of the air redirecting element of the air lance of FIG. 8a;

5 FIG. 9b is a cross-sectional view of the air redirecting element of FIG. 9a;

FIG. 10a is a schematic perspective view of an air embossing system for producing an embossed pattern on a pile fabric, as viewed from the right, including a stencil stabilizer therein, according to one embodiment of the invention; and

10 FIG. 10b is a schematic perspective view of the air embossing of FIG. 10a, as viewed from the left.

DETAILED DESCRIPTION

The present disclosure describes a variety of improved air embossing systems and methods of operation of air embossing systems that includes embodiments that are able
15 to improve the performance of such systems and result in the production of embossed fabrics which can have an unprecedented level of fine detail and uniformity to the embossed pattern and a lack of undesirable artifacts in the embossed pattern. As will become more apparent from the detailed description below, an important factor in the performance of air embossing systems is the design and positioning of the air lance,
20 which distributes air through a patterned stencil and onto the surface of the fabric, within the system. The present disclosure describes, in the context of some embodiments, a variety of improved air lance designs and improved systems for positioning the air lance with respect to the stencil and fabric.

The present invention is broadly directed to methods and systems for air
25 embossing an embossable fabric. It should be understood that while the invention is described in the embodiments below in the context of embossable fabrics comprising flocked, pile fabrics, that the invention is not so limited and that an embossable fabric as used herein encompasses any fabric having at least one embossable surface. An
30 "embossable surface" refers to a surface that can be permanently or temporarily visibly altered by an air stream impinging thereon. In addition, while the present invention is described as utilizing air for embossing an embossable surface of a fabric, it should be

understood that other gases may be substituted for air, as would be apparent to those of ordinary skill in the art.

While, in some embodiments, the air embossing systems disclosed can include an air lance directing a stream of air directly onto the embossable surface of an embossable fabric to form a pattern thereon, in preferred embodiments, the air stream from the air lance is directed through a stencil before impinging upon the surface of the fabric. A “stencil” as used herein defines a gas impermeable surface having a plurality of apertures therein oriented in a pattern on the surface. The air directed from the air lance onto the surface of the stencil, in such systems, is interrupted by the solid, gas-impermeable stencil but passes relatively freely through the openings or apertures within the stencil, thus forming an embossed pattern on the surface of the fabric dictated by the pattern of apertures within the stencil. Stencils for use within the context of the invention can comprise flat or cylindrical surfaces, and the surfaces can be stationary or movable with respect to the embossable surface of the fabric during operation of the air embossing system. Preferred systems utilize a rotatable, hollow cylindrical stencil disposed across essentially the entire width of the embossable surface of the fabric and having an air lance disposed therein.

An “air lance” as used herein refers broadly to a conduit, manifold, or other object able to direct a stream of air onto the surface of a stencil and/or embossable fabric.

In preferred embodiments, described in detail below, the air lance comprises an elongated conduit, extending across essentially the entire width of the fabric that is embossed by the system, which includes at least one nozzle for directing the stream of air. A “nozzle,” as used herein, refers to the smallest orifice within the air lance through which an air stream passes. An “orifice,” or “opening” as used herein in the context of the nozzle or nozzles, refers to a planar or contoured interfacial area providing a transition between a region of the air lance in which the air stream is confined on at least two adjacent and opposed sides, defining a smallest cross-sectional dimension of the air stream, by surfaces aligned essentially parallel, or having a component in the coordinate direction parallel to but having overall orientation that is angled with respect to the direction of bulk flow of the air stream, and a region, which may be external to the air

lance, wherein the air stream is unconfined on at least one of such two adjacent and opposed sides.

As shown in more detail below, some of the air lances disclosed can include a plurality of discrete nozzles therein, for example, a plurality of nozzles comprising individual holes within the air lance, each of which direct a stream of air toward the surface of an embossable fabric. In such embodiments, each of such holes comprises a “nozzle.” For embodiments where the nozzles are not all of the same size, or where the air lance includes a nozzle having a characteristic dimension that is non-uniform along the length of the air lance, the “smallest orifice in the air lance through which an air stream passes,” which defines a “nozzle”, refers to the smallest orifice in the lance through which any portion or component of the air stream passes. In other words, for embodiments including a nozzle or nozzles that are non-uniform in size, as described above, the smallest orifice through which any given molecule or atom of the air stream passes before exiting the air lance comprises a “nozzle”.

In preferred embodiments, the nozzle or nozzles within the air lance are constructed and positioned to direct a stream of air through at least one opening in a stencil and onto an embossable surface of the fabric. The term “constructed and positioned to direct a stream of air through at least one opening in a stencil and onto an embossable surface” of a fabric as used herein refers to the nozzle(s) being sized and positioned within the air embossing system such that at least a portion of an air stream emitted from the nozzle(s) is directed through an opening of the stencil and onto the embossable surface of the fabric.

Conventional prior art air lances utilized for air embossing fabrics typically comprise a long tubular conduit having a single row of holes extending lengthwise along the tube so that they traverse the width of the fabric when the air lance is positioned for use. The holes, comprising nozzles of the air lance, in prior art configurations, are typically relatively large in diameter (e.g., greater than about 0.25 inch in diameter). The open area in the air lance formed by the nozzles also, in conventional designs, is at least about 40 % of the internal cross sectional area of the main body of the air lance. Also, in conventional air embossing systems, the nozzles are positioned spaced apart from the

stencil through which the air is directed by a relatively large distance of at least about 1 inch.

The above-described conventional air lance designs are not well suited for producing finely detailed embossed patterns in fabrics, which patterns have a uniform visual appearance across the width of the embossed fabric. Such finely detailed embossed patterns in fabrics are highly desirable in the marketplace and are enabled and provided by many of the improved systems and methods disclosed herein. The air lances and air embossing systems utilizing the air lances disclosed herein can include a variety of improvements over the above-described prior art system, which improvements, alone or in combination, can solve many of the above-mentioned problems inherent in the prior art systems.

For example, some embodiments of the disclosed air embossing systems can include air lances that are designed so that the distance separating the nozzle(s) from the stencil is significantly less than for prior art systems. In combination with the above, or in other embodiments, air embossing systems can include air lances having a nozzle(s) with a characteristic dimension smaller than typical prior art nozzle sizes. In combination with the above, or in other embodiments, the air lances can include a nozzle(s) having a total open area that is significantly smaller with respect to a cross-sectional area of a conduit comprising the main body of the air lance than for typical prior art air lances. In combination with the above, or in other embodiments, an embossing method that involves emitting an air stream from the nozzle(s) of the air lance at a velocity that is significantly higher than that created by conventional air embossing systems can be utilized. In combination with the above, or in other embodiments, the air lances also can include nozzle(s) formed in the shape of a continuous slit, as opposed to the discrete holes comprising nozzles typically included in conventional air lances. In combination with the above, or in other embodiments, the air lances can include air redirecting elements or baffles therein, and/or nozzles that are shaped to create more focused and collimated air flow therethrough when compared to conventional air lance nozzles. In combination with the above, or in other embodiments, one or more stencil stabilizers configured to apply a force to a rotating stencil of the system during operation thereby reducing any variations in the distance separating the embossable surface of a

fabric being embossed with the system and that portion of the fabric-facing surface of the stencil directly adjacent to the embossable surface during rotation of the stencil can be provided.

Certain of the above-mentioned inventive features, when utilized alone or in
5 combination with other of the above-mentioned features, or in combination with other
inventive features of the air embossing systems described in more detail below, and/or in
combination with features of air embossing systems known in the art, can solve many of
the problems associated with typical prior art air embossing systems. For example, air
embossing systems and air lances as disclosed herein can create, in some embodiments, a
10 fabric embossing air stream having a high degree of collimation, a low degree of
turbulence, and a high flow velocity, yielding better definition and more fine detail in
fabric surfaces embossed with the inventive systems. The disclosed systems, in some
embodiments, also can include air lances which can emit an air stream having a more
even and uniform air flow velocity distribution across the entire width of the air lance
15 nozzle region than is achievable in typical prior art air lances. The disclosed air
embossing systems, in some embodiments, also can reduce or essentially eliminate
visible embossing artifacts present in an embossed fabric and created by the shape and
configuration of typical air lance nozzle designs that are utilized in conventional air
lances. In addition, some embodiments of disclosed air embossing systems can
20 essentially eliminate or reduce visible embossing artifacts present in an embossed fabric
surface and created by air impinging upon the surface of the fabric diagonally thereto,
which creates an overall visual directionality of the surface and a resulting distortion of
the embossed pattern, which is undesirable. In addition, some embodiments of the
disclosed air embossing systems can eliminate or reduce visible embossing artifacts
25 created by non-uniformity in the distance separating the portion of the stencil directly
adjacent to the fabric and the embossable surface of the fabric during rotation of the
stencil.

A conventional flocked fabric 10, which is unembossed, is shown in FIG. 1a, and
in cross-section in FIG. 1b. The fabric is comprised of a substrate layer 12 which is
30 coated by an adhesive layer 14, which is, in turn, coated by a pile layer 16 that is
comprised of a plurality of short lengths of pile fiber 18 that adhere to adhesive layer 14.

As shown in FIG. 1b, for an unembossed pile fabric, the individual pile fibers 18 are typically oriented essentially parallel to each other and essentially perpendicular to the surface of the adhesive layer 14 in which they are embedded.

Substrate 12, as shown, is comprised of a woven fabric formed by warp yarns 21 and fill yarns 23. Substrate 12 can be formed from a variety of woven materials incorporating natural and/or synthetic fibers, or combinations thereof. In one particular embodiment, the substrate can comprise a poly-cotton blend of 65%/35% having a weight in the order of 3.0 to 3.5 oz/sq. yd. While in the illustrated embodiment, a woven fabric is shown as a substrate, it should be understood that in other embodiments, substrate 12 may be any type of material suitable for flocking with a pile layer, such as a variety of woven fabrics, non-woven fabrics, knitted fabrics, porous or non-porous plastic and paper sheets, and the like, as apparent to those of ordinary skill in the art.

Adhesive layer 14 can be any conventional adhesive known in the art for use in fabricating flocked pile fabrics. Such adhesives include a wide variety of water based and/or non-aqueous solvent based adhesives. Also, as apparent to those of ordinary skill in the art, the adhesives may further include such components as viscosity modifiers, plasticizers, thermosetting resins, curing catalysts, stabilizers, and other additives well known in the art. The viscosity and composition of the adhesive chosen can be selected according to criteria readily apparent to those of ordinary skill in the art, including, but not limited to, the porosity and composition of substrate 12, the desired cure time and technique employed, the particular method of depositing pile fibers 18 onto the adhesive, the final weight and hand of the pile fabric desired, etc. In one particular embodiment, adhesive layer 14 comprises an acrylic polymer adhesive, which is applied on substrate 12 to have an essentially uniform thickness and a coating density of about 2.0 to 3.0 oz/sq. yd. of pile fabric. For a more detailed discussion of adhesives and various additives which can be used for forming adhesive layer 14, the reader is referred to U.S. Patent No. 3,916,823 to Halloran, incorporated herein by reference.

Pile fibers 18 comprising pile layer 16 may similarly be comprised of a wide variety of natural and/or synthetic fibers according to the particular desired characteristics of pile fabric 10. In a preferred embodiment, pile layer 16 is comprised of pile fibers 18 formed from a synthetic polymer material. In even more preferred

embodiments, pile fibers 18 comprise nylon fibers. Fibers 18 for flocking may be natural in color or dyed, depending on the particular application, and pile layer 16 may be formed of pile fibers 18 which are all of the same color, thus forming a pile face 16 having a solid color, or from a plurality of pile fibers 18 having different colors, thus forming a pile face 16 that is multicolored. For use in the present invention, where a printed pattern is transferred to the pile fabric, it is preferred to use pile fibers of the same color or undyed pile fibers.

The length of pile fibers 18, their denier, and the number density of the pile fibers on adhesive layer 14 can be varied over a relatively wide range and selected to yield a pile fabric having desirable characteristics for a particular application, as would be apparent to those of ordinary skill in the art. In one typical embodiment, pile fibers 18 can have an overall length between about 0.025 in and about 0.08 in (more preferably between about 0.04 in and about 0.065 in), a denier between about 0.45 and about 3.5, and an overall pile density of between about 1.0 to about 3.5 oz/sq. yd. of fabric. Pile layer 16 can be deposited on the adhesive coated substrate, as discussed in more detail below, by a variety of methods conventional in the art, including the use of flocked depositing equipment of the beater bar type, or electrostatic flocking equipment, such as described in more detailed in commonly-owned U.S. Patent No. 5,108,777 to Laird incorporated herein by reference. A printed pattern may also be transferred to the flocked fabric by a variety of conventional techniques, including, but not limited to, screen printing, transfer paper printing, painting, air brush, etc., as apparent to those of ordinary skill in the art.

FIGs. 2a-2b illustrates a flocked fabric 20 that is typical of the fabric that has been air embossed utilizing inventive air embossing systems and methods provided in accordance with the present disclosure. Pile layer 16, comprising the embossable surface of fabric 20, includes therein a plurality of air embossed features 22. Air embossed features 22 are characterized by flattened or otherwise reoriented pile fibers. Adjacent to and separating embossed features 22 are unembossed portions 24 of the fabric surface, which are characterized by pile fibers 18 that extend essentially perpendicularly from adhesive layer 14.

The orientation of pile fibers in the air embossed and unembossed portions of the fabric is seen more clearly in the cross-sectional view of FIG. 2b. FIG. 2c illustrates a similar embossed pile fabric 30 typical of that produced according to conventional prior art air embossing systems and methods. A comparison of the inventive air embossed fabric 20 and the conventionally produced air embossed fabric 30 illustrates several important distinctions. First, the inventive air embossed fabrics can have embossed features wherein the smallest, most finely detailed embossed features have a characteristic dimension significantly less than that achievable with conventional systems and methods. For example, embossed fabric 20, includes a smallest embossed feature 26 having a small characteristic dimension 28. By contrast, the corresponding embossed feature 36 produced by a conventional system has a characteristic dimension 38 which is typically much greater. A "characteristic dimension" of an embossed feature, as used herein, refers to the smallest cross-sectional dimension of the feature, as measured from a first edge 27 of an unembossed portion of pile layer 16 across the feature to a second edge 29 of another unembossed region on the opposite side of the feature.

It can also be seen by comparing the larger embossed features of FIGs. 2b and 2c that fabric 20, provided according to the present disclosure, has a significantly greater level of visual contrast between fibers in reoriented region 25 and the adjacent unembossed regions 24 of pile layer 16, when compared to fabric 30 produced according to conventional air embossing technology. Specifically, the reoriented fibers in reoriented portion 25 are significantly more flattened onto the substrate in the inventive fabric 20. In addition, distance 31 separating the flattened fibers of reoriented portion 25 and the essentially perpendicular fibers of an adjacent unembossed portion 24 can be very small and significantly less than the equivalent distance 37 of fabric 30 typically achievable using conventional air embossing technology. Thus, air embossed fabrics produced by air embossing systems and methods as described herein can have an unprecedented level of fine detail and an unprecedented level of sharpness and visual contrast between embossed and unembossed portions of the pile fabric, yielding embossed patterns and visual effects previously unachievable by air embossing systems and producible only via utilization of more expensive roll embossing techniques.

FIG. 3 illustrates a preferred method for forming and embossing a flocked pile fabric. Embossed fabric production system 100 shown in FIG. 3, with the exception of the inventive modifications to air embossing system 109 described in detail below, can be essentially conventional in design and can be operated by methods well known to those of ordinary skill in the art. Such methods and systems for air embossing have been utilized extensively in the prior art and are described in more detail, for example, in U.S. Patent No. 3,916,823 to Halloran. The process for producing an embossed pile fabric, for example similar to fabric 20 shown previously in FIG. 2a, can proceed as described below. Roll 102 of a substrate 12 can be conveyed, in the direction indicated by arrow 105, under tension from substrate roll 102 to take up roll 120 via conventional motor drive mechanisms for controllably driving one roll (i.e. take up roll 120) or both rolls. The fabric can be guided and supported along the path of the process via a series of support rollers 104. In other embodiments, instead of, or in addition to, conveying the fabric via motor-driven rotation of the take up roll/substrate roll, the fabric may be moved through the system via a conventional conveying system, such as a belt or apron conveyor. An adhesive layer is then applied to substrate 12 by a conventional adhesive applicator 106, for example a roll coater, curtain coater, doctor blade, printing method etc. Typically, the adhesive is applied to the substrate by a doctor blade, although other methods such as printing, paint spraying and silk-screening may be used. In a preferred embodiment, an adhesive layer is applied to the entire upper surface of substrate 12.

Substrate 12, now coated with an adhesive layer, is then passed to flocking chamber 108, which includes a pile applicator 110. In flocking chamber 108, as is conventional for producing flocked fabric, a layer of flocking formed by a multiplicity of fibers 18 is applied to the adhesive. Conventionally, and as hereinafter described, this deposition may be achieved by conventional beater bar or electrostatic techniques in which the ends of the pile fibers 18 adhere substantially to the adhesive layer. Pile fibers 18, in preferred embodiments, are oriented essentially perpendicular to the adhesive layer. In some preferred embodiments, flocking chamber 108 may comprise an alternating current electrostatic flocking device having a variable frequency alternating electrostatic field that optimizes flocked fiber characteristics and processing efficiency,

such as that described in commonly owned U.S. patent No. 5,108,777 to Laird and incorporated herein by reference.

After application of a pile layer, the flocked substrate 111 is passed under air embossing cylinder 112, which includes an air lance therein (shown and described in detail below) that is in fluid communication with pressurized air supply line 114. As described in more detail below, air embossing cylinder 112 typically comprises a cylindrical screen or stencil having perforations and solid areas therein. Also as described in more detail below, pressurized air from air supply line 114 is directed by the air lance through the apertures or perforations in the cylindrical screen or stencil of embossing cylinder 112, in order to form the embossed features within the pile layer of the fabric. An embossed pattern is formed by deflection of pile fibers 18 in the pile layer by air flowing through the apertures within the cylindrical screen or stencil of embossing cylinder 112. Upon flowing through the apertures in the stencil of embossing cylinder 112 the air impinges upon pile fibers 18 and orients them in a direction that is dictated in part by the air velocity, direction of air flow, and size of the aperture in the stencil through which the air passes. In other words, those portions of the pile layer passing underneath apertures within the cylindrical stencil will become oriented to form the depressions in the embossed pattern, whereas those portions passing under solid areas of the stencil will not be subject to substantial air flow or reorientation of pile fibers 18 in the pile layer. As will be apparent to those of ordinary skill in the art, it is preferred that the adhesive layer be in a wet, uncured state during the air embossing procedure, such that the pile fibers 18 are not rigidly held by the adhesive and are able to have their position and orientation changed by an impinging air flow. The velocity of the air flow impinging upon the pile layer should be sufficient to exert a force on pile fibers 18 in order to create a desired degree of reorientation of the fibers.

After being embossed by embossing cylinder 112, the pile fabric is passed through a curing chamber 116 in order to cure the adhesive layer so that the embossed pattern becomes permanently set. Curing chamber 116 may be comprised of any conventional curing equipment that exposes the embossed, but uncured, pile fabric to radiation, or other means of temperature elevation, to effect curing of the adhesive layer. Typical curing chambers operate by exposing the flocked fabric to a source of radiation,

such as infrared radiation or heat, or ultraviolet radiation. In some preferred
embodiments, curing chamber 116 comprises a gas-fired air dryer, as is well known in
the art, that exposes the flocked fabric to a flow of heated air to enable convective drying
and curing of the adhesive. After being cured, the embossed flocked fabric 118 exits the
5 curing chamber and is wound onto take-up roll 120. The speed at which the fabric is
conveyed through air embossing system 100 can vary depending on a number of
operating factors, as apparent to those of ordinary skill in the art. For some typical
embodiments, the speed would be in the range of about, for example, 25 to 150 ft/min.

FIGs. 4a-4c show air embossing system 109 in greater detail. Air embossing
10 system 109 comprises a modified version of a commercially available air embossing
system (Aigle Equipment Model No. AP-1, Burgano Toninese, Italy). In alternative
embodiments, the inventive features described herein may be utilized with other
commercial available air embossing systems or may be integrated into a custom built and
designed air embossing system, as would be apparent to those of ordinary skill in the art.
15 Furthermore, it should be emphasized that any particular dimensions, sizes, materials,
etc. described below for the illustrated embodiments of the invention are purely
exemplary and are based upon the physical and operational constraints of the particular
illustrated embodiment of air embossing system 109. Other embodiments of the
invention, employing alternative air embossing systems, may utilize equipment having
20 different sizes and dimensions and employing different materials than specifically
described herein. Accordingly, the particular sizes, dimensions, materials etc. described
below are given purely for illustrative purposes and may be scaled, modified, or changed
for application of the inventive features to alternative air embossing systems, within the
scope of the invention.

25 Referring to FIG. 4a, flocked, unembossed fabric 111, is conveyed, as previously
described, toward embossing cylinder 112 in the direction shown by arrow 122.
Embossing cylinder 112 includes a generally cylindrical central region, disposed above
embossable surface 113 of unembossed fabric 111, comprising a generally cylindrical
stencil 128, described in more detail below. Embossing cylinder 112 includes at each
30 end thereof a reduced diameter stencil flange 130 (seen more clearly in FIG. 5) whereby
it is attached to rotating bearings 132 of motorized drive unit 134. Stencil flanges 130

are attached to rotating bearings 132 utilizing stencil mounting clamps 136, which may be of any conventional design known to those of ordinary skill in the art. Motorized stencil drive unit 134 includes support structures 138 and 140 disposed on opposite sides of the width of fabric 111. At least one of support structures 138 and 140 includes
5 therein a variable speed motor (not shown) which powers a conventional drive mechanism to rotate stencil 128 with respect to fabric 111. The drive mechanism for rotating the cylinder can be any suitable drive mechanism known in the art, including, but not limited to, belt-drive, gear-drive, friction and wheel-drive, inductive-drive, etc. mechanisms as apparent to those of ordinary skill in the art. The drive mechanism of the
10 illustrated embodiment comprises a gear-drive mechanism in which a variable speed motor (not shown) within support structure 140 rotates a gear (not shown) which, in turn, is engaged with a circumferential gear (not shown) comprising an outer surface of rotating bearing 132 within support structure 138.

In the illustrated embodiment, the variable speed embossing cylinder drive motor
15 can be operated to rotate cylinder 112 in the direction of arrow 140 (i.e., in a direction opposite that of the motion 122 of fabric 111) or, more preferably, in the direction of arrow 142 (i.e., in the same direction as the direction 122 of fabric 111).

In conventional prior art systems, embossing cylinder 112 is rotated in the direction of arrow 142 such that the speed of the surface of stencil 128 is essentially the
20 same as the speed of fabric 111 passing under stencil 128. In such conventional embodiments, the rotational speed of apertures 144, within stencil 128 of embossing cylinder 112, is matched to the speed of fabric 111 passing underneath, resulting in embossed features 22 in the air embossed fabric 118 having an overall length, as measured in the direction of motion 122 which is essentially the same as the overall
25 length of the aperture 144 in stencil 128, as measured along the direction of rotation 142, which forms the embossed feature. By utilizing the variable speed motor drive disclosed herein, stencil 128 can be rotated, in some embodiments, at speeds that are different than the speed of the fabric passing under the stencil, in order to create a variety of embossed patterns on the fabric, which each have a different visual appearance, with a single, given
30 stencil,.

For example, by rotating the stencil in direction 142 at a speed which is greater than that of the speed of the fabric passing under the stencil, the embossed features produced by air passing through apertures 144 are shortened as measured along a direction parallel to the direction of motion 122 of the fabric when compared to an equivalent embossed pattern produced by a stencil rotating at the same speed as the fabric. In contrast, by rotating stencil 128 in a direction of arrow 142 at a speed which is less than the speed of the fabric passing under the stencil, embossed features 122 can be relatively lengthened and the level of detail visually evident in the embossed feature can be increased when compared to features produced with a stencil rotated at the same speed as the speed of the fabric. Thus, by changing the relative speed of the stencil with respect to the fabric, a variety of different patterns can be produced utilizing a single stencil. In some embodiments, the speed of the fabric differs from the speed of the rotating stencil by at least a factor of about 2, and in other embodiments differs from the speed of the fabric by at least a factor of about 4.

One embodiment for embossing cylinder 112 is shown in greater detail in FIG. 4d. Embossing cylinder 112 comprises a hollow cylinder having a centrally disposed stencil 128 defining an embossing region 146, which extends across the width of the fabric to be embossed. In the illustrated embodiment, the embossing region is between about 54 inches and about 64 inches in length. The embossing cylinder 112, as illustrated, has a stencil region 128 having an outer circumference of about 25 inches. The inner diameter of stencil region 128, in the illustrated embodiment, is about 7.95 inches, while the inner diameter of stencil flange 130 is about 5.5 inches.

Cylindrical stencil 128 can be conventionally formed from, for example, a cylindrical screen which has a series of solid, air impermeable regions 141 therein and a series of apertures 144 therein, which apertures permit air flow therethrough. Cylindrical stencil 128 can be formed in any manner conventionally used for forming such stencils. For example, in one embodiment, cylindrical stencil 128 can be formed using a well known lacquered screen ("Penta" screen) process, where a cylindrical screen, typically constructed from a metal such as nickel, is coated with a lacquer. In forming the stencil, for such embodiments, the screen is first coated with an essentially uniform layer of lacquer, covered with a pattern template having regions that can block ultraviolet

radiation, and exposed to ultraviolet radiation which tends to cure the lacquer. The regions of the screen beneath the pattern template regions that can block ultraviolet radiation will remain uncured after exposure and can be subsequently removed from the screen, thus leaving behind on the screen a lacquer coating, forming the stencil, having
5 apertures therein with a pattern that is complementary to that of the pattern template. In another embodiment, the stencil can be formed by coating a metal screen with a patterned metallic layer using a Galvano process well known in the art. In yet other embodiments, cylindrical stencil 128 can be formed by directly covering a cylindrical screen with an air impermeable layer, such as a paper, plastic, or other air impervious
10 layer, and then cutting out selected portions from the air impervious layer to form apertures 144. It is to be understood, of course, that regions corresponding to apertures 144 may be cut out of the air impervious layer prior to utilizing the layer to form cylindrical stencil 128. In other embodiments, cylindrical stencil 128 may be formed from a stencil typically employed for use in rotary screen printing operations or by any
15 other methods apparent to those of ordinary skill in the art for forming air embossing stencils. Apertures 144 in cylindrical stencil 128 result in the formation of embossed depressions 22 in embossed fabric 118 as air passes through the apertures and impinges upon fabric 111 as it passes under embossing cylinder 112. As is apparent in FIG. 2a, the embossed depressions 22 formed by apertures 144 can typically have a similar
20 overall shape and orientation as the apertures in cylindrical stencil 128.

As described in more detail below, cylindrical stencils (e.g. 128) produced according to the above described methods, while preferably having a cylindrical shape which is essentially perfectly circular when sectioned in a plane perpendicular to the longitudinal axis of the stencil and while preferably having the longitudinal axis, which
25 is centrally disposed within the stencil, being essentially co-linear to the longitudinal rotational axis of the embossing cylinder (e.g. 112) supporting and containing the stencil, often, because of manufacturing defects, fabrication/mounting tolerances, damage in use, etc., have a cylindrical shape which, when sectioned in a plane perpendicular to the longitudinal axis is not circular and/or have their longitudinal axis being offset from the
30 longitudinal rotational axis of the embossing cylinder supporting the stencil such that all portions of the inner surface of the stencil are not equidistant from the longitudinal

rotational axis of the embossing cylinder. Such irregularities in shape of the cylindrical stencil and/or deviations of the central longitudinal axis of the stencil from the central longitudinal rotational axis of the embossing cylinder cause the stencil to display an undesirable characteristic of "run out" when it is configured as illustrated in FIGs. 4a and 4b and rotated above the embossable surface (e.g. 113) of the fabric. Specifically, as the stencil rotates above the fabric surface, deviations from circular in the cross-sectional shape of the stencil and/or non-co-linearity of the central longitudinal axis of the stencil and the rotational axis of the embossing cylinder result in deviations in the distance separating the embossable surface of the fabric from the portion of the outer surface of the stencil positioned above and directly adjacent to the embossable surface of the fabric, as the stencil rotates.

This "run out" phenomena is illustrated and explained in more detail in the context of FIGs. 5d-5f below. The term "run out" as used herein refers to the difference between the distance separating the embossable surface of the fabric being embossed and the portion of the outer surface of the stencil positioned above and directly adjacent to the region of the fabric surface being embossed when the rotating stencil is in a rotational position such that the above-described separation distance is at its maximum value, and the distance separating the embossable surface of the fabric being embossed and the portion of the outer surface of the stencil positioned above and directly adjacent to the region of the fabric surface being embossed when the rotating stencil is in a rotational position in which the above-mentioned separation distance is at its minimum value. Such "run out" is undesirable since variations in the above-mentioned distance can create undesirable variations in the level of detail achievable and the overall appearance of the embossed pattern formed on the fabric. In addition, for embodiments where it is desirable to maintain the portion of the outer surface of the stencil directly adjacent to the embossable surface of the fabric within a distance from the embossable surface of the fabric that is less than that defining the "run out" of the stencil, the stencil can create undesirable artifacts in the embossed pattern caused by direct contact of the outer surface of the stencil with the embossable surface of the fabric during rotation of the stencil.

While the above described "run out" phenomena can be present in the cylindrical stencils produced according to any of the above-described methods for forming air

embossing stencils, the degree of "run out" tends to be greatest in stencils formed by the above-mentioned "Penta screen" producing process. Such stencils are typically lighter in weight, thinner, and less mechanically rigid than stencils produced by other of the above-mentioned processes. "Penta screen" stencils, however, have many features which make them desirable for use with air embossing systems and methods. For example, "Penta screens" are typically easier and less expensive to fabricate than screens made by some other typical prior art methods for forming stencils (e.g., those formed by a Galvano process). The Applicants have observed that the amount of "run out" typically observed when utilizing "Penta screen"-type stencils can be as great as about 0.1 in., or even greater in some instances. As described in more detail below, one aspect of the present invention involves stabilizing the rotation of the cylindrical stencil utilized for air embossing with one or more stencil stabilizers so that the stencil rotates substantially true about the rotational axis of the embossing cylinder so that there is a reduced variation in the distance separating the embossable surface of a fabric being embossed and the portion of the fabric-facing surface of the stencil directly adjacent to the embossable surface of the fabric during rotation of the stencil.

Referring again to FIG. 4a, support structures 138 and 140 also include mechanisms thereon for holding and positioning an air lance (shown and described in detail below), which air lance is configured and positioned to direct a stream of air through apertures 144 in stencil 128 and onto fabric 111 to produce embossed features 22 in embossed fabric 118. In FIGs. 4a and 4b, in order to more clearly illustrate the air lance support and positioning mechanism, the air lance has been removed from the system and is not illustrated. When assembled for operation, the elongated air lance is inserted into aperture 148 in rotating bearing 132 such that it is disposed within embossing cylinder 112, extends across the width of embossing cylinder 112, and is supported by air lance inlet cradle 150 and air lance outlet cradle 152 (shown more clearly in FIG. 4b) of system 109. Aperture 148, from which the inlet region of the air lance extends when installed in its operable configuration, has an internal diameter which is essentially equal to the internal diameter of stencil flange region 130 (i.e., about 5.5 inches as illustrated) of embossing cylinder 112.

When configured for operation, the inlet region of the air lance is cradled and supported by air lance inlet cradle region 154 of air lance inlet support arm 150. Preferably, air lance inlet cradle region 154 is sized and shaped such that it is complementary to the size and shape of the inlet region of the air lance so that the inlet region of the air lance rests snugly and securely within the air lance cradle region, when the system is in operation.

Air lance inlet support arm 150 is pivotally attached to support structure 138 via spacer 156 and pivot bearing 158 so that the support arm can be pivoted up and down in the direction of arrows 160 in order to adjust the height of the air lance with respect to embossing cylinder 112 and in order to adjust the distance between the nozzle(s) in the air lance and the inside surface of stencil 128, as described in more detail below.

Height adjustment of the air lance, supported by air lance inlet support arm 150, is effected by air lance inlet height adjuster 162. Height adjuster 162 comprises a main body 164 attached to the face of support structure 138 via mounting bracket 166. Height adjuster 162 further includes a reciprocating piston 168 connected to the air lance inlet support arm 150 via a nut 170 on a threaded end thereof. In preferred embodiments, air lance inlet height adjuster 162 has a range of motion such that in a lower most position a nozzle of an air lance inserted into embossing cylinder 112 can contact the lowest portion of the internal surface of the embossing stencil, and an uppermost position providing a separation distance between the nozzle of the air lance and an internal surface of embossing stencil 128 that is at least as great as the maximum separation distance desired during operation the system. In the illustrated embodiment, air lance inlet height adjuster 162 is pneumatically actuated via air line 172 to effect coarse up and down adjustment, and also includes a manually actuated fine height adjustment knob 174, which is utilized by an operator to make fine height adjustments. The height adjuster also, if desired, can include a scale 176, which can assist an operator to accurately and reproducibly position the inlet of the air lance.

Details of the mechanism provided on support structure 140 for positioning and supporting a mounting shaft of an air lance, which mounting shaft being positioned at the opposite end from the inlet of the air lance (shown more clearly in FIGs. 6-8), is illustrated in FIG. 4b. Air lance mounting shaft support arm 152 is similar in

configuration to air lance inlet support arm 150 and is pivotally movable in order to adjust the height and position of the downstream end of the air lance via air lance downstream end height adjuster 178 which is essentially identical in design to inlet height adjuster 162. Height adjuster 162 and height adjuster 178, in preferred
5 embodiments, are adjusted to create an essentially uniform distance between the nozzle(s) of the air lance and an adjacent internal surface of embossing cylinder 112 that is essentially uniform across essentially the entire width of stencil region 128 of embossing cylinder 112. In other embodiments, however, the height adjusters may be differentially adjusted such that some nozzles of the air lance are closer to the stencil
10 than others, or some portions of a given nozzle provided by the air lance are closer to the internal surface of the stencil than other portions.

As illustrated below in FIGs. 6-8, which show a variety of embodiments of inventive air lances, the downstream ends of the illustrated air lances can include mounting shafts having outer diameters which are typically less than the outer diameters
15 of the main body portions and inlet regions of the air lances. The mounting shaft of the air lance is supported and positioned by air lance mounting shaft support clamp 180 which is mounted to support arm 152 via bolt and nut fasteners 182. In the illustrated embodiment, mounting shaft support clamp 180 is mounted within a slot 184 on a platform region 186 of support arm 152. This configuration allows mounting shaft
20 support clamp 180 to be slidably movable in the direction of arrows 188, in order to adjust the lateral position of the downstream end of the air lance within embossing cylinder 112. In preferred embodiments, the lateral position of the mounting shaft support clamp is adjusted so that the nozzle(s) of the air lance is positioned such that it is bisected by center line 190 of embossing cylinder 112.

25 Mounting shaft support clamp 180 also includes an angular adjustment set screw and knob 192 which can be utilized to adjust the angular orientation of the air lance within embossing cylinder 112. Support clamp 180 also includes perpendicular alignment set screw 194, which is mateable with an alignment hole (see FIGs. 6-8) within the mounting shaft of the air lance. When alignment set screw 194 is inserted into
30 the alignment hole, it serves to fix the angular adjustment of the air lance so that the nozzle(s) is positioned to direct a stream of air essentially perpendicularly to the

lowermost region of the internal surface of stencil 128 of embossing cylinder 112 (shown more clearly in FIG. 5 below). In certain embodiments, set screw 194 may be turned out so that it does not project into aperture 196 of mounting shaft support clamp 180, and the air lance may be positioned and secured utilizing angular adjustment set screw in knob
5 192 so as to position and secure the mounting shaft within aperture 196 at an orientation such that the nozzle(s) is not perpendicular and/or is not configured to direct an air stream essentially perpendicular to the lowermost internal surface of stencil 128 of embossing cylinder 112. In certain such embodiments, the air lance may be positioned such that the air stream forms an angle of, for example, about 5 degrees to about 10
10 degrees with respect to center line 190.

FIG. 4c illustrates a view of air embossing system 109 as seen by an observer positioned underneath fabric 111. In preferred embodiments, system 109 includes a support surface 236 positioned directly beneath stencil 128 that is configured to support the underside of fabric 111 at a location where the adjacent embossable surface of the
15 fabric is being impinged upon by an air stream emitted by the nozzle(s) of the air lance, when installed in the system during operation. While in alternative embodiments to that illustrated in FIG. 4c, the support surface may comprise a platform or other planar surface, it is preferred, as illustrated, that the support surface comprise a cylindrical, fabric support roller 104.

20 In the illustrated embodiment, fabric support roller 104 is mounted on roller mounting arms 198, which are supported by a roller support beam 200. In some embodiments, roller mounting arms 198 may be configured so that the vertical position of fabric support roller 104 may be adjusted with respect to roller support beam 200, fabric 111 and stencil 128 in the direction of arrows 199. Fabric support roller 104, in
25 preferred embodiments, is configured to be rotated, most preferably in a direction of motion 201 co-directional to fabric 111.

In the illustrated embodiment, fabric support roller 104 is driveably rotated via electric motor 202 and drive belt 204 located on motor support platform 203. In
30 alternative embodiments, as would be apparent to those of ordinary skill in the art, fabric support roller 104 may be rotated by a wide variety of alternative mechanical means. In the preferred embodiment illustrated, a surface cleaning element 206 is provided in

contact with an external surface 236 of fabric support roller 104. Surface cleaning element 206 serves to scrape off and remove any adhesive, pile fibers, or other debris which may collect on the surface 236 of fabric support roller 104, thus eliminating or reducing any buildup of debris under the surface of fabric 111 during operation, which
5 buildup in prior art systems typically limits the length of time the system can be operated without shutdown and cleaning of the support surface. In the illustrated embodiment, surface cleaning element 206 comprises a scraping blade positioned in contact with the outer cylindrical surface 236 of fabric support roller 104 along essentially the entire width of the fabric support roller positioned directly beneath stencil region 128 of
10 embossing cylinder 112. In the most preferred embodiments, the surface cleaning element is positioned to contact the support roller along substantially the entire length of the roller that is in contact with the underside of fabric 111. Alternatively, there are many other surface cleaning elements which may be utilized instead of scraping plate 206, for example, brushes, air jets, water jets, etc.

15 FIG. 5a is a cross-sectional view of one embodiment of air embossing system 109. For the purposes of illustration of the relative position of certain of the different elements of system 109, FIG. 5a illustrates a cross-sectional view of air embossing system 109 with one embodiment of an inventive air lance installed within the system and with certain details of the surrounding support structures not illustrated for clarity.

20 Air lance 210 is somewhat similar in design to air lance 700 illustrated and discussed in greater detail in the context of FIGs. 8a-8g below. As discussed above, air lance 210, when installed in operable engagement with air embossing system 109, has an inlet region supported and positioned by air lance inlet support arm 150 and air lance inlet height adjuster 162, and has a mounting shaft at its downstream end that is
25 supported and positioned by air lance mounting shaft support arm 152 and air lance mounting shaft height adjuster 178.

Air lance 210 illustrates one embodiment for an air lance which enables the nozzle(s) of the air lance to be positioned in close proximity to or in direct contact with an internal surface of the stencil. Air lance 210 is shaped in the form of a tubular conduit
30 and includes a main body portion 212 to which is attached a nozzle forming component 214. Nozzle forming component 214 includes at its end a nozzle 216 and is shaped and

positioned to enable the nozzle to be placed in very close proximity to or in direct contact with a portion 218 of the inner surface 223 of stencil 128, which portion 218 of the inner surface faces and is adjacent to the nozzle and is disposed directly opposite the portion 233 of the outside surface of the stencil that is directly adjacent to fabric 111.

5 A portion of an inner/outer surface of the stencil is "directly adjacent" to the fabric or the embossable surface of the fabric when such portion is positioned next to the fabric or the embossable surface at a distance, measured in a direction perpendicular to the fabric surface, less than the distance, measured in a direction perpendicular to the fabric surface, separating the fabric or embossable surface and any other portion of the
10 inner/outer surface of the stencil. In addition, any separation distance(s) referred to herein between the fabric, or the embossable surface of the fabric, and the outer surface of the stencil, or the portion of the outer surface of the stencil directly adjacent the fabric or embossable surface of the fabric, refer, unless otherwise indicated, to the perpendicular distance separating that portion of the outer surface of the cylinder that is
15 positioned directly adjacent to the embossable surface of the fabric and that portion of the embossable surface of the fabric that is positioned directly adjacent thereto (i.e. the smallest separation distance between the outer surface of the cylindrical stencil and the embossable surface of the fabric measurable at any instant of time during rotation of the embossing cylinder).

20 As discussed in more detail below, in order to minimize pressure drop along the length of the air lance and in order to provide a desirable distribution of air flow within the air lance, main body portion 212 preferably is essentially uniform in diameter along the entire length of the air lance through which air flows, when the air lance is in operation. Accordingly, because of the physical constraints imposed by the air
25 embossing system, conventional prior art air lances having nozzles formed directly in the side wall of the main body portion of the air lance and not including a nozzle forming component, such as nozzle forming component 214, which projects and extends away from the side wall of the main body portion, cannot be positioned within the embossing cylinder so that the nozzle is in close proximity to or in contact with the inner surface of
30 the stencil.

The physical constraint of the air embossing system which prevents a nozzle formed directly in the side wall of a conventional air lance from being positioned in close proximity to or in contact with the inside of the stencil is due to the difference in internal diameter of stencil 128 and the smallest internal diameter 219 of stencil flange 130 and aperture 148 of the air embossing system. As discussed previously, for a typical setup utilizing a stencil having a 25 inch outer circumference with a 7.95 inch internal diameter and having a flange having an internal diameter of about 5 ½ inches, a distance 220 of about 1.2 inches exists between the inner surface 222 of aperture 148 and stencil flange 130 and the inner surface 223 of stencil 128. For conventional air lances without a nozzle forming component and having an inlet region having a diameter equal to or similar to the diameter of the main body portion, a nozzle formed in the side wall of the main body portion will be constrained by contact of the inlet portion of the air lance with surface 222, which contact will prevent the nozzle from being able to be positioned from the internal surface portion 218 of stencil 128 by a distance that is significantly less than distance 220.

Nozzle forming component 214, which extends along a substantial fraction of the length of main body portion 212 but does not extend into the inlet portion of the main body, is able to bridge distance 220 to enable the nozzle 216 to be positioned as close to surface portion 218 of stencil 128 as desired or in contact with surface portion 218, if desired. Nozzle forming component 214, as described in more detail below in the context of FIGs. 8a-8g, preferably extends along the length of main body portion 212 across essentially the entire width of stencil 128 and fabric 111, but does not extend into regions of the main body portion adjacent to internal surface 222.

It is generally desirable to maximize the internal diameter of main body portion 212 in order to minimize any pressure drop along the length of air lance 210, when the system is in operation. It is also required to size nozzle forming component 214 so that it extends from the external surface of main body portion 212 by a distance that enables nozzle 216 in the nozzle forming component to be positioned at a desirable distance from surface portion 218 of stencil 128 and/or in contact with surface portion 218. Thus, nozzle forming component 214 is shaped and positioned to enable nozzle 216 to be separated from surface portion 218 by a distance, including in preferred embodiments a

zero separation distance in contact with the inner surface, that is substantially less than the distance separating outlet opening 224 in main body portion 212, which outlet opening is in fluid communication with nozzle 216, and surface portion 218.

“Substantially less than” when referring to the above discussed distance between nozzle 216 and surface portion 218 in comparison to the distance separating outlet opening 224 and surface portion 218 indicates that the distance separating nozzle 216 and surface portion 218 is no more than about 60% of the distance separating outlet opening 224 and surface portion 218, and may, in some preferred embodiments, be less than 1% of the distance separating the outlet opening in the main body of the air lance and surface portion 218 of the stencil.

In the illustrated embodiment, main body portion 212 of air lance 210 comprises an aluminum conduit having a wall thickness of about 1/8 inch and an outer diameter of about 4 inches. In other embodiments, air lance 210 may be constructed of a variety of other materials, for example, other metals, plastics, etc. and may have a wall thickness different than that above, which is selected to provide sufficient resistance to operating pressure for the chosen material, as would be apparent to those of ordinary skill in the art. As discussed above, the main body portion 212 includes an outlet opening 224 therein, which is in fluid communication with nozzle forming component 214. Outlet opening 224 may comprise a plurality of holes in the side wall of main body portion 212; however, in more preferred embodiments such as that illustrated, outlet opening 224 comprises an elongated slot extending along a substantial portion of the length of the main body portion, as illustrated more clearly in FIGs. 8a - 8g. Main body portion 212 may also be stabilized against internal pressure by including one or more internal support struts 226 along its length, which can be welded or otherwise attached to main body portion 212 and can extend across outlet slot 224 in order to resist expansion of main body portion 212 when the air lance is in operation. Typically, when in operation, the inlet of air lance 210 is attached to an air supply 114, as shown above in FIG. 3, which preferably comprises a variable speed blower able to provide a user-adjusted volumetric flow rate of air to air lance 210. Typical operating pressures within air lance 210 can range from about 1 inch H₂O to about 100 inches H₂O.

Nozzle forming component 214 may be formed of any suitable material, as would be apparent to those of ordinary skill in the art, and, in preferred embodiments is formed of a rigid metal. Nozzle forming component 214 spans outlet slot 224 of main body portion 212 and includes an upper curved surface 225 shaped to conform to the contour of the outer surface of main body portion 212. Nozzle forming component 214 may be attached to main body portion 212 by any variety of means apparent to those of ordinary skill in the art. In the illustrated embodiment, nozzle forming component 214 is removably attached to main body portion 212 via a plurality of bolts 228 positioned along the length of the nozzle forming component on opposite sides of outlet slot 224.

Nozzle forming component 214, as illustrated, includes an internal chamber 230 therein which extends along the length of the nozzle forming component coextensive with nozzle 216. Nozzle 216 can comprise a plurality of individual holes or ports within the lower surface of nozzle forming component 214; however, in order to avoid artifacts caused by the air impermeable spaces between nozzles comprising individual apertures or orifices, in preferred embodiments, nozzle 216 comprises an elongated rectangular slit extending along a substantial fraction of the length of nozzle forming component 214 and across the width of stencil 128 and the embossable width of fabric 111, when installed in the system.

In preferred embodiments, nozzle slit 216 extends along the length of nozzle forming component 214 so that it is co-extensive with outlet slot 224 in main body portion 212 and is aligned directly beneath and parallel with the outlet slot. In the illustrated embodiment, nozzle forming component 214 extends away from main body portion 212 so that nozzle 216 is separated from outlet opening 224 by a distance of about 1.25 inches, which is sufficient to more than span the entirety of distance 220 separating surface portion 218 and surface 222, when the air lance is positioned in an operable configuration within the air embossing system. The illustrated combination, for example, of a 4 inch external diameter main body portion 212 and a nozzle forming component 214 that extends away from the main body portion by a distance by about 1.25 inches, results in an overall effective diameter 232 of air lance 210 that is just sufficient to clear smallest diameter 219 of stencil flange 130 and aperture 148 of the air embossing system.

It has been determined, according the invention, that by positioning nozzle 216 very close to surface portion 218 of stencil 128, which is directly adjacent to fabric 111, and in some preferred embodiments, in direct contact with surface portion 218 defining a zero separation distance, that the degree of collimation of air stream 231, emitted from the nozzle, at the point where the stream passes through stencil 128, is significantly enhanced over that of air streams emitted by conventional air lances at their point of passage through the embossing stencil. By reducing the distance separating nozzle 216 and surface portion 218, the length of air stream 231 between its source at nozzle 216 and surface portion 218 is accordingly reduced, and the amount of dispersion of the air stream is significantly reduced or essentially eliminated, resulting in the ability to achieve much finer levels of detail and an improved appearance of the embossed features of embossed fabric 118. As described in much more detail below, the close proximity of nozzle 216 to surface portion 218 of stencil 128, or contact between the nozzle and the surface, combined with the ability of nozzle forming component 214 to effectively redirect airflow from a direction essentially parallel to longitudinal axis 320 of air lance 210 to a direction substantially perpendicular to the longitudinal axis can enable air stream 231 to be directed in a direction that is much more perpendicular to the surface of fabric 111 than is achievable in conventional air lance designs.

As described previously in the context of FIGs. 4a and 4b, the position of air lance 210 and the distance separating nozzle 216 from surface portion 218 of stencil 128 can be adjusted by an operator as desired via manipulation of height adjusters 162 and 178. In addition, as previously described, the angular orientation of nozzle 216 with respect to center line 190 may be adjusted via angular adjustment set screw and knob 192 and perpendicular alignment set screw 194 (see in FIG. 4b). As illustrated in FIG. 5a, air lance 210 is positioned such that its alignment slot in its mounting shaft (see e.g. FIGs. 8a - 8g) is engaged by alignment set screw 194 so that nozzle 216 is positioned along the center line 190 of stencil 128 so as to direct air stream 231 essentially perpendicular to surface portion 218 and the embossable surface 113 of fabric 111. In preferred embodiments, nozzle 216 is positioned such that it is separated from surface portion 218 of stencil 128 during operation by a distance not exceeding about 0.75 inch, resulting in air stream 231 having a length between the nozzle 216 and surface portion 218 not

exceeding about 0.75 inch. In other preferred embodiments, the distance separating nozzle 216 and surface portion 218 does not exceed about 0.5 inch, in other embodiments does not exceed about 0.25 inch, in yet other embodiments does not exceed about 0.1 inch, in other embodiments does not exceed about 0.05 inch, in yet other
5 embodiments does not exceed about 0.025 inch, in other embodiments does not exceed about 0.0125 inch, and in yet other embodiments does not exceed about 0.01 inch. In some preferred embodiments, as previously mentioned, the nozzle 216 is placed in direct contact with surface portion 218 resulting in a zero separation distance.

In addition, it is preferred to adjust the vertical position of fabric support roller
10 104 and fabric 111 such that the upper most surface 113 of pile layer 16 is separated from external surface portion 233 of stencil 128, which surface portion 233 is opposite internal surface portion 218 and is positioned directly adjacent and above pile layer 16, by a distance not exceeding about 0.02 inch. In other embodiments, fabric-facing surface portion 233 of stencil 128 is positioned from the embossable surface of pile air 16 by a
15 distance not exceeding about 0.01 inch, in other embodiments by a distance not exceeding 0.005 inch, and yet in other embodiments by a distance not exceeding about 0.001 inch. Thus, it is desirable that the distance between surface portion 233 and pile layer 16 be very small but without surface portion 233 actually making physical contact with pile layer 16, which would tend to distort the pile air and create undesirable visual
20 artifacts. As previously mentioned, variation in the distance separating fabric surface 113 and surface portion 233 during rotation owing to irregularities in the shape or centering of stencil 128 causing "run out" can seriously impair or make impossible the achievement of the above mentioned desired separation distances without incurring artifacts due to contact of the stencil with the fabric. The disclosure also describes means
25 for stabilizing the rotation of the stencil to overcome or reduce this problem. Such means are discussed in much greater detail below.

Also, as illustrated in FIG. 5a, it is preferred that support surface 236 of fabric support roller 104 be positioned such that its upper most surface portion 238 is aligned with center line 190 such that surface portion 238 is positioned directed beneath and
30 spaced apart from nozzle 216 such that air stream 231 exiting the nozzle is directed to impinge upon fabric 111 at a location 241 where the fabric is adjacent to and in contact

with support surface 236. This configuration prevents the fabric from being pushed away from the embossing surface of stencil 128 by air stream 231 and maintains the desired distance between stencil 128 and pile layer 16 of embossable fabric 111.

Another way to improve the degree of collimation of air stream 232 and the ability of air lance 210 to produce fine embossed detail and desirable embossing performance is to substantially reduce the characteristic orifice dimension of nozzle 216 in comparison to characteristic orifice dimensions of nozzles in conventional air lances. A "characteristic orifice dimension" of a nozzle, as used herein, refers to the smallest cross-sectional dimension of the nozzle. In the illustrated embodiment, where nozzle 216 comprises an elongated rectangular slit, the characteristic orifice dimension 240 comprises the width of the elongated slit forming nozzle 216. For embodiments wherein the nozzles comprise circular holes, the characteristic dimension of each nozzle would be the diameter of the circular hole forming the nozzle. Similarly, for other shapes, the characteristic dimension can be determined by measuring the smallest cross-sectional dimension of the particular shape comprising the nozzle (e.g., for a nozzle comprising an ellipse, the characteristic orifice dimension would comprise the length of the minor axis of the ellipse). In preferred embodiments, the characteristic orifice dimension of the nozzles of air lances provided according to the invention is less than about 0.2 inch. In other preferred embodiments, the characteristic orifice dimension of the nozzle does not exceed about 0.1 inch, in other embodiments does not exceed about 0.05 inch, in yet other embodiments does not exceed about 0.01 inch, in other embodiments does not exceed about 0.005 inch, and in yet other embodiments does not exceed about 0.001 inch.

In addition to increasing the degree of collimation of air stream 232, by reducing the characteristic dimension of the nozzles of the air lances, the total amount of open area of the nozzles, through which the air stream passes, is a much smaller fraction of the cross-sectional internal area of the main body portion of the air lance supplying air to the nozzle. Thus, the inventive air lances, having nozzles with small characteristic orifice dimensions, generally can have a much higher fraction of the total resistance to air flow provided by the nozzle(s) than is typical for conventional prior art air lance designs. In preferred embodiments, the total open area provided by the nozzle(s) of the air lances

provided by the invention does not exceed about 15% of the internal cross-sectional area of the main body portion of the air lance. In other preferred embodiments the nozzle area does not exceed about 7.5%, in other embodiments does not exceed about 1.5%, and in yet other embodiments does not exceed about 0.1% of the total open cross-sectional area of the main body portion of the air lance.

By designing the inventive air lances so that most of the resistance to air flow is provided by the nozzle(s), the pressure drop along the length of the air lance can be substantially reduced, and the air flow emitted from the nozzle(s) along the length of the air lance can be much more evenly distributed than in conventional air lance designs. In some preferred embodiments, by employing a nozzle(s) with a very small characteristic orifice dimension, the air flow velocity through the nozzle(s) of the air lance can be substantially constant along the portion of the length of the air lance along which the nozzle(s) is positioned. This uniformity of air flow velocity emitted from the air lance along its length can result in a high degree of uniformity in the embossed pattern across essentially the entire width of fabric 111.

It is also desirable, according to some embodiments of the invention, to supply a sufficient flow of air to the inlet of the air lance to create a stream of air emitted from the nozzle(s) having an air flow velocity of at least about 12,000 feet per minute. In other preferred embodiments, sufficient air flow is supplied so that the velocity of air exiting the nozzle(s) of the air lance is at least about 15,000 feet per minute, in other embodiments at least about 20,000 feet per minute, and in yet other embodiments at least about 25,000 feet per minute. Such air flow velocities are substantially higher than those employed or achievable by typical prior art air embossing systems and enable the inventive system to produce extremely finely detailed embossed patterns. The air flow velocity through the nozzle(s) of the air lances can be easily determined by an operator of the system based upon the total open area of the nozzle(s), a measured inlet pressure of the air supply to the air lance, and performance charts typically supplied by the manufacture of the air blower utilized to supply air to the air embossing system. Such measurements and determinations are routine for those of ordinary skill in the art.

FIG. 5b illustrates a first embodiment for providing stencil stabilizers for reducing variations in the distance separating embossable surface 113 of fabric 111 and

the portion 233 of the fabric-facing surface of the stencil that is directly adjacent to the embossable surface of the fabric during rotation of the stencil. Stencil 128 in the embodiment illustrated in FIG. 5b comprises a stencil characterized by "run out," as previously discussed, making the maintenance of a consistent distance separating surface 113 of the fabric and portion 233 of the outer surface of the stencil during rotation of the stencil and operation of the system essentially impossible. Without some form of stencil stabilization, such as that shown in FIG. 5b and shown and described below in other embodiments, the separation between the portion 233 of the outer surface of the stencil and surface 113 of the fabric directly adjacent portion 233 would vary during rotation of the stencil by an amount essentially equal to the degree of "run out" inherent in the stencil, which can be as much as 0.1 inch or more.

In the illustrated embodiment, the stencil stabilizers comprise end surfaces 250 and 251 of nozzle forming component 214, positioned on the upstream and downstream sides of nozzle 216 respectively. In preferred embodiments, surfaces 250 and 251 are coated with an anti-friction material, for example polytetrafluoroethylene (PTFE), or other friction reducing coating known to those of ordinary skill in the art, in order to prevent wear and damage to inner surface 223 of stencil 128 during use.

Surfaces 250 and 251 of nozzle forming component 214 act as stencil stabilizers upon being brought into direct contact with inner surface 223 of stencil 128. Also, in the configuration illustrated in FIG. 5b, nozzle 216 is separated from inner surface portion 218 of stencil 128 by a zero separation distance (i.e., is in direct contact with surface portion 218), which is also desirable, in many embodiments, for increasing the level of definition of the embossed pattern formed on surface 113 of fabric 111 by decreasing, or essentially eliminating, the degree of dispersion of the air stream emitted from nozzle 216 prior to contact with inner surface portion 218 of stencil 128.

As is explained in more detail below, and as is illustrated in FIGs. 5d-5f, in preferred embodiments for providing stencil stabilization to reduce variations in the distance separating the embossable surface of the fabric and the portion of the outer surface of the stencil directly adjacent the fabric, the stencil stabilizer(s) provided by the air embossing system is brought into contact with and forced against inner surface 223 of stencil 128 to an extent sufficient to apply a force to the stencil during operation of the

system that is sufficient to reduce variations in the distance separating embossable surface 113 of fabric 111 at position 241 and portion 233 of the outer surface of the stencil directly adjacent to the embossable surface of the fabric during rotation of the stencil, and in even more preferred embodiments is sufficient to essentially eliminate variations in the above-mentioned separation distance. In such embodiments, the stencil stabilizer(s) is brought into contact with the inner surface of the stencil and is forced against the inner surface to a degree sufficient to create a tension in the stencil, which tension is sufficient to reduce, and preferably eliminate the degree of "run out" of the stencil and create a consistent separation distance between portion 233 of the fabric-facing surface of stencil 128 and embossable surface 113 of the fabric during air embossing. As is illustrated in FIG. 5b, the tension created in stencil 128 due to contact of the stencil stabilizers with the inner surface of the stencil can be sufficient to distort the unstressed shape of the stencil during rotation. For example, the unstressed shape of stencil 128 illustrated in FIG. 5b is shown by phantom lines 252, which shape is distorted due to the tension created in stencil 218 during operation of the system.

Referring now to FIGs. 5d-5f, the function of stencil stabilization provided according to some aspects of the invention is illustrated for a system including a stencil 128 having a somewhat irregular, elliptical shape, and displaying a substantial degree of "run out" during rotation. FIGs. 5d and 5e illustrate operation of the system configured to provide a desired separation distance (d_{max}) between the embossable surface of the fabric and the portion of the external surface of the stencil directly adjacent to the embossable surface without a force applied to the stencil by a stencil stabilizer, and FIG. 5f illustrates operation of the same system as configured to provide a desired separation distance (d_{max}) between the embossable surface of the fabric and the portion of the external surface of the stencil directly adjacent to the embossable surface including stabilization of the stencil during rotation.

In FIGs. 5d and 5e, stencil stabilizer surfaces 250 and 251 of nozzle forming component 214 are not positioned in contact with inner surface 223 of stencil 128, and thus no force is applied to stencil 128 to stabilize its rotation. In FIG. 5d, location (A) of stencil 128 is at the 12 o'clock position where the elliptically shaped stencil is rotationally positioned such that the separation distance between surface 113 of fabric

111 at position 241 and the portion 233 of the outer, fabric-facing surface of stencil 128 directly adjacent to position 241 is at its minimum value ($d_{min}(no\ force)$). The degree of “run out” of stencil 128 is sufficient to cause the fabric-facing surface of the stencil to directly contact fabric 111 when the stencil is in the position illustrated in FIG. 5d, thus causing undesirable distortion of the fabric surface and artifacts in the embossed pattern. FIG. 5e illustrates the configuration of the system as illustrated in FIG 5d, except after stencil 128 has rotated in the direction of arrow 142 one quarter turn. Now, the above-described separation distance between fabric surface 113 and portion 233 of the fabric-facing surface of stencil 128 is at its maximum value ($d_{max}(no\ force)$). The “run out” of stencil 128 is defined as the difference $d_{max}(no\ force) - d_{min}(no\ force)$.

FIG. 5f illustrates the system of FIGs. 5d and 5e, also configured to provide a desired separation distance (d_{max}) between the embossable surface of the fabric and the portion of the external surface of the stencil directly adjacent to the embossable surface, except configured so that the stencil 128 and air lance 210 are positioned within the system such that stencil stabilizing surfaces 250 and 251 of nozzle forming component 214 are in contact with the inner surface 223 of stencil 128 so as to apply a force to the stencil during operation of the system sufficient to reduce, and preferably eliminate, variations in the above-mentioned separation distance between the outer surface of stencil 128 and surface 113 of fabric 111 during rotation of the stencil. Surfaces 250 and 251 comprising stencil stabilizers are preferably in contact with the inner surface of stencil 128 at at least one rotational position of stencil 128, and in particularly preferred embodiments, the stencil stabilizers provided by the system are in contact with the internal surface of stencil 128 continuously throughout its rotation. When the stencil stabilizers are positioned in contact with the inner surface of stencil 128, the maximum distance ($d_{max}(force)$) separating embossable surface 113 at position 241 of fabric 111 from portion 233 of the outer surface of stencil 128 directly adjacent to the embossable surface of the fabric will be less than the maximum separation distance of the stencil equivalently configured within the system and positioned with respect to fabric 111 as illustrated in FIG 5f, except without having a force applied to the stencil by the stencil stabilizer(s) ($d_{max}(no\ force)$) (i.e. with the longitudinal axes of stencil 128 and roller 104 equivalently spaced but without surfaces 250 and 251 being engaged in contact with

inner surface 223 of the stencil). As discussed above, in the most preferred embodiments, the stencil stabilizers are forced against the inner surface of the stencil so that variations in the separation distance between the portion of the outer surface of the stencil directly adjacent the fabric and the embossable surface of the fabric are
5 essentially eliminated during rotation (i.e., $d_{max}(force)$ is essentially equal to $d_{min}(force)$ during rotation of the stencil).

The extent to which the maximum above-mentioned separation distance between the stencil and the fabric with no force applied ($d_{max}(no\ force)$) will exceed the maximum separation distance when the system is configured to apply a stabilizing force to the
10 cylindrical stencil ($d_{max}(force)$), as illustrated in FIG. 5f, will depend on the degree of "run out" of stencil 128 (i.e., $d_{max}(no\ force) - d_{min}(no\ force)$). In typical embodiments, $d_{max}(no\ force)$ can exceed $d_{max}(force)$ by at least about 0.001 in., in other embodiments by at least about 0.01 in., in other embodiments by at least 0.05 in., and in yet other
15 embodiments by at least about 0.1 in. As discussed above, in the most preferred embodiments, $d_{max}(no\ force) - d_{max}(force)$ is selected to essentially equal or slightly exceed $d_{max}(no\ force)$ minus $d_{min}(no\ force)$, in order to essentially eliminate "run out" and variation in the distance separating the embossable surface of the fabric and the portion of the outer surface of the stencil directly adjacent to the embossable surface during rotation of the stencil.

20 The method for stabilizing the rotation of stencil 128, as illustrated in FIG 5f, comprises first positioning a portion of the fabric-facing surface of the stencil directly adjacent to embossable surface 113 of fabric 111 at a first distance from the embossable surface of the fabric and then positioning the stencil stabilizers (surfaces 250 and 251) with respect to the inner surface of stencil 128 such that the stencil stabilizers are in
25 contact with the inner surface of stencil 128. In the most preferred embodiments, where it is desirable to essentially eliminate any "run out" and thereby essentially eliminate variations in the distance separating the embossable surface of the fabric and the portion of the fabric-facing surface of the stencil directly adjacent thereto, the stencil stabilizers are positioned within stencil 128 such that at least a portion thereof is in contact with the
30 inner surface of stencil 128 during the entire rotation thereof and is pressed against the

inside surface of the stencil with sufficient force during rotation to essentially eliminate “run out.”

This can be achieved, for example, as follows. First, stencil 128 is installed into the system and rotationally positioned, as illustrated above in FIG. 5d, so that the distance separating embossable surface 113 of fabric 111 and that portion of the fabric-facing surface of stencil 128 directly adjacent thereto is minimized (i.e., $d_{min}(no\ force)$). The vertical position of roller 104 and/or stencil 128 is then adjusted such that $d_{min}(no\ force)$ essentially equals or slightly exceeds the desired separation distance between the portion of the fabric-facing surface of stencil 128 directly adjacent to the fabric and embossable surface 113 of the fabric. The stencil stabilizers are then subsequently positioned into engaging contact with inner surface 223 of stencil 128 (e.g., by positioning air lance 210 such that stencil stabilizing surfaces 250 and 251 are in engaging contact with the inner surface of stencil 128) and forced against the inner surface of the stencil, if necessary, until the portion of the fabric-facing surface of stencil 128 directly adjacent to the fabric and embossable surface 113 of the fabric are separated by the desired separation distance.

FIG. 5c illustrates one preferred embodiment for providing a stencil stabilizer constructed to be positioned in contact with an inner surface of the stencil during operation of the system, while also providing a non-zero separation distance between nozzle 216 and inner surface 223 of stencil 128. In the illustrated embodiment, surface 253 of the upstream side of nozzle forming component 214 forms the stencil stabilizer in contact with inner surface 223 of stencil 128 during rotation. As above, in preferred embodiments, surface 253 is preferably coated with a friction-reducing material to prevent wear and damage to stencil 128 during use. As illustrated in FIG. 5c, nozzle forming component 214 is formed from an upstream 256 and a downstream 257 subcomponent, each positioned on a separate side of opening 224 in conduit 212. Nozzle forming component 214, as illustrated, is formed by mounting separable components 256 and 257 on opposite sides of outlet opening 224 such that they are positioned adjacent and separated from each other on conduit 212 so that the distance between adjacent facing surfaces 258 and 259 of the separable components defines a slit forming nozzle 216. In order to provide a desired separation distance between nozzle

216 and inner surface portion 218 of stencil 128 when stencil stabilizing surface 253 of nozzle forming component 214 is in contact with the inner surface 223 of stencil 128, upstream separable component 256 of nozzle forming component 214 is mounted to conduit 212 with a series of spacers or shims 260 positioned between the outer surface of the conduit and contoured upper surface 225 of component 256. The thickness of spacers or shims 260 is selected to be equal to the desired separation distance between the nozzle 216 and the inner surface portion 218 of the stencil. In other embodiments, instead of utilizing spacers/shims 260, component 256 may simply be manufactured such that it extends away from opening 224 and conduit 212 by a greater distance than subcomponent 257, or, in yet other embodiments, one or more ridges, projections, etc., may be attached to or formed on subcomponent 256 such that they extend beyond nozzle 216 to contact the inner surface 223 of stencil 128. In embodiments such as the latter of the above-described alternative embodiments, nozzle forming component 214 may be formed of a single, monolithic unit, instead of being formed as two separable components, as illustrated in FIG. 5c. Also, alternatively, downstream component 257 may be shimmed, etc., such that it extends away from opening 224 by a distance exceeding the maximum distance by which subcomponent 256 extends away from opening 224. In such embodiments, surface 261 would comprise the stencil stabilizing surface, which surface is positioned downstream of nozzle 216. It is preferred, however, that a stencil stabilizer be positioned to contact the inner surface of the stencil upstream of the nozzle, as illustrated in FIG. 5c, in order to prevent buildup of debris and other material which tends to clog the nozzle.

In general, for systems providing air lances including thereon at least one stencil stabilizer attached to and extending from the conduit forming at least part of the air lance, the stabilizer is constructed and positioned on the air lance to contact the inner surface of the stencil, when the air lance is configured in the system for operation, and is further constructed and positioned on the air lance so that the portion of the stencil stabilizer making contact with the inner surface of the stencil during operation is separated from the longitudinal central axis (e.g., axis 320 as shown in FIG. 5c) of the conduit by a distance that exceeds the distance separating the nozzle of the air lance from the longitudinal central axis of the conduit. As illustrated in FIG. 5c, stencil stabilizing

surface 253 is separated from longitudinal central axis 320 by a distance that exceeds the distance separating nozzle 216 from longitudinal central axis 320. Also, as illustrated in FIG. 5c, a desired separation distance between nozzle 216 and inner surface portion 218 of stencil 128 is enabled by positioning upstream separable component 256 of nozzle forming component 214 such that the maximum separation distance separating the upstream component from longitudinal central axis 320 (i.e., the distance separating surface 253 from longitudinal axis 320) exceeds the maximum distance separating downstream separable component 257 from longitudinal central axis 320 (i.e., the distance separating surface 261 from longitudinal axis 320) by an amount essentially equal to the desired distance separating nozzle 216 from inner surface portion 218 of stencil 128.

FIG. 6a illustrates an alternative embodiment of an air lance. Air lance 300, as shown in FIG. 6a, has a nozzle region 302 of main body portion 304 positioned so that it is facing the observer. FIG. 6b shows air lance 300 in a side view. Air lance 300 comprises a conduit having a main body portion 304 and includes an inlet opening 306 and a threaded inlet connector 308, allowing attachment of the air lance to air supply line 114 of the air embossing system when it is in operation. Main body portion 304 is essentially constant in diameter along its entire length. Main body portion 304 includes an inlet region 310 upstream of nozzle region 302 and may, optionally, include a small end region 312 downstream of nozzle region 302 and upstream of sealed end 314 of the main body portion. In alternative embodiments, air lance 310, or any other air lance illustrated herein, may, instead of having a single inlet opening for attachment to the air supply, have each of its ends open for fluid communication and attachable to an air supply. Affixed to downstream end 314 of main body portion 304 is mounting shaft 316 including an alignment slot 318 (seen most clearly in FIG. 6b), which mounting shaft typically has a diameter that is smaller than the diameter of main body portion 304.

When mounted in an operable configuration within air embossing system 109, inlet region 310 is disposed upon air lance inlet cradle 154 (see FIG. 4a) such that at least inlet connector 308 extends beyond air lance inlet support 150, so as to be easily connectable to air supply line 114. Air lance 300 is disposed within embossing cylinder 112 and extends across the entire width of the embossing cylinder so that mounting shaft

316 is disposed within air lance mounting tube support clamp 180 of the air embossing system (see FIG. 4b), when the air lance is configured for operation. Typically, for preferred embodiments where it is desired that nozzle region 302 be positioned so that it is bisected by center line 190 of embossing cylinder 112, alignment slot 318 is

5 configured to be engageable, when the air lance is in the above-described mounting position, with perpendicular alignment set screw 194, thus allowing the perpendicularly aligned position of the nozzle to be easily ascertained and securely maintained during operation.

Nozzle region 302 of air lance 300 extends along main body portion 304 in a
10 direction essentially parallel to longitudinal axis 320 of the air lance so that it is located within, and is essentially coextensive with, the width of stencil region 128 of embossing cylinder 112, when the air lance is installed in an operable configuration. Accordingly, nozzle region 302 is also configured to extend across essentially the entire width of the embossable surface 113 fabric 111, when in operation.

15 In the embodiment illustrated, nozzle region 302 is about 54 inches to about 64 inches in length, inlet region 310 is about 24 inches to about 28 inches in length, end region 312 is about 1 inch to about 4 inches in length, and mounting shaft 316 is about 13 inches to about 15 inches in length and is about 2 inches to about 3 inches in outer diameter.

20 Nozzle region 302 includes therein a plurality of individual nozzles 324, which, in the illustrated embodiment comprise a plurality of circular holes within main body portion 304. In the illustrated embodiment, nozzles 324 comprise holes bored directly into the side wall of main body portion 304; however, in alternative embodiments, nozzles 324 may be formed in a separable plate element, which is attachable by screws
25 or other fasteners to main body portion 304. Also, in other embodiments, the holes 324 comprising the nozzles may be arranged or positioned differently within nozzle region 302 than that shown. For example, in one alternative embodiment, the nozzles may be arranged in a single row within the nozzle region.

Because nozzle region 302, in the illustrated embodiment, includes nozzles 324
30 comprising of a plurality of individual holes separated by regions 325 of main body portion 304, which regions 325 are impermeable to air flow, it is preferred that nozzle

region 302 be separated from inner surface 218 of stencil 128 (see FIG. 5) by at least about 0.75 inch. In the illustrated embodiment, since the outer diameter of main body portion 304 is essentially constant (typically about 4 inches to about 5 ¼ inches), as previously discussed in the context of FIG. 5, it is not possible to position nozzles 324
5 any closer to inner surface 218 of stencil 128 than distance 120 (e.g., about 1.2 in, as illustrated). In order to reduce dispersion when nozzles 324 are separated by such relatively large distances, main body portion 304 preferably includes flaps 326 installed on each side of nozzle region 302. The flaps are flexible, in some embodiments, and thus they do not tend to prevent insertion of the air lance through the flanged region 130
10 of the embossing cylinder 112, and so that after insertion into the embossing cylinder, they extend downward from main body portion 304 by a distance preferably approximately equal to the distance separating nozzles 324 from the internal surface of the stencil region of the embossing cylinder.

For embodiments where it is desired to provide one or more stencil stabilizers on
15 air lance 300, one or both of flaps 326 can be replaced by a rigid component extending away from main body portion 304, forming a doctor blade positionable in contact with the inner surface of the air embossing stencil, when the air lance is positioned for operation. For such embodiments, in order to be able to insert the air lance into aperture 148 of the system, the overall, effective outermost diameter of the air lance-stabilizer
20 combination cannot exceed distance 219 as illustrated in FIG. 4d. In some preferred embodiments, the rigid doctor blade(s) forming one or both of components 326 and providing stencil stabilization can be separable from main body component 304 and interchanged with other rigid components of different size or can be positioned on body 304 at varying distances (as measured along the circumference of body 304) from the
25 nozzles, in order to change the separation distance between the nozzles and the inner surface of the stencil, when the air lance is positioned for operation with the stencil stabilizer(s) in contact with the inner surface of the stencil.

In order to improve the collimation of air flow from nozzles 324 and the distribution of air velocity along the length of nozzle region 302, it is preferred that
30 nozzles 324 have a characteristic dimension, characterized by the diameter of the holes comprising nozzles 324, that does not exceed about 0.2 inch, as was discussed above in

the context of air lance 210 illustrated in FIG. 5a. In other preferred embodiments, the characteristic dimension of nozzles 324 does not exceed about 0.1 inch, in other embodiments does not exceed about 0.05 inch, in yet other embodiments does not exceed about 0.01 inch, in other embodiments does not exceed about 0.005 inch, and in yet other preferred embodiments does not exceed about 0.001 inch.

Air lance 300 is shown in cross section in FIG. 6c. Nozzle region 302 is shown magnified in figure insert 328 of FIG. 6c. FIG. 6c illustrates one preferred embodiment for providing nozzles 324 having a characteristic nozzle length 330 which exceeds the characteristic orifice dimension 332 of the nozzle. In the illustrated embodiment, characteristic nozzle length 330 is essentially equal to the wall thickness of main body portion 304. Thus, in the embodiment illustrated in FIG. 6c, it is preferred that the diameter of nozzles 324 be no greater than, and preferably less than, the wall thickness of main body portion 304. In general, the "characteristic nozzle length," as used herein in the context of the air lances provided according to the invention, refers to the maximum dimension of the nozzle as measured in a direction that is essentially parallel to the overall direction of air flow within the nozzle (i.e., in a direction that is typically essentially perpendicular to the longitudinal axis of the air lance). By providing nozzles having a characteristic nozzle length that exceeds the characteristic orifice dimension of the nozzle, the air lances can significantly reduce the proportion of the air stream that is emitted from the nozzle in a diagonal direction with respect to the inner surface of the stencil, the surface of the fabric, and the longitudinal axis of the air lance. For an embodiment where the nozzles are in the form of circular holes having characteristic nozzle lengths approximately equal to the diameter of the holes forming the nozzle, it is apparent that essentially the entire stream of air directed towards the inner surface of the stencil through each nozzle will be directed through the nozzle at an angle of at least about 45 degrees with respect to the longitudinal axis of the air lance, when the system is in operation. Any component of the air stream forming an angle less than 45 degrees with respect to the longitudinal axis will impinge upon a side wall (e.g., walls 333 shown in FIG. 6c) and will be deflected towards the surface of the stencil at an angle with respect to the longitudinal axis of the air lance of at least about 45 degrees. In even more preferred embodiments, the characteristic length 332 of nozzles 324 exceeds the

characteristic orifice diameter 332 by at least a factor of about 2, in more preferred embodiments by at least a factor of about 3, and in the most preferred embodiments, by at least a factor of about 4.

FIG. 6d and FIG. 6e show cross sectional views of an alternative embodiment of air lance 300 that includes a plurality of air redirecting elements 340 that are shaped and positioned to intercept and deflect the air flow within main body portion 304 so that a greater fraction of the air flow is directed essentially perpendicular to longitudinal axis 320 and to the embossable surface 113 of fabric 111, when the air embossing system is in operation. As discussed above, in preferred embodiments, air directing elements 340 preferably intercept and direct the air flow so that essentially all of the air flow exits from nozzles 324 toward the fabric in a direction making an angle of at least about 45 degrees with respect to longitudinal axis 320 of the air lance. Air redirecting elements 340 comprise a series of baffles that may be formed of a wide variety of materials and may comprise a variety of structures able to deflect and redirect air flow. An "air redirecting element", "air flow redirecting element," or "baffle" as used herein refers broadly to any element positioned within an air lance, which is shaped, positioned, and configured such that at least a portion of the flow of air supplied to the air lance impinges upon and is redirected by the element from an initial air flow direction forming an angle of less than about 45 degrees with respect to the longitudinal axis of the air lance to a subsequent air flow direction forming an angle greater than about 45 degrees with respect to the longitudinal axis of the air lance.

In the embodiment illustrated in FIGs. 6d and 6e, air flow redirecting elements 340 comprise a plurality of tubular inserts positioned within outlet openings 341 of main body portion 304. Air redirecting elements 340 have an outer diameter that is equal to or slightly less than the diameter of outlet openings 341, such that they may fit snugly and securely within outlet openings 341, when installed as shown in FIG. 6d. Air redirecting elements 340 can, in some embodiments, be press fit into outlet openings 341 or, for improved stability, may be welded to main body portion 304, once they are inserted into outlet openings 341. Alternatively, air redirecting elements 340 may be welded, or otherwise attached within main body portion 304 adjacent and in fluid communication with outlet openings 341, without actually being inserted into the outlet openings.

Nozzles 324, as illustrated, have a characteristic orifice dimension 342 essentially equal to the internal diameter of air directing elements 340 and have a characteristic nozzle length 344 essentially equal to the length of air directing elements 340, as measured in a direction perpendicular to longitudinal axis 320 of the air lance. In
5 alternative embodiments, air directing elements 340, instead of being press fit within outlet openings 341 of main body portion 304, may have an inner diameter equal to or greater than the diameter of outlet openings 341 and may be attached to an inner surface of main body portion 304 above outlet openings 341, as described above, such that the characteristic nozzle length comprises the sum of the wall thickness of main body
10 portion 304 plus the length of an air redirecting element 340, as measured along a direction perpendicular to longitudinal axis 320. In such alternative embodiments, it is preferred that a substantial fraction of both (i.e., at least about 50%) of the characteristic length of the nozzle be comprised of the length of the air redirecting element, as measured in a direction essentially perpendicular to the longitudinal axis of the main
15 body.

Referring again to the embodiment shown in FIGs. 6d and 6e, in preferred embodiments, the length 344 of air redirecting elements 340, as measured in a direction that is essentially perpendicular to longitudinal axis 320, exceeds characteristic orifice dimension 342 of nozzles 324 by a factor of at least about 2, more preferably a factor of
20 at least about 3, and most preferably by a factor of at least about 4.

FIGs. 6f and 6g illustrate a cross-sectional view of another alternative embodiment of air lance 300 including a main body portion 304 including therein a single, monolithic air redirecting element 350. A "monolithic" air redirecting element, as used herein, refers to an air redirecting element having a plurality of surfaces for
25 redirecting or deflecting air, wherein the surfaces are formed within a single, undivided piece of material, or comprise a plurality of physically distinct elements that are interconnected together so as to form a continuous structure. Air redirecting element 350 is preferably positioned within main body portion 304 and attached to an internal surface of the main body portion by welded attachments, or other means of fastening, as would
30 be apparent to those of ordinary skill in the art. Air redirecting element 350 has an overall width and length sufficient to essentially completely cover and be coextensive

with nozzle region 302 of air lance 300. Air redirecting element 350 performs an essentially equivalent function as that previously described for air redirecting elements 340 in the context of FIGs. 6d and 6e above. Air redirecting element 350 can comprise a wire or fabric mesh, screen, grate, or any other suitable structure, as would be apparent to those of ordinary skill in the art. Air redirecting element 350, as illustrated in FIG. 6g, can comprise a grate-like structure having a plurality of cells 352, which form air flow channels that are oriented essentially perpendicularly to longitudinal axis 320 of the air lance. Cells 352 are separated one from another by a series of walls of structure 350 forming dividers 354. Distance 356, is the characteristic dimension of channels 352. In general, the "characteristic dimension" of a channel in a monolithic air redirecting element, as used herein, is defined as the largest cross-sectional dimension of the channel as measured along a direction essentially parallel to the longitudinal axis of the air lance.

The monolithic baffle 350 illustrated in FIGs. 6f and 6g has channels 352 comprising a plurality of square conduits arranged in a grid pattern. However, in alternative embodiments, the monolithic air redirecting element may have channels comprising a plurality of cells having cross-sectional shapes other than square. In one preferred embodiment, monolithic air redirecting element 350 comprises a honeycomb-like structure, described in more detail below in the context of FIG. 9, having a plurality of hexagonally shaped cells arranged in a honeycomb-like pattern.

In preferred embodiments, the height 358 of air redirecting element 350, as measured in a direction essentially perpendicular to the longitudinal axis of the air lance, exceeds characteristic dimension 356 by a factor of at least about 2, more preferably by a factor of at least about 3, and most preferably by a factor of at least about 4. Air redirecting element 350, when it is constructed and positioned as shown in FIGs. 6f and 6g functions to increase the fraction of air flow through nozzles 324 that is directed essentially perpendicularly to the longitudinal axis 320 of the air lance and essentially perpendicularly to the surface of the fabric being embossed, when the air embossing system is in operation. In other words, the monolithic air redirecting elements provided in the embodiment illustrated in FIGs. 6f and 6g, and in other embodiments of the air lances described below, increase the fractional amount the stream of air directed through apertures or openings in the stencil of the air embossing system that is oriented in a

direction essentially perpendicular to the embossable surface of the fabric being embossed, when the air lance is in operation, when compared to the fractional amount of a stream of air directed through the openings in the stencil essentially perpendicular to the embossable surface of the fabric by an essentially equivalent air lance, but without the air redirecting element included therein.

Air lance 500 illustrated in FIGS. 7a-7e represents an alternative embodiment for providing certain of the benefits of air lance 220, discussed above in the context of FIG. 5a, and air lance 700, discussed below in the context of FIGS. 8a-8g. Specifically, air lance 500 is configured to provide a nozzle that can be positioned in close proximity to the internal surface of an embossing stencil and in close proximity to the surface of an embossable fabric. Air lance 500, when installed in air embossing system 109 similarly to the installation shown previously for air lance 220 in FIG. 5a, can be positioned with respect to interior surface portion 218 of stencil 128 (see FIG. 5a) so that its nozzle 502 is positioned from surface portion 218 at a distance that is less than distance 220 defining the overhang distance between the internal surface of the stencil and the internal surface of the embossing cylinder in flange region 130 (or the internal surface of aperture 148 of air embossing system 109, whichever creates a larger overhang distance 220). Nozzle 502 may be positioned at distances with respect to surface portion 218 that are similar to the preferred distances separating surface 218 and nozzle 216 of air lance 210 described above in the context of FIG. 5a, or the nozzle may be positioned in direct contact with inner surface portion 218 of the stencil at a zero separation distance in some embodiments.

Air lance 500 comprises a main body portion 504 including, in preferred embodiments, a single, slit-shaped nozzle 502 extending along a substantial fraction of the length of main body portion 504 and defining nozzle region 506. In alternative, less preferred, embodiments, the air lance may include a plurality of nozzles comprising individual holes instead of a single, slit-shaped nozzle. As discussed above for air lances 210 and 300, the nozzle region preferably extends across essentially the entire width of embossing cylinder stencil region 128 and embossable surface 113 of fabric 111, when the air lance is positioned within air embossing system 109 for operation.

Nozzle 502, in preferred embodiments, has a characteristic orifice dimension, defined by width 508 of the slit, that is less than about 0.2 inch and preferably falls within the preferred range discussed above for nozzle 216 of air lance 210. In the illustrated embodiment, slit width 508 is essentially constant along the entire length of nozzle region 506. In alternative embodiments, slit 502 may be tapered so that slit width 508 changes along the length of the nozzle. For example, in some such embodiments, slit 502 may be wider at the end of the nozzle nearest offset inlet tube 510 than at the end nearest offset mounting shaft 512. Such a configuration, especially for nozzles having relatively large characteristic orifice dimensions, may improve the uniformity of air flow velocity along the length of nozzle region 506.

Referring now to FIG. 7b, a side view of air lance 500 shows that inlet tube 510 and mounting shaft 512 have centers that are offset with respect to longitudinal axis 320 of the air lance. Inlet tube 510 also has a smaller diameter than main body portion 504 of air lance 500. Providing a reduced diameter inlet tube, which is offset with respect to longitudinal axis 320, enables the provision of an overhang region 514, which enables nozzle 502 to be positioned within embossing cylinder 112 so that it is able to be placed in a desirably close proximity to or in contact with the internal surface portion 218 of stencil 128 (see FIGs. 5a and 5b). For embossing cylinders and embossing systems having the dimensions and configuration described previously in the context of FIGs. 4 and 5, air lance 500 can be configured, as in the illustrated embodiment, with a main body portion 504 having an outside diameter of about $5\frac{1}{4}$ inches (or somewhat smaller than $5\frac{1}{4}$ inches so as to permit clearance of optional stencil stabilizers 550 when in their fully collapsed configuration as explained below), and having an offset inlet tube, as illustrated, having an outside diameter of no more than about 2.8 inches. This configuration provides an overhang distance 514 of at least about 1.2 inches, sufficient to completely traverse distance 220 shown above in FIG. 5a.

It is to be understood that for embodiments of an air embossing system utilizing an air lance similar to air lance 500, inlet tube 510 should be of sufficient length so that upstream surface 518 of main body portion 504 is positioned within embossing cylinder 112 so that it is completely contained within the large internal diameter portion of the embossing cylinder, when configured for operation. Also, air lance inlet support arm

150 of air embossing system 109 (see FIG. 4a) should be configured so that air lance inlet cradle 154 is shaped and sized to conform to the smaller size of inlet tube 510 of air lance 500.

5 A cross-sectional view of a preferred embodiment of air lance 500 is shown in FIGs. 7c, 7d, and 7e. Preferably, in order to maintain a constant characteristic orifice dimension upon pressurization of air lance 500 during operation, main body portion 504 is stabilized by one or more support struts 226, as described above in the context of air lance 210 in FIG. 5a. In addition, preferred embodiments of air lance 500, the lance also includes a monolithic air redirecting element or baffle 520 that can be essentially similar
10 in configuration and function to air redirecting element 350 described above in the context of FIGs. 6f and 6g.

For embodiments where nozzle 502 is positioned in close proximity to the internal surface of the embossing stencil (e.g., at distances of less than about 0.75 inch) or in direct contact with the inner surface of the stencil, it is preferred that the thickness
15 of the walls or dividers 522 of structure 520 separating each of the cells or channels 524 be less than the characteristic orifice dimension of nozzle 502. It has been found, in the context of the present invention, that if wall thickness 522 exceeds the characteristic orifice dimension of nozzle 502 that undesirable, visually apparent artifacts may be created in the embossed pattern of a fabric embossed using the air lance. Accordingly, in
20 preferred embodiments, it is preferred that the thickness of walls 522 of structure 520 be less than, and preferably substantially less than, the characteristic orifice dimension of nozzle 502. In the most preferred embodiment, the thickness of walls 522 is preferably minimized such that it is as small as possible, while maintaining the structural integrity of baffle 520 in operation. For aluminum honeycomb-like structures, such as baffle 800
25 shown in FIG. 9, it is preferred that the thickness of the walls not exceed about 0.002 inch. In other embodiments, the wall thickness of walls forming a monolithic baffle comprising an aluminum honeycomb-like structure may be as small as about 0.001 inch or less.

Air lance 500 illustrated in FIG. 7a-7e also includes a plurality of optional stencil
30 stabilizer components 550 attached to the conduit comprising main body portion 504 of the air lance. In the illustrated embodiment, stencil stabilizing components 550 are

positioned on both the upstream side and the downstream side of nozzle 502 on main body portion 504. The structure and position of stencil stabilizer components 550 is most clearly illustrated in FIGs. 7a, 7b, and 7e. As seen most clearly in FIG. 7b, stencil stabilizing components 550 include a base portion 553, which is attached to main body portion 504, and further include extending away from base portion 553 and main body portion 504 stencil contacting elements 554, aligned essentially parallel to the longitudinal axis 320 of air lance 500. Stencil contacting elements 554 of stencil stabilizer components 550 are preferably coated, as described previously, with a friction-reducing coating to prevent damage to the interior surface of the stencil during rotation of the stencil. Stencil contacting elements 554 are supported by and spaced from cylindrical bases 553 via shafts 555. Preferably, as illustrated in FIGs. 7b and 7e, base components 553 are sized and positioned such that end surfaces 559 do not extend substantially beyond line 556 lying within the plane of nozzle 502.

As illustrated in FIG. 7e, stencil contacting elements 554 and connecting shafts 555 are biased by spring 557 within mounting portion 553 of stencil stabilizers 550 tending to force stencil contacting elements 554 in a direction extending away from main body 504. Accordingly, stencil stabilizers 550 are partially collapsible, by applying a force to stencil contacting elements 554 directed towards the main body of the air lance, enabling the distance separating nozzle 502 from the inner surface of an embossing stencil into which air lance 500 is mounted for operation to be adjustable, while maintaining stencil contacting elements 554 in contact with the inner surface of the embossing stencil. Spring actuated stencil stabilizers 550 thus enable air lance 500 to be positioned within embossing cylinder 112 during operation of the air embossing system 109 so that nozzle 502 can be separated from the inner surface portion 218 of the embossing stencil 128 by any distance less than or equal to distance 558, while maintaining stencil contacting elements 554 in contact with the inner surface of the embossing stencil during rotation of the stencil (see FIG. 5). Accordingly, by utilizing adjustable stencil stabilizers 550, the distance separating nozzle 502 and the inner surface portion 218 of the stencil can be varied from essentially zero to distance 558 while providing a stabilizing force to the inner surface of the stencil sufficient to reduce variations in the distance separating the embossable surface of the fabric and the portion

of the fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil.

Stencil contacting elements 554 are separated from longitudinal axis 320 of air lance 500 by a distance that is adjustable via applying a force to air lance 500 tending to
5 move nozzle 502 closer to the inner surface of the embossing stencil when the air lance is mounted in the system so that stencil contacting elements 554 are in contact with the inner surface of the stencil. Because the degree of force provided by spring 557 tending to extend stencil contacting elements 554 away from main body component 504 is directly proportional to the extent to which spring 557 is collapsed, the level of force
10 applied to the inner surface 223 of stencil 128 will therefore be inversely proportional to the distance separating nozzle 502 from inner surface portion 218 of the stencil, when stencil contacting elements 554 are in contact with the inner surface of the stencil.

In alternative embodiments, spring 557 may be replaced by any other element able to apply a restoring force tending to extend stencil contacting elements 554 from
15 main body component 504 of the air lance 500 when compressed, which are known to those of ordinary skill in the art, for example, including, but not limited to, air bladders, various elastomeric components, etc. In yet other embodiments, springs 557 may be replaced by hydraulic or pneumatic pistons, mechanical displacement actuators, or other such components known in the art, which are able to controllably extend, retract, and
20 position stencil contacting elements 554 at a desired, predetermined distance with respect to main body component 504 of air lance 500. For such embodiments, the degree of extension of stencil contacting elements 554 could be manually and/or automatically adjustable during operation to also provide a desired predetermined level of force applied to the embossing stencil created by elements 554 in contact with the inner surface of the
25 embossing stencil for any desired separation distance. The level of force, for such embodiments, can, therefore, be adjusted, independently of the separation distance between the nozzle and the inner surface of the stencil, to a selected desired value for any desired separation distance between nozzle 502 and the inner surface of the embossing stencil.

30 FIGs. 8a-8g illustrate a preferred embodiment of an air lance 700 essentially similar in configuration to air lance 210 described previously in the context of FIG. 5a-

5b, except including a nozzle forming component 702 configured to contain one or more air redirecting elements or baffles therein and including an optional stencil stabilizer 900 comprising a collapsible, hinged doctor blade thereon. Elements which are essentially identical to those described previously for air lance 210 are labeled in FIGs. 8a-8g using the same figure labels. Similarly, and as with air lance 500 of FIGs. 7a-7e, components essentially equivalent to or similar to those illustrated and discussed in the context of air lance 300 shown in FIGs. 6a-6g are also labeled with the same figure labels as those used in FIGs. 6a-6g.

Referring to FIG. 8a, nozzle forming component 702 includes, machined therein, a nozzle slit 216, which extends along the majority of its length except for regions 703 and 705 at its upstream and downstream ends respectively. Nozzle forming component 702 preferably is sized so that it projects beyond an outermost surface 707 (see FIG. 8b) of main body portion 212 by a distance 709 that is equal to or greater than distance 220 shown and discussed above in the context of FIG. 5a, thus, enabling nozzle 216 to be positioned as close to surface portion 218 of stencil 128 as is desired during operation or in contact with surface portion 218 of stencil 128, if desired.

Nozzle slit 216 can be formed in nozzle forming component 702 by a variety of conventional machining methods, as would be apparent to those of ordinary skill in the art, including, but not limited to, cutting with a blade, water jet cutting, laser cutting, etc. For embodiments involving extremely narrow slits, for example nozzles having a characteristic orifice dimension less than about 0.02 inch, nozzle forming component 702, instead of being formed of a unitary, monolithic structure having slit 216 machined therein, may instead comprise two separable components, each separable component being mounted on opposite sides of outlet opening 224 of main body portion 212 (see FIG. 8c) such that they are positioned adjacent and separated from each other on the main body portion, for example by the use of very thin shim(s) or spacer, so that the distance between the adjacent facing surfaces of the two components defines a slit forming a nozzle having a characteristic nozzle orifice dimension essentially equal to the width of the shim(s) or spacers utilized to separate the two subcomponents of the nozzle forming component during mounting to the main body portion (see also the previous discussion related to FIG. 5c). In addition, as discussed previously for the prior air

lances provided according to the invention, air lance 700 includes a nozzle region 704, having a length defined by the length of nozzle 216, which nozzle region extends across essentially the entire width of stencil 128 and embossable surface 113 of embossable fabric 111, when air lance 700 is positioned within air embossing system 109 for
5 operation.

FIGs. 8c and 8e present cross-sectional views of air lance 700 illustrating one preferred embodiment for providing an air redirecting element 800 within nozzle forming component 702. Nozzle forming component 702 includes a hollow chamber 708 therein for containing air directing element 800 and further includes, downstream of
10 hollow chamber 708, a tapered chamber 710, which serves to further direct and focus air flow within the nozzle forming component toward slit nozzle 216. Main body portion 212 includes an outlet opening 224 comprising an elongated slot disposed along the length of the main body portion essentially coextensive with and parallel to slit nozzle 216. Hollow chamber 708 and tapered chamber 710 extend along the length of nozzle
15 forming component 702 so that they are essentially coextensive with slit nozzle 216 and elongated slot 224 in main body portion 212.

Air redirecting element 800, in the illustrated embodiment, comprises a monolithic aluminum honeycomb-like structure, shown in more detail in FIG. 9 and discussed above in the context of FIGs. 6 and 7. As shown most clearly in FIG. 8d and
20 FIGs. 9a and 9b, air redirecting element 800 comprises a plurality of hexagonally shaped cells 802 with a characteristic dimension 804 and a height 806. In one embodiment, air redirecting element 800 comprises an aluminum honeycomb structure including a plurality of hexagonally shaped cells 802 each having a characteristic dimension of about 1/8 inch and a height of about 1/2 inch. Preferably, as discussed previously with respect
25 to monolithic air redirecting elements 520 and 350, the thickness of the walls 808 of the structure separating cells 802 is less than the characteristic orifice dimension of nozzle 216. In one illustrative embodiment, the thickness of walls 808 is about 0.002 inch, and in another illustrative embodiment, the thickness is about 0.001 inch.

Referring to FIG. 8c, hollow chamber 708 preferably is sized and shaped to
30 snugly accommodate monolithic air redirecting element 800 in order to prevent vibration and motion of the air redirecting element during operation of the air lance. For

added stability, in some embodiments, air redirecting element 800 may be welded, or otherwise affixed to one or more internal surfaces of hollow chamber 708 in order to further prevent motion of the element during operation. As illustrated in FIG. 8c, hollow chamber 708 is preferably located within nozzle forming component 706 so that air
5 redirecting element 800 is positioned as far upstream of nozzle 216 as possible.

Positioning air redirecting element 800 as far upstream as possible from nozzle 216 further acts to reduce potential artifacts within an embossed pattern of a fabric, which artifacts may be due to the presence of walls 808 separating the cells 802 of the air redirecting element.

10 Air redirecting element 800 is preferably installed in hollow chamber 708 so that channels 802 formed by the cells of the structure of the monolithic air redirecting element are aligned so that they are essentially perpendicular to longitudinal axis 320 of main body portion 212. In operation, air redirecting element 800 serves to redirect and deflect air flow within main body portion 212 so that a greater fraction of air flow
15 emitted from nozzle 216 is directed essentially perpendicularly to longitudinal axis 320 and embossable surface 113 of fabric 111, as compared to that emitted from an essentially equivalent air lance but without air redirecting component 800 installed therein. It should be emphasized, that for embodiments involving air lances utilizing nozzle forming components (e.g., air lance 210 shown in FIG. 5 and air lance 700 shown
20 in FIG. 8) utilization of an air redirecting element is optional and may not be required, under some operating conditions, in order to yield desirable embossing performance, especially, for example, when using air lances with nozzles having a very small characteristic orifice dimension, for example, less than about 0.1 inch.

Also included on air lance 700 illustrated in FIGs. 8a-8e is one embodiment of an
25 optional stencil stabilizer 900 constructed and positioned on the air lance to apply a force to the embossing stencil of the air embossing system in which the air lance is installed during operation of the system in order to reduce variations in the distance separating the embossable surface of the fabric being embossed and the portion of the fabric-facing surface of the stencil that is directly adjacent thereto during rotation of the stencil.

30 Stencil stabilizer 900 comprises a spring-biased articulated arm assemblies 902 connected at its stencil-contacting end to a doctor blade 904 which, in the illustrated

embodiment, comprises an elongated rod, bar, blade, etc. positioned parallel to and essentially coextensive with nozzle 216 of nozzle forming component 702. Doctor blade 904 is preferably coated, at least on its stencil-contacting surface 906, with a material, such as PTFE, effective to reduce friction caused by contact and relative motion between the stencil-contacting surface 906 and the inner surface of the stencil during operation.

Reference is now made to FIG. 8e, which most clearly shows the articulated arm assemblies 902 of stencil stabilizer 900. In the illustrated embodiment, three such articulated arm assemblies are included to support and position the doctor blade 904; however, more or fewer such structures may be utilized depending on the overall length of doctor blade 904, the force with which doctor blade is engaged with the inner surface of the stencil during operation, etc., as would be apparent to those of ordinary skill in the art. Stencil stabilizer 900 can be connected to air lance 700 via attachment to nozzle forming component 702. As illustrated, articulated arm assembly 902 includes a first extension arm 908 connected to nozzle forming component 702 via flange 910 and bolt 228. Arm 908 is pivotally connected at its other end 912 to arm 914, which includes, or is connected to, at end 916 to doctor blade 904. In the illustrated embodiment a spring 918 is connected to both arm 908 and 914 and is constructed to provide a biasing force tending to pivot arm 914 with respect to 908 in the direction of arrow 920 thus, similar to stencil stabilizers 550 illustrated in FIGs. 7a-7e, stencil stabilizer 900 is constructed so that, when air lance 700 is installed in an operable configuration in air embossing system 109 the distance separating the nozzle 216 from the inner surface portion 218 of the stencil 128 in which the air lance is installed can be adjustable, while maintaining doctor blade 904 in contact with the inner surface of the stencil to provide a force thereon to stabilize the rotation of the stencil.

Also, similarly to stencil stabilizers 550, the level of force applied to the inner surface of the stencil, when doctor blade 904 is in contact with the inner surface of the stencil, is inversely proportional to the distance separating nozzle 216 from the inner surface portion 218 of the stencil due to the increase in restoring force created by spring 918 upon the movement of doctor blade 904 closer to longitudinal axis 320 of the air lance in the direction of arrow 922.

Stencil stabilizer 900 is configured to contact the inner surface of the embossing stencil in which air lance 700 is installed during operation with nozzle 216 positioned at any desired separation distance from the inner surface portion 218 of the stencil, ranging from a zero separation distance with nozzle 216 in direct contact with inner surface portion 218 of the stencil (i.e., when stencil stabilizer 900 is in a collapsed configuration) to a maximum separation distance 924 with stencil stabilizer 900 in its fully extended position. During installation of air lance 700 into the air embossing system, stencil stabilizer 900 can be positioned in its fully collapsed configuration to minimize the overall diameter of the air lance with the stencil stabilizer attached thereto. In order to further reduce the overall diameter of air lance 700 with stencil stabilizer 900 in a fully collapsed position, it is contemplated that arm 908 may be further articulated to include an additional pivot point(s) therein enabling assembly 902 to be rotated towards main body portion 212 such that pivot point 912 lies against or in close proximity to surface 926 of nozzle forming component 702.

While, in the illustrated embodiment, a spring is illustrated as providing a biasing force, in alternative embodiments, as discussed above in the context of stencil stabilizers 550, a variety of other known mechanisms and/or materials for providing a restoring force tending to extend doctor blade 904 may be utilized. In addition, as described above for stencil stabilizers 550, biasing means 918 can, in alternative embodiments, be replaced with a mechanical, pneumatic, hydraulic, etc., actuating mechanism configured to controllably adjust the position of doctor blade 904 with respect to longitudinal axis 320 and nozzle 216 in order to controllably adjust the level of force applied to the inner surface of the embossing stencil when the air lance is configured for operation in the system and positioned with nozzle 216 separated from the inner surface of the stencil by any desired distance ranging from contact of the nozzle with the inner surface of the stencil to a maximum separation distance (e.g., distance 924 shown in FIG. 8e) dictated by the overall structure of the stencil stabilizer and range of motion of the controllable positioning actuator.

An alternative embodiment of air lance 700 providing a plurality of air redirecting elements and not including optional hinged doctor blade stencil stabilizer 900 is illustrated in the cross sectional views of FIGs. 8f and 8g. Nozzle forming component

includes a hollow chamber 758 therein that contains a plurality of air redirecting elements 760 comprising a series of baffling vanes disposed along essentially the entire length of chamber 758 and spaced apart from each other at regular intervals defined by distance 762. Vanes 760 are preferably oriented within chamber 758 so that an air
5 deflecting surface 764 of each vane is essentially perpendicular to longitudinal axis 320 of main body 212. As shown in FIG. 8g, nozzle forming component 756 preferably includes a plurality of spaced grooves 766 in side wall 768 of chamber 758 for positioning and securing the edges of vanes 760 therein. Grooves 766 should have a width that is essentially equal to or slightly less than thickness 770 of vanes 760, such
10 that when inserted into grooves 766 vanes 760 are essentially immobilized during operation of the air lance. In alternative embodiments, nozzle forming component 756 may include a chamber not including vane-mounting grooves therein, and the vanes may instead be secured to the side wall of the chamber by welding or other affixing means, as would be apparent to those of ordinary skill in the art.

15 In preferred embodiments, thickness 770 of each of vanes 760, as measured in a direction essentially parallel to longitudinal axis 320 of main body portion 212, is less than the characteristic orifice dimension of slit nozzle 216. In one illustrative embodiment, thickness 770 of vanes 760 is less than about 0.02 inch, and in another illustrative embodiment is less than about 0.01 inch.

20 It is also preferred that the height 772 of each vane 760, as measured along a direction that is essentially perpendicular to longitudinal axis 320 of main body portion 212, exceeds the distance 762 between each of vane 760 by a factor of at least about 2, and, in more preferred embodiments exceeds the distance by a factor of at least about 3, and in the most preferred embodiments exceeds the distance by a factor of at least about
25 4. While several embodiments of air redirecting elements for redirecting air flowing within an air lance have been illustrated herein, those of ordinary skill in the art will readily envision a variety of other means and structures for providing air redirecting elements to perform the functions described herein, and each of such variations or modifications are deemed to be within the scope of the present invention.

30 While the previously illustrated and described stencil stabilizers have comprised components of the air lance or components connected to the air lance, the scope of the

present invention is not so limited. For example, FIGs. 10a and 10b illustrate an alternative embodiment of air embossing system 109 including a stencil stabilizer 1002, which is not connected to any air lance installed in the system during operation. In the illustrated embodiment, a doctor blade 1002 (seen most clearly in the insert of FIG. 10a) is supported at its ends by air lance inlet support arm 150 and air lance mounting shaft support arm 152. Stencil stabilizer 1002 comprises a first end 1006 supported in aperture 1000 of air lance inlet support arm 150. Stencil stabilizer 1002 includes a second end 1008, which is inserted at its end in aperture 1004 of mounting shaft support arm 152. End pieces 1006 and 1008 of stencil stabilizer 1002 are connected via connecting pieces 1010 and 1012 to doctor blade 1014, whose outer surface 1015 is positioned in contact with the inner surface of embossing stencil 128 during operation to stabilize the rotation of the stencil. End pieces 1006 and 1008 have a length that is sufficient to span reduced diameter stencil flange region 130 on each end of rotating embossing cylinder 112. Connecting arms 1010 and 1012 preferably have a length that is selected to enable doctor blade 1014 to come into direct contact with the inner surface of stencil 128 when inlet support arm 150 and outlet support arm 152 are positioned to provide a desirable spacing between the nozzle of the air lance and the inner surface of embossing stencil 128.

In some embodiments, as illustrated, apertures 1000 and 1004 may comprise elongated slots enabling the vertical position of stencil stabilizer 1002 to be adjusted as indicated by arrows 1016. Such a configuration enables the vertical position of doctor blade 1014 to be adjustable to accommodate a range of vertical positions of inlet support arm 150 and outlet support arm 152 corresponding to a variety of desired separation distances between the nozzle of an installed air lance and the inner surface of stencil 128 during operation. In some embodiments, stencil stabilizer 1002 can be biased by a spring or other mechanism in a direction 1018 tending to engage doctor blade 1014 with the inner surface of stencil 128. In yet other embodiments, the vertical position of stencil stabilizer 1002 can be manually and/or automatically controlled by including a mechanical, hydraulic, etc., actuating mechanism able to controllably adjust the vertical position of stencil stabilizer 1002 with respect to support arms 150 and 152 during operation of the system.

An advantage of each of the previously illustrated stencil stabilizing mechanisms is that essentially no portion of any of the previously described stencil stabilizers intercepts or obstructs the stream of air emitted from the nozzle of the air lance during rotation of the stencil and operation of the system. Accordingly, the stencil stabilizers previously described do not tend to create undesired artifacts in the embossed pattern due to obstruction of the fabric-embossing air stream. Such interception of the air stream by the stencil stabilizers is avoided in the previously described embodiments by constructing and positioning the stencil stabilizer with respect to embossing stencil 128 such that the stencil stabilizer does not rotate during rotation of the stencil. However, in alternative embodiments, where artifacts caused by interception of the air stream by the stencil stabilizer are not detrimental to the appearance of the embossed fabric or where such "artifacts" may form part of a desired embossed pattern, the stencil stabilizer can be configured so that it rotates with the stencil and crosses the path of the air stream emitted from the nozzle of the air lance installed in the system. In one such embodiment (not shown), the stencil stabilizers can comprise one or more substantially rigid bars attached to the inner surface of stencil 128, or positioned in engaging contact with the inner surface of stencil 128, and extending either longitudinally between reduced diameter stencil flanges 130 or extending circumferentially around at least a portion of the inner circumference of stencil 128.

In addition, in some alternative embodiments, stencil stabilizers can be configured to apply a force to the outside, fabric facing surface of the stencil to stabilization instead of, or in addition to, applying a force to the inside surface of the stencil as shown and discussed previously. Also, certain alternative embodiments of a stencil stabilizer, within the scope of the invention, can be configured to apply a force to the stencil for stabilization of its rotation as discussed above without contacting any surface of the stencil. Such alternative stencil stabilizers can, for example, create a tension within the stencil by applying a force to one or both ends of the cylindrical stencil either directed inwardly, towards the center point of the stencil, so as to slightly reduce the unstressed length of the stencil and create a hoop stress in the stencil by expansion of its unstressed circumference, or directed outwardly, away from the center point of the stencil, so as to slightly increase the unstressed length of the stencil and

create tension in the stencil by reduction of its unstressed circumference. In yet other alternative embodiments within the scope of the invention, a force may be applied to the stencil by a stencil stabilizer(s) without contact between the stabilizer(s) and the inner or outer surface of the stencil by configuring the stabilizer(s) to apply a force to the stencil by utilizing a magnetic and/or electric field.

While several embodiments of stencil stabilizing components for stabilizing the rotation of the air embossing stencil during rotation to reduce variations in the distance separating the embossable surface of the fabric being air embossed and the portion of the fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil have been illustrated herein, those of ordinary skill in the art will readily envision a variety of other means and structures for providing stencil stabilizers to perform the functions described herein, and each of such variations or modifications are deemed to be within the scope of the present invention.

More generally, those skilled in the art would readily appreciate that all parameters and configurations described herein are meant to be exemplary and that actual parameters and configurations will depend upon the specific application for which the systems and methods of the present invention are used. Those skilled in the art will recognize, or be able to ascertain using no more than routine experimentation, many equivalents to the specific embodiments of the invention described herein. It is, therefore, to be understood that the foregoing embodiments are presented by way of example only and that, within the scope of the appended claims and equivalents thereto, the invention may be practiced otherwise than as specifically described. The present invention is directed to each individual feature, system, or method described herein. In addition, any combination of two or more such features, systems, or methods, provided that such features, systems, or methods are not mutually inconsistent, is included within the scope of the present invention. In the claims, all transitional phrases or phrases of inclusion, such as "comprising," "including," "carrying," "having," "containing," and the like are to be understood to be open-ended, i.e. to mean "including but not limited to." Only the transitional phrases or phrases of inclusion "consisting of" and "consisting essentially of" are to be interpreted as closed or semi-closed phrases, respectively.

CLAIMS

1. A system for air embossing a surface of an embossable fabric comprising:
a cylindrical stencil having an inside surface and a fabric-facing surface; and
at least one stencil stabilizer constructed and positioned to apply a force to the
5 stencil during operation of the system sufficient to reduce variations in a distance
separating the embossable surface of the fabric and a portion of the fabric-facing surface
of the stencil directly adjacent thereto during rotation of the stencil.
2. The system of claim 1, wherein the at least one stencil stabilizer is constructed
10 and positioned to apply a force to the stencil during operation of the system that is
sufficient to essentially eliminate variations in a distance separating the embossable
surface of the fabric and a portion of the fabric-facing surface of the stencil directly
adjacent thereto during rotation of the stencil.
- 15 3. The system of claim 1, wherein the at least one stencil stabilizer is constructed
and positioned so that at least a portion thereof is in contact with a surface of the stencil.
4. The system of claim 3, wherein the at least one stencil stabilizer is constructed
and positioned so that at least a portion thereof is in essentially continuous contact with a
20 surface of the stencil during the entirety of its rotation.
5. The system of claim 3, wherein the force applied to the stencil by the at least one
stencil stabilizer is sufficient to create a tension in the stencil.
- 25 6. The system of claim 5, wherein the force applied to the stencil by the at least one
stencil stabilizer is sufficient to distort the shape of the stencil during a least a portion of
the rotation of the stencil.
7. The system of claim 3, wherein at least a portion of the stencil stabilizer contacts
30 an inner surface of the stencil.

8. The system of claim 7, further comprising an air lance including at least one nozzle thereon, the nozzle being constructed and positioned to direct a stream of air through at least one opening in the stencil and onto the embossable surface of the fabric.

5 9. The system of claim 8, wherein no portion of the stencil stabilizer intercepts a stream of air emitted from the nozzle during rotation of the stencil.

10. The system of claim 9, wherein the stencil stabilizer does not rotate during rotation of the stencil.

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11. The system of claim 10, wherein the stencil stabilizer is connected to the air lance.

15

12. The system of claim 11, wherein the stencil stabilizer comprises at least a portion of a nozzle forming component of the air lance.

20

13. The system of claim 11, wherein at least a portion of the stencil stabilizer is positioned at a zero separation distance in contact with the inner surface of the stencil and wherein a distance separating the nozzle from the inner surface of the stencil is equal to or exceeds the zero separation distance.

14. The system of claim 13, wherein the distance separating the nozzle from the inner surface of the stencil is adjustable.

25

15. The system of claim 14, wherein the level of force applied to the inner surface of the stencil is inversely proportional to the distance separating the nozzle from the inner surface of the stencil.

30

16. The system of claim 11, wherein at least a portion of the stencil stabilizer contacts the inner surface of the stencil at location that is upstream of the nozzle.

17. The system of claim 16, wherein the system includes at least two stencil stabilizers.

18. The system of claim 17, wherein at least a portion of a first stencil stabilizer
5 contacts the inner surface of the stencil at location that is upstream of the nozzle and
wherein at least a portion of a second stencil stabilizer contacts the inner surface of the
stencil at location that is downstream of the nozzle.

19. The system of claim 8, wherein a maximum first distance separating the
10 embossable surface of the fabric from a portion of the fabric facing surface of the stencil
directly adjacent thereto, without the force applied to the stencil by the stencil stabilizer,
exceeds a maximum second distance separating the embossable surface of the fabric
from the portion of the fabric facing surface of the stencil directly adjacent thereto when
the system is configured for operation with the force applied to the stencil by the stencil
15 stabilizer.

20. The system of claim 19, wherein the first distance exceeds the second distance
by at least about 0.001 inch.

20 21. The system of claim 20, wherein the first distance exceeds the second distance
by at least about 0.005 inch.

22. The system of claim 21, wherein the first distance exceeds the second distance
by at least about 0.01 inch.
25

23. The system of claim 22, wherein the first distance exceeds the second distance
by at least about 0.05 inch.

24. The system of claim 23, wherein the first distance exceeds the second distance
30 by at least about 0.1 inch.

25. A system for air embossing a surface of an embossable fabric comprising:
a cylindrical stencil having an inner surface and a fabric-facing surface; and
an air lance including at least one nozzle thereon, the nozzle being constructed
and positioned to direct a stream of air through at least one opening in the stencil and
5 onto the embossable surface of the fabric, with
the nozzle being positioned so that at least a portion thereof is in contact with the
inner surface of the stencil when the system is in operation.
26. The system of claim 25, wherein a portion of the air lance forming the nozzle that
10 is in contact with the inner surface of the stencil applies a force to the inner surface of the
stencil sufficient to reduce variations in a distance separating the embossable surface of
the fabric and a portion of the fabric-facing surface of the stencil directly adjacent
thereto.
27. The system of claim 26, wherein the portion of the air lance forming the nozzle
15 that is in contact with the inner surface of the stencil applies a force to the inner surface
of the stencil sufficient to essentially eliminate variations in a distance separating the
embossable surface of the fabric and a portion of the fabric-facing surface of the stencil
directly adjacent thereto.
28. The system of claim 25, wherein the air lance includes a nozzle forming
20 component thereon, which nozzle forming component includes at least one orifice
forming the at least one nozzle, at least a portion of which is in contact with the inner
surface of the stencil.
29. The system of claim 26, wherein a maximum first distance separating the
25 embossable surface of the fabric from a portion of the fabric facing surface of the stencil
directly adjacent thereto, without the force applied to the stencil by the stencil stabilizer,
exceeds a second distance separating the embossable surface of the fabric from the
30 portion of the fabric facing surface of the stencil directly adjacent thereto when the

system is configured for operation with the force applied to the stencil by the stencil stabilizer.

30. An air lance for directing air through a rotating stencil and onto a surface of an embossable fabric for air embossing the fabric comprising:

a conduit having at least one inlet opening therein;

at least one orifice forming at least one nozzle, the nozzle being constructed and positioned to direct a stream of air through the stencil and onto the embossable surface of the fabric, when the air lance is in operation; and

at least one stencil stabilizer connected to and extending from the conduit, the stabilizer being constructed and positioned to contact an inner surface of the stencil during operation of the system, said contact creating a force on the inner surface that is sufficient to reduce variations in a distance separating the embossable surface of the fabric and a portion of a fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil, the stabilizer being further constructed and positioned so that at least a portion of the stencil stabilizer extends, when the stabilizer is not in contact with the inner surface, to a location separated from the longitudinal central axis of the conduit by a first distance, said first distance exceeding a second distance separating the nozzle from the longitudinal central axis of the conduit.

31. The air lance of claim 30, wherein the at least one stabilizer is constructed and positioned to contact the inner surface of the stencil during operation of the system, said contact creating a force on the inner surface that is sufficient to essentially eliminate variations in a distance separating the embossable surface of the fabric and a portion of the fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil.

32. The air lance of claim 30, wherein the stencil stabilizer comprises at least a portion of a nozzle forming component of the air lance, the nozzle forming component including the at least one orifice forming the at least one nozzle therein.

33. The air lance of claim 32, wherein the nozzle forming component comprises a first and a second separable component, with the first and second separable components being mounted on opposite sides of an outlet opening disposed in the conduit such that they are positioned adjacent to and separated from each other on the conduit so that the distance between adjacent facing surfaces of the first and second separable components defines a slit forming the nozzle.

34. The air lance of claim 33, wherein the stencil stabilizer comprises at least a portion of the first separable component and wherein a maximum distance separating the first separable component from the longitudinal central axis of the conduit exceeds a maximum distance separating the second separable component from the longitudinal central axis of the conduit.

35. The air lance of claim 34, wherein the first separable component is mounted on a side of the outlet opening that is upstream of the nozzle when the air lance is in operation.

36. The air lance of claim 30, wherein a distance separating at least a portion of the at least one stencil stabilizer from the longitudinal central axis of the conduit is adjustable, when the stabilizer is positioned in contact with the inner surface of the stencil.

37. In a system for air embossing an embossable fabric by directing a stream of air through at least one opening in a rotating cylindrical stencil and onto an embossable surface of the fabric, means for reducing variations in a distance separating the embossable surface of the fabric and a portion of a fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil.

38. A method for stabilizing the rotation of a cylindrical stencil of an embossing system for air embossing a surface of an embossable fabric comprising:

positioning a portion of a fabric facing surface of the stencil directly adjacent to the embossable surface of the fabric and at a first distance from the embossable surface of the fabric;

positioning at least a portion of at least one stencil stabilizer at least partially
5 disposed within the cylindrical stencil so that the portion is in direct contact with a surface of the stencil; and
rotating the stencil.

39. The method of claim 38, further comprising the steps of:
10 directing a stream of air onto the inner surface of the stencil;
passing the stream of air through at least one opening in the stencil; and
impinging the stream of air onto the embossable surface of the fabric.

40. The method of claim 39, wherein during the directing step the stream of air is
15 emitted from at least one nozzle of an air lance that is at least partially disposed within the stencil, the nozzle being positioned in contact with the inner surface of the stencil.

41. The method of claim 40, wherein during the impinging step a distance separating the embossable surface of the fabric and a portion of a fabric facing surface of the stencil
20 that is positioned directly adjacent thereto is maintained essentially constant during rotation of the stencil.

42. A method for stabilizing the rotation of a cylindrical stencil of an embossing system for air embossing a surface of an embossable fabric comprising:
25 applying a force to the stencil sufficient to reduce variations in a distance separating the embossable surface of the fabric and a portion of a fabric-facing surface of the stencil directly adjacent thereto during rotation of the stencil; and
rotating the stencil.

30 43. The method of claim 42, wherein the applying step comprises the steps of:

positioning a portion of the fabric-facing surface of the stencil at a first distance from the embossable surface of the fabric;

positioning at least a portion of at least one stencil stabilizer at least partially disposed within the cylindrical stencil so that the portion is in direct contact with an inner
5 surface of the stencil.

44. The method of claim 42, wherein the force applied to the stencil during the applying step is sufficient to essentially eliminate variations in the distance separating the embossable surface of the fabric and the portion of the fabric-facing surface of the
10 stencil directly adjacent thereto during rotation of the stencil.

45. A system for air embossing a fabric comprising:
a cylindrical stencil with a plurality of openings formed therein;
means for rotating the stencil about a rotational axis that is parallel to or co-linear
15 with the longitudinal axis of the stencil;
means for supporting a fabric having an embossable surface for movement in a direction forming a non-zero angle with respect to the longitudinal axis of said stencil;
means for directing air from within the cylindrical stencil through the openings and towards the embossable surface; and
20 at least one stencil stabilizer constructed and positioned to engage an inner surface of the cylindrical stencil to reduce variations in a distance separating the means for supporting the fabric and a portion of an outer surface of the stencil directly adjacent to the embossable surface of the fabric as the stencil rotates.

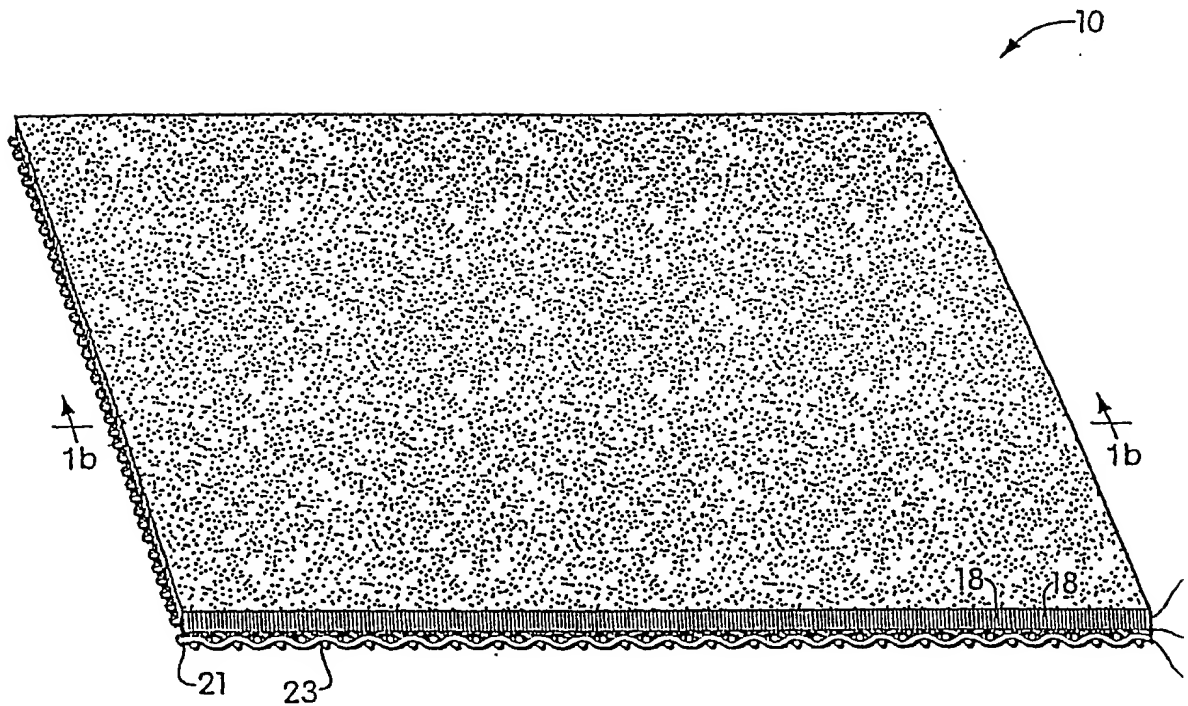


Fig. 1a

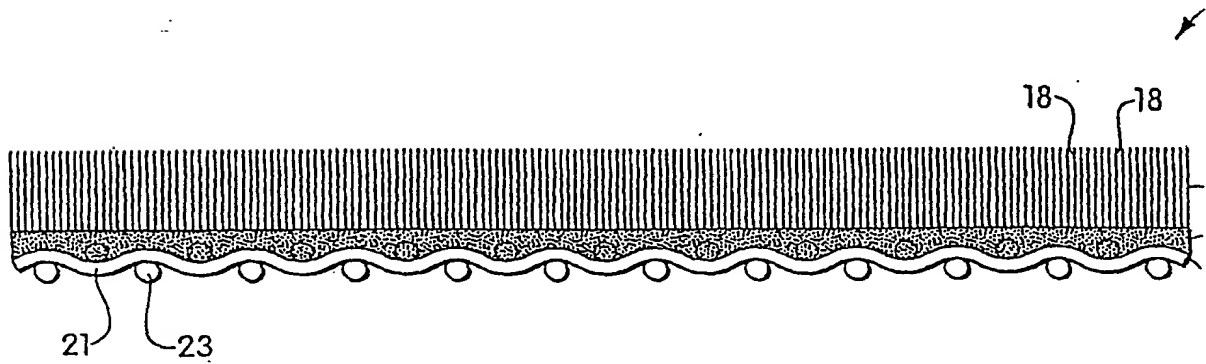


Fig. 1b

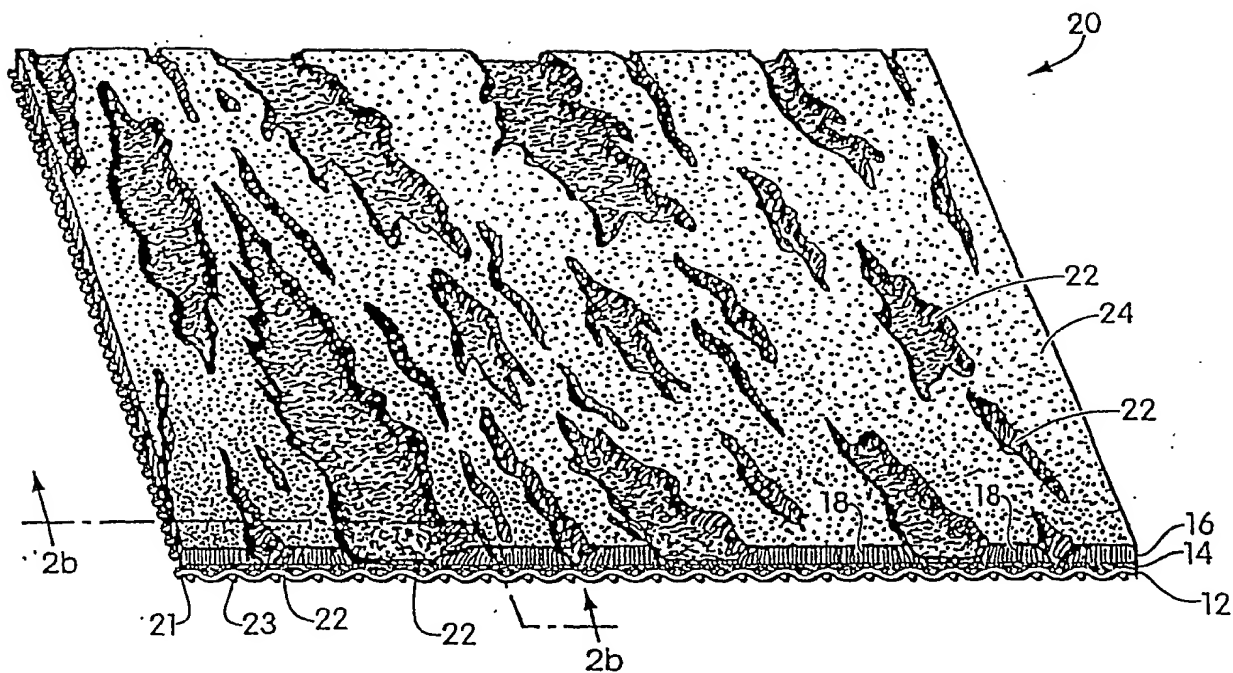


Fig. 2a

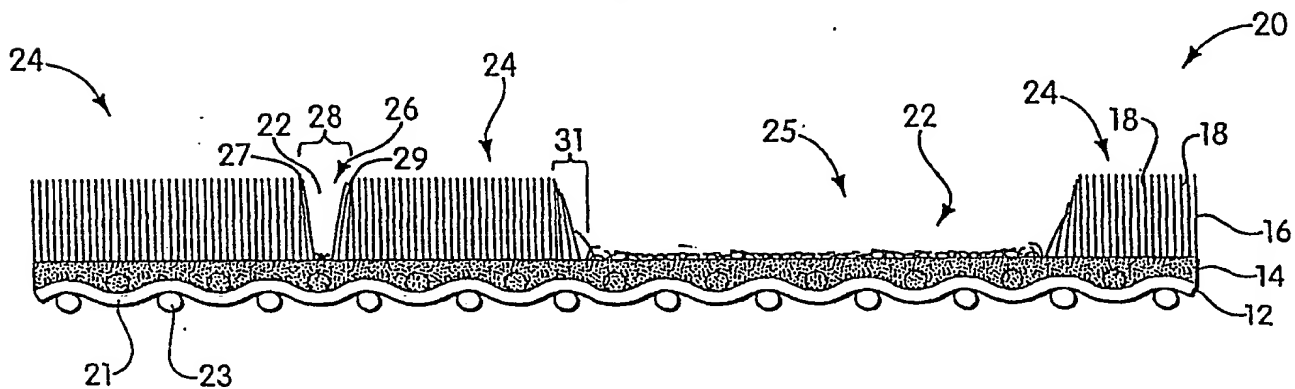
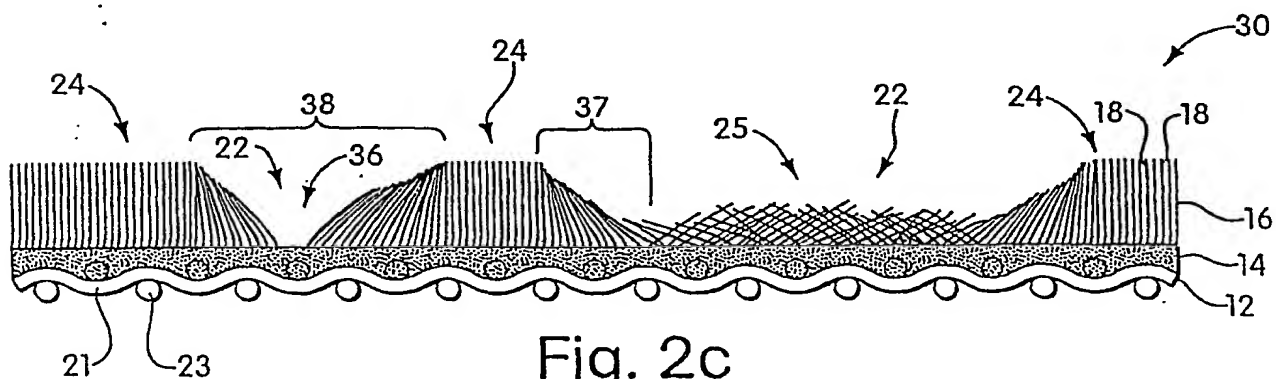


Fig. 2b

Fig. 2c
(Prior Art)

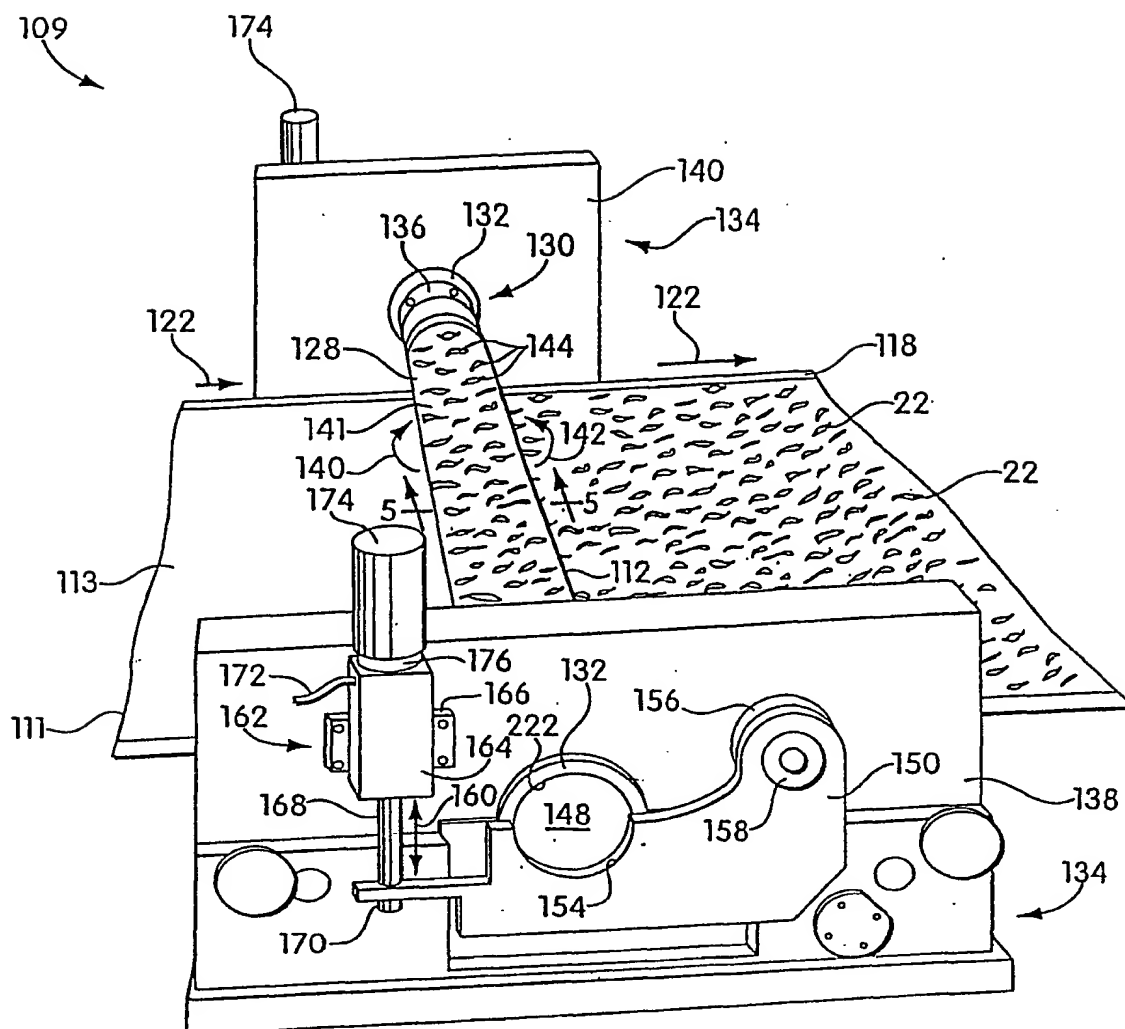


Fig. 4a

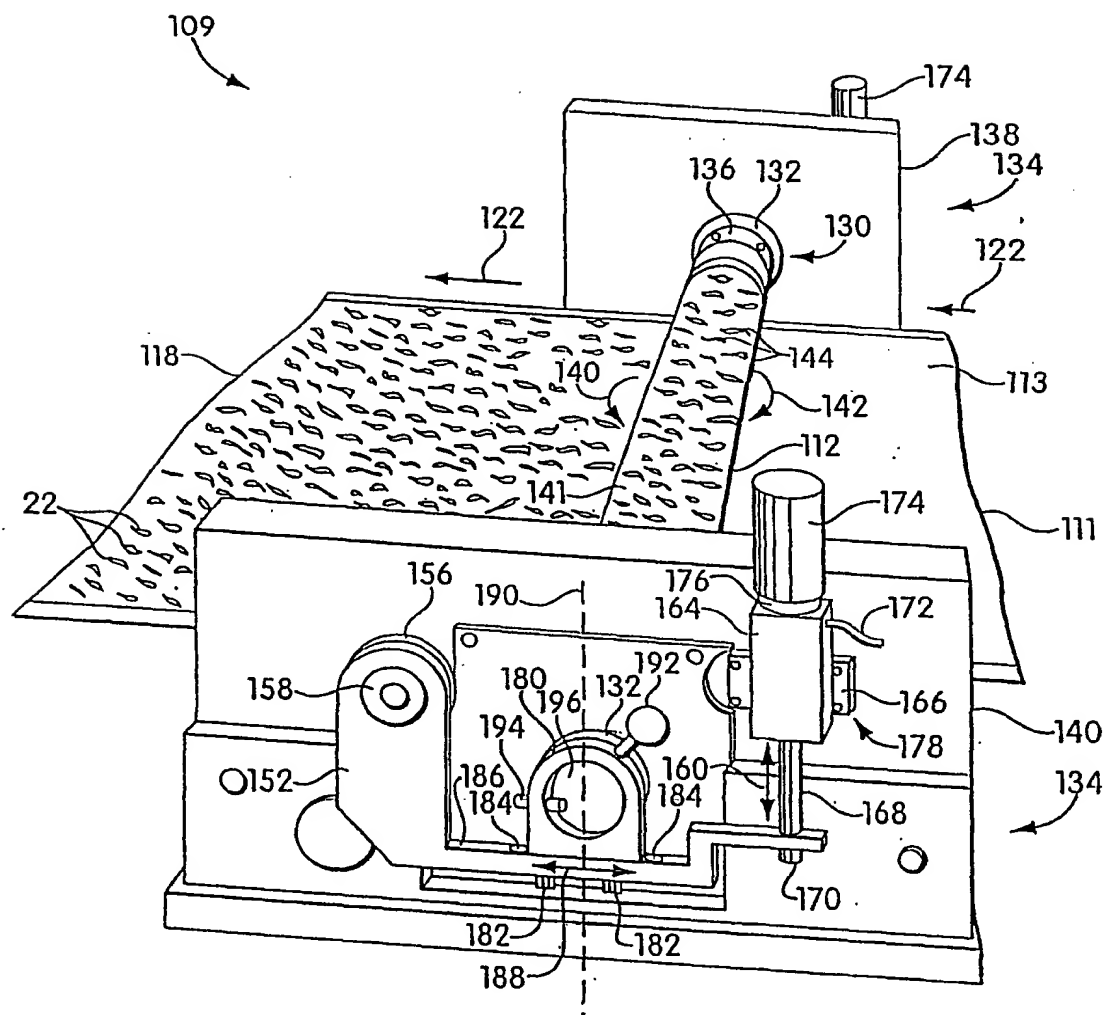


Fig. 4b

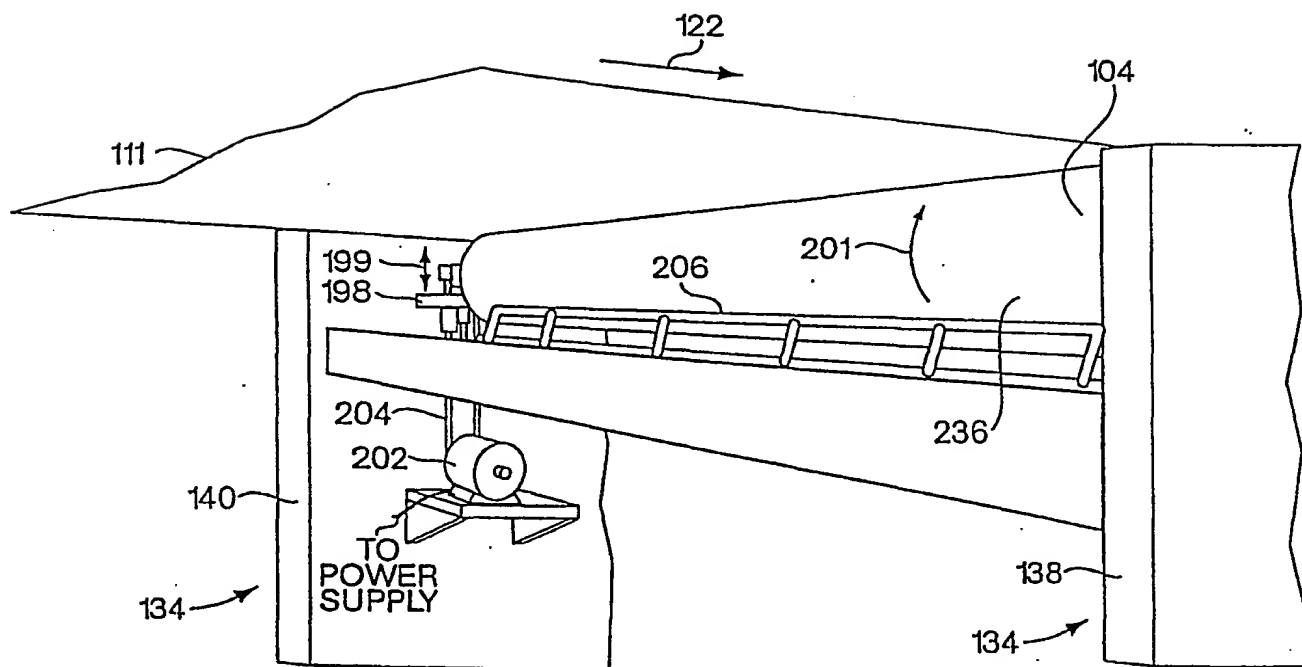


Fig. 4c

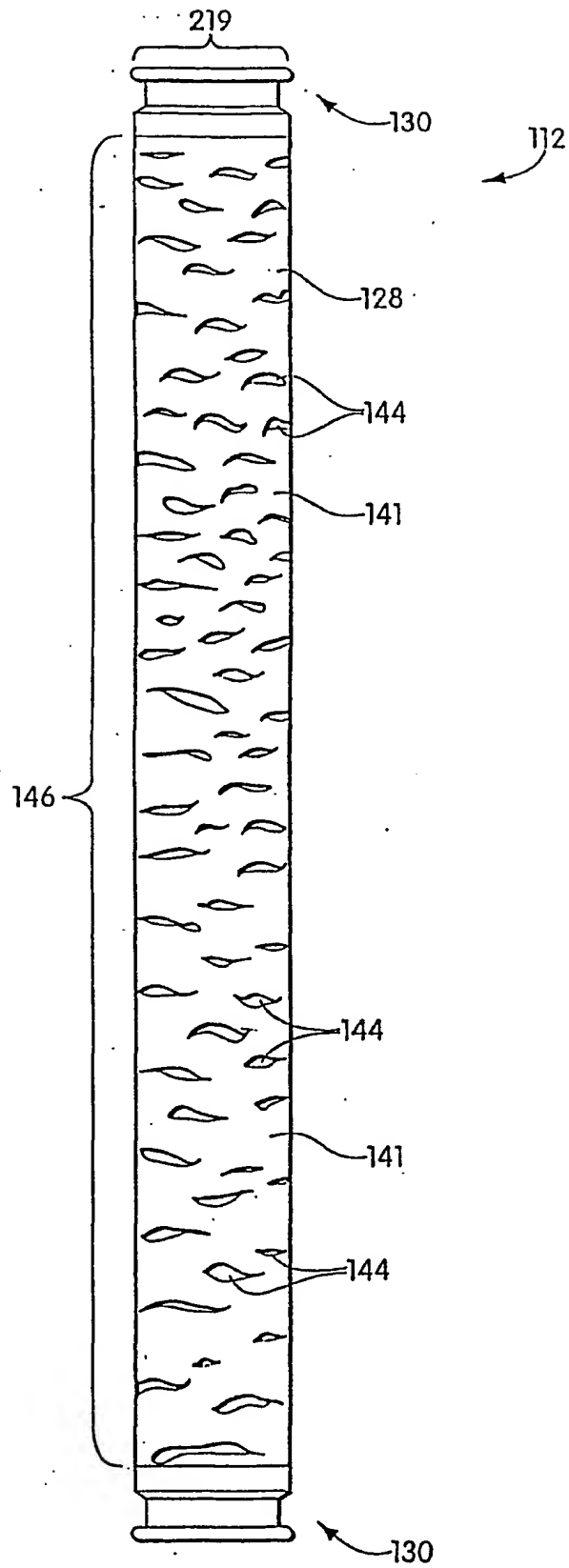


Fig. 4d

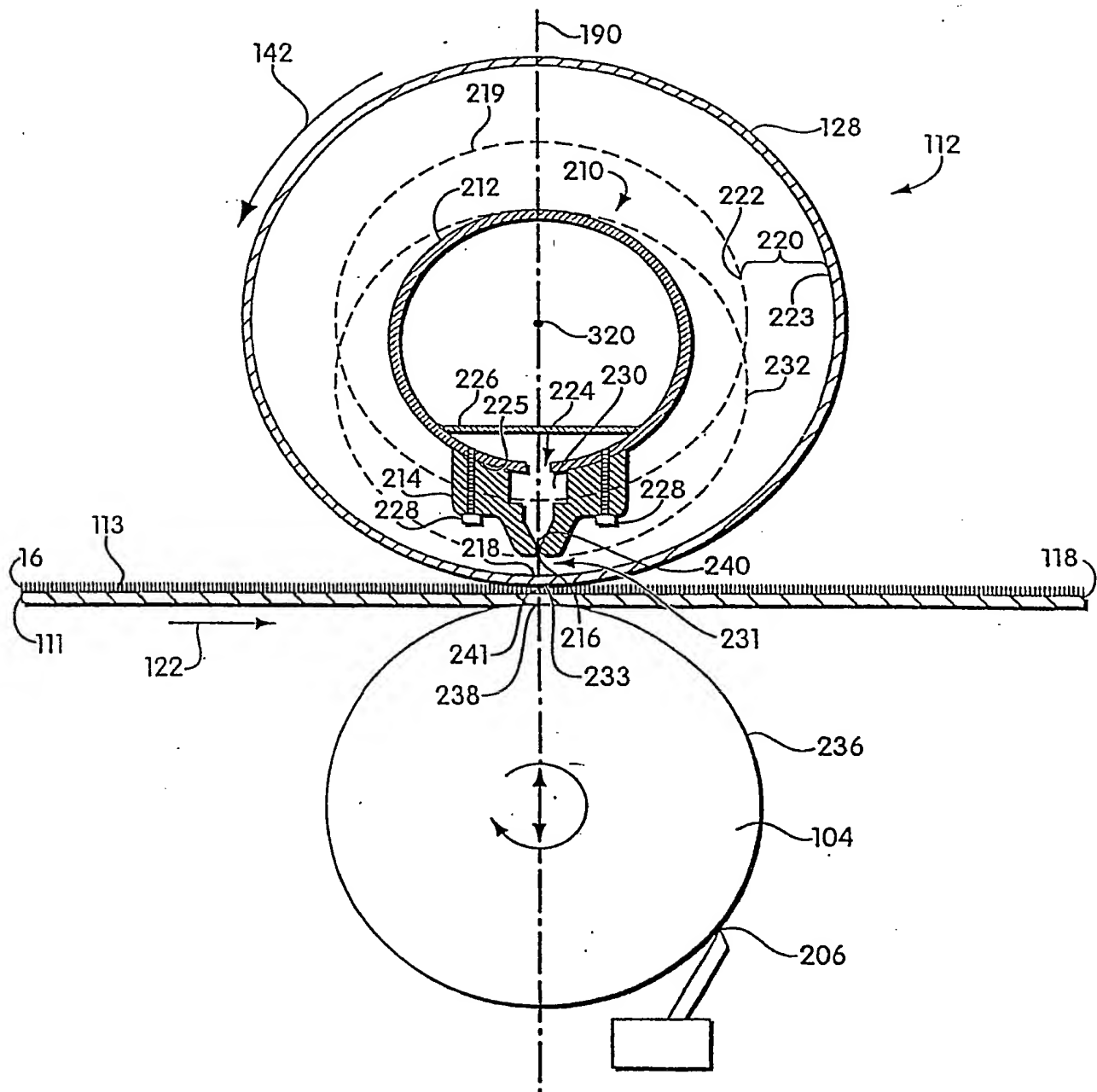


Fig. 5a

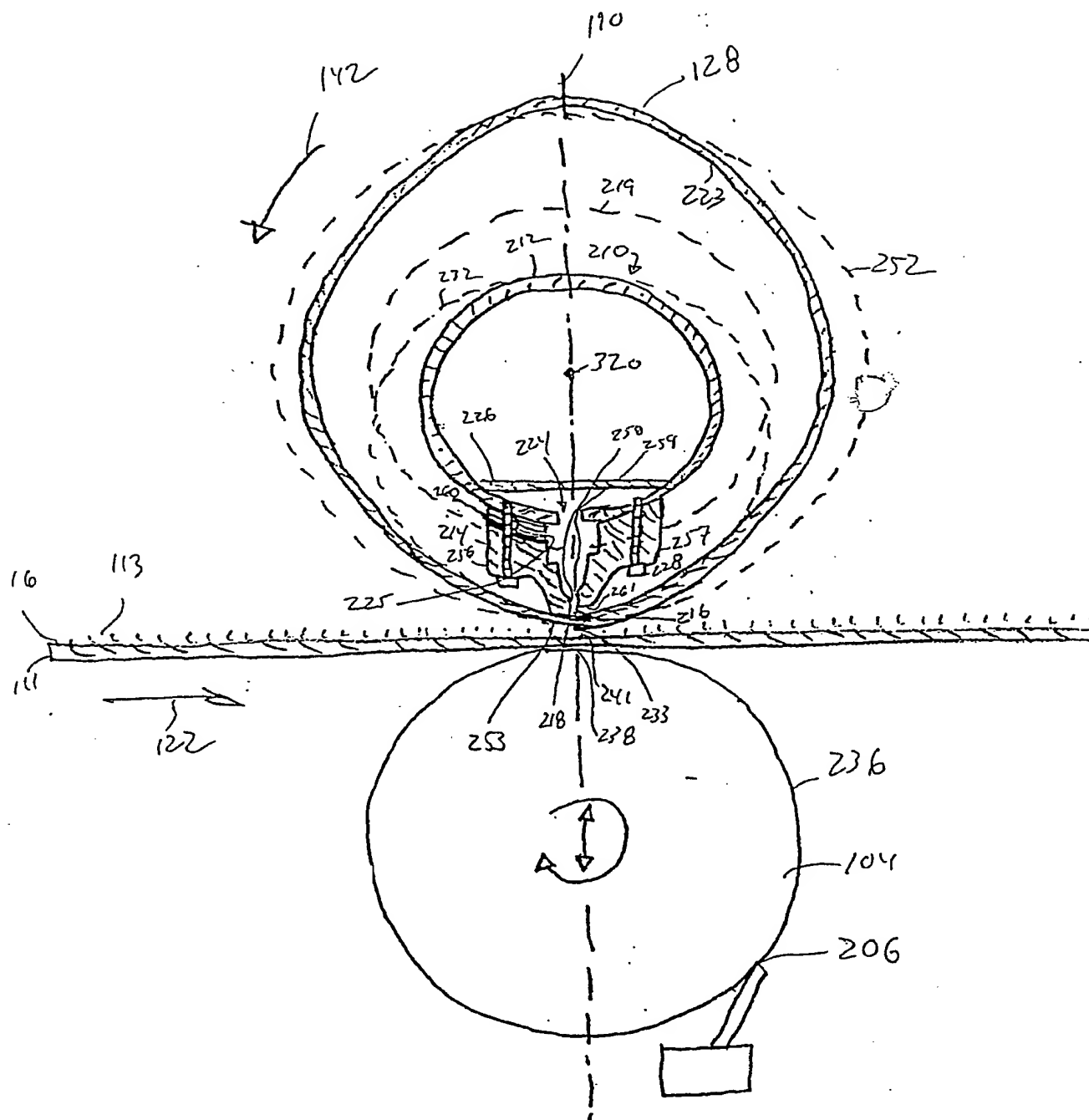


Fig. 5C

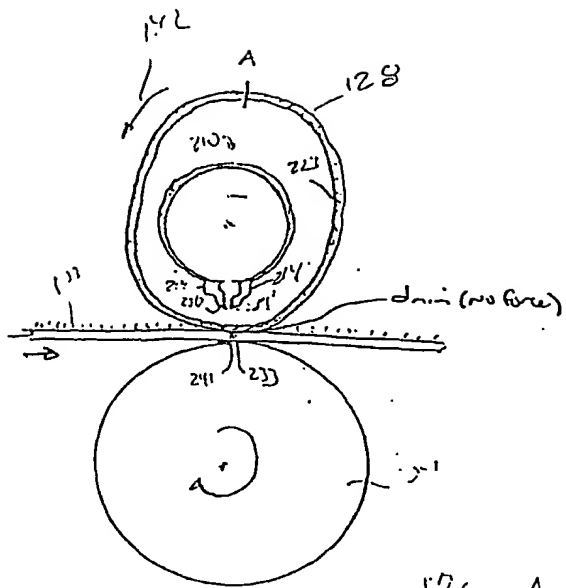


Fig 5d

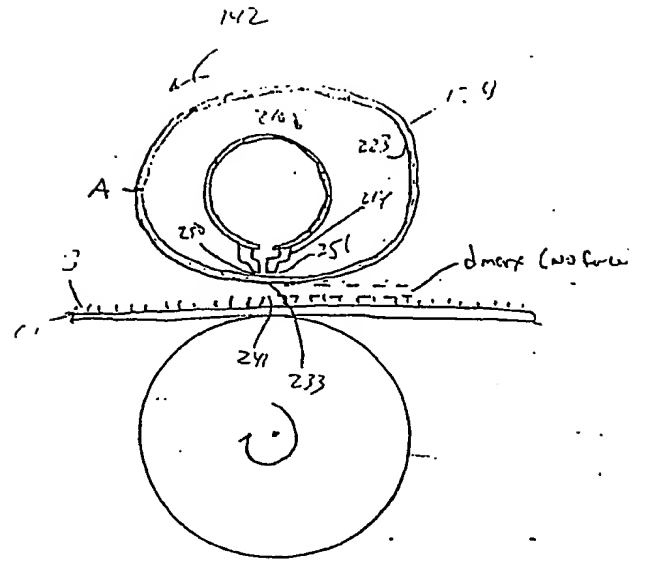


Fig 5e

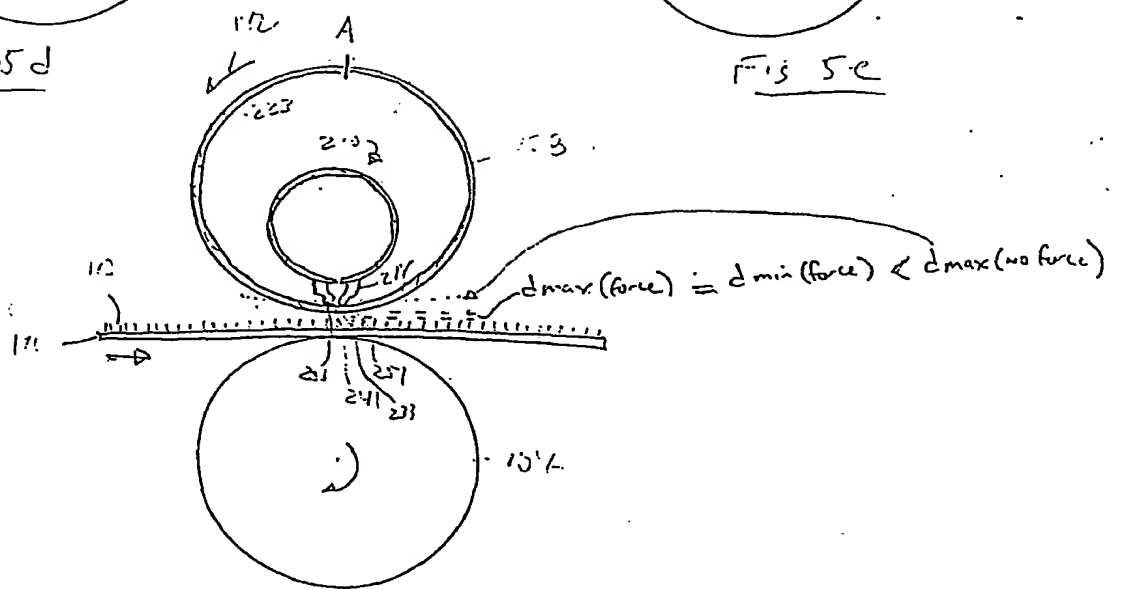
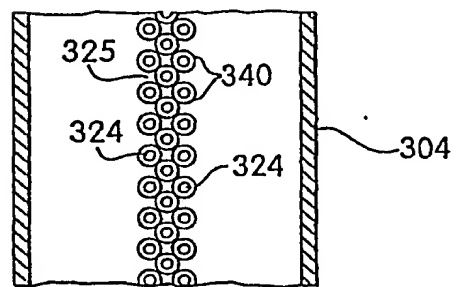
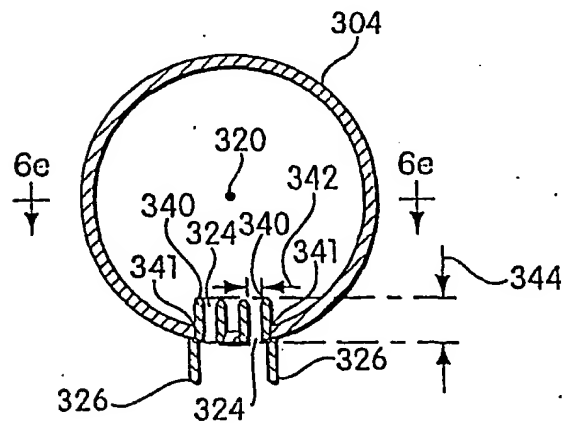
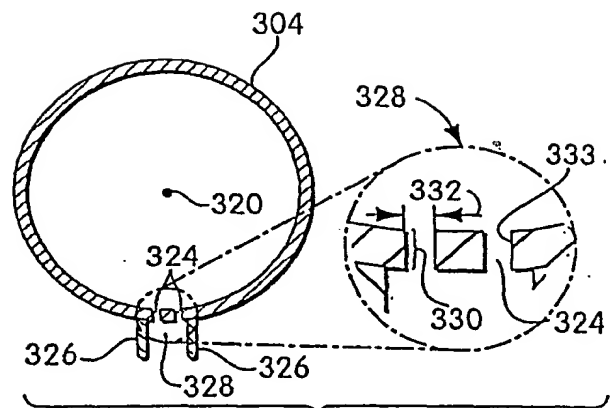
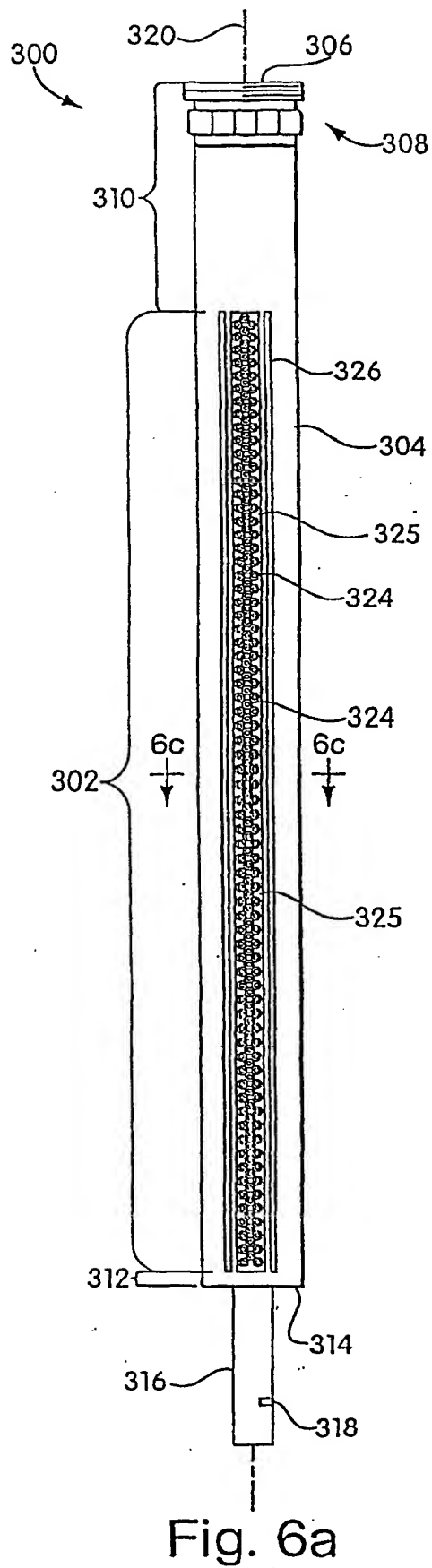


Fig 5f



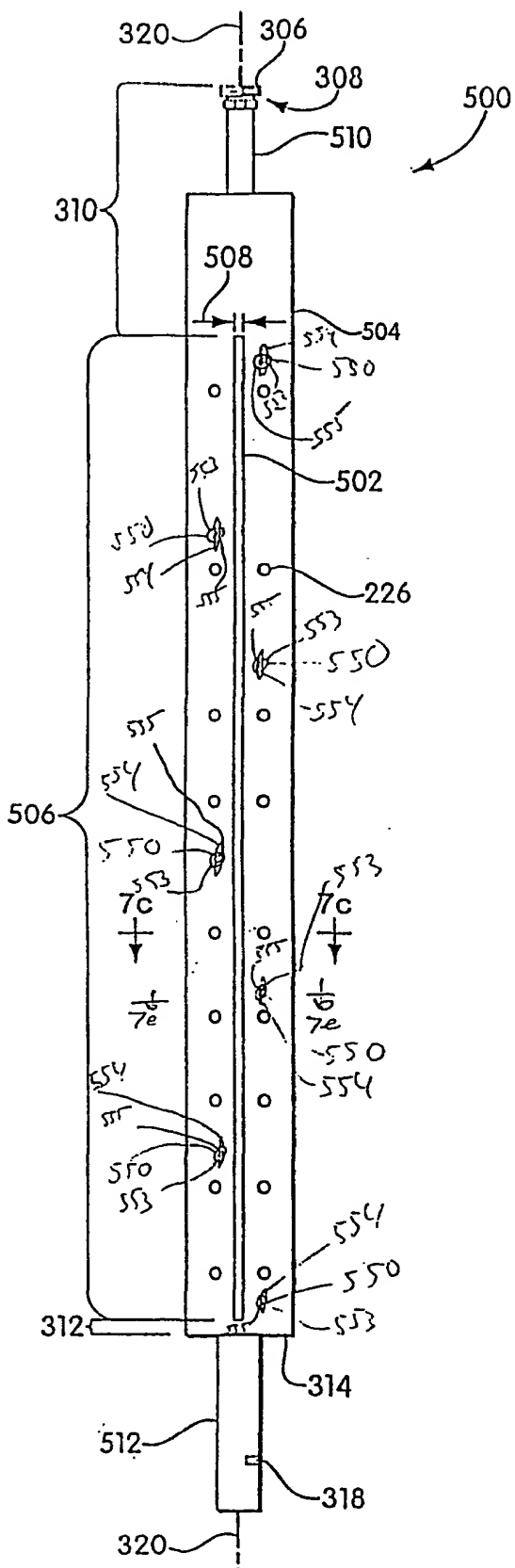


Fig. 7a

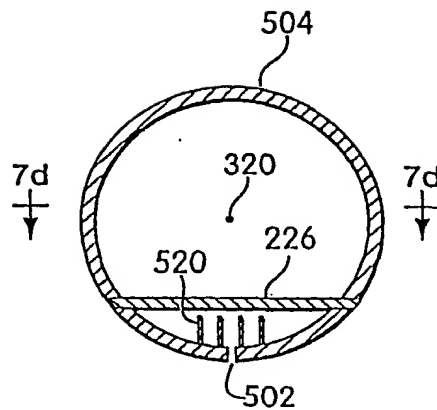


Fig. 7c

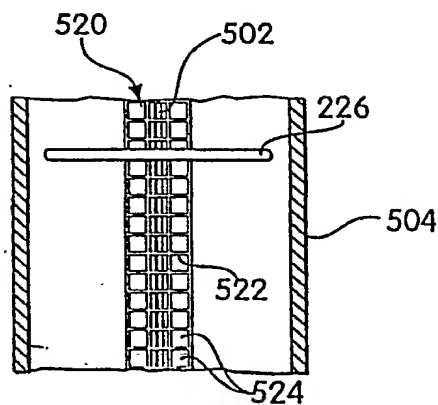


Fig. 7d

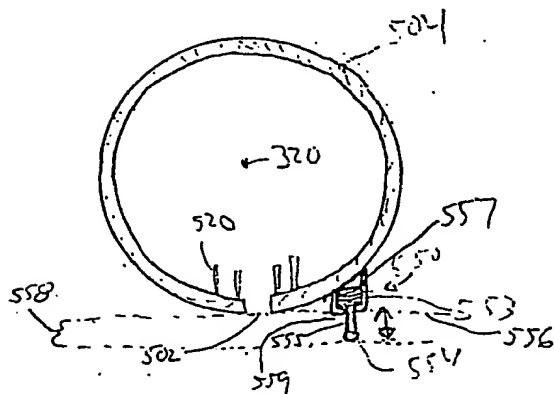


Fig. 7e

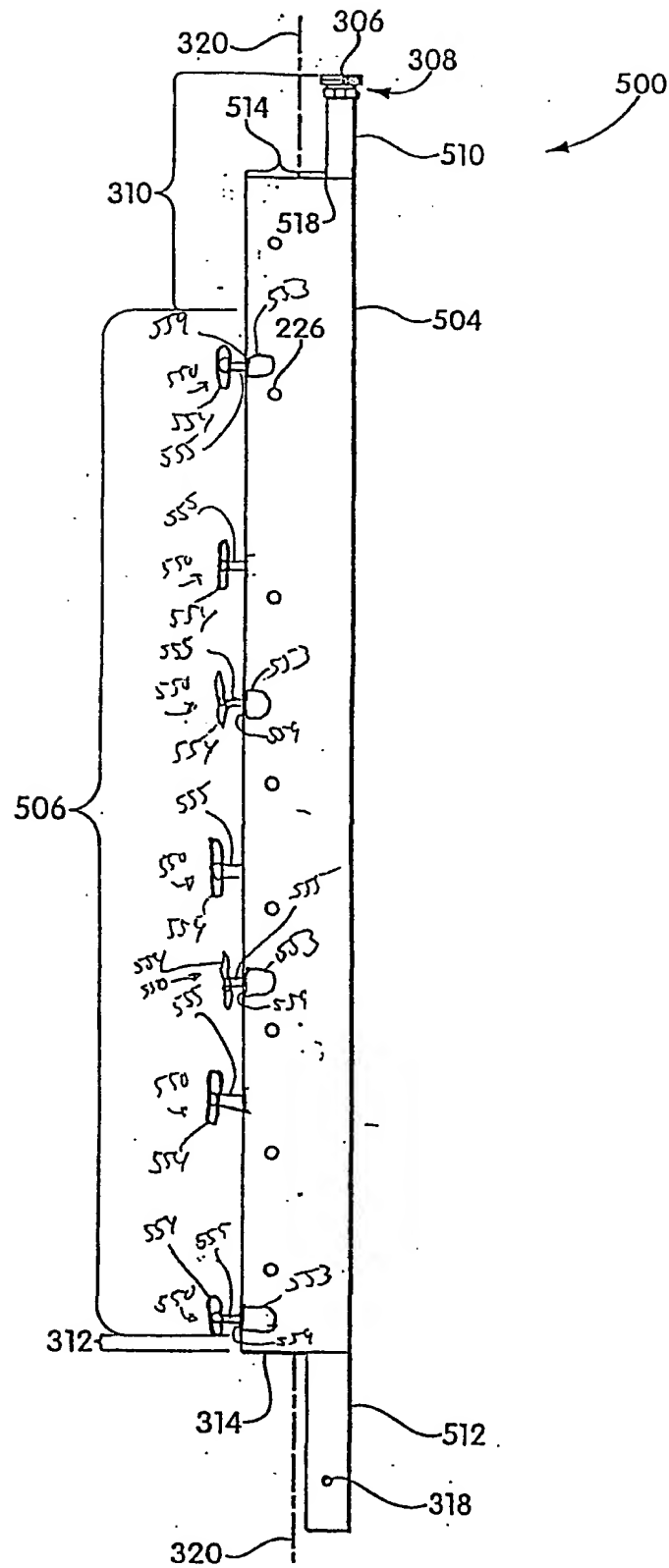


Fig. 7b

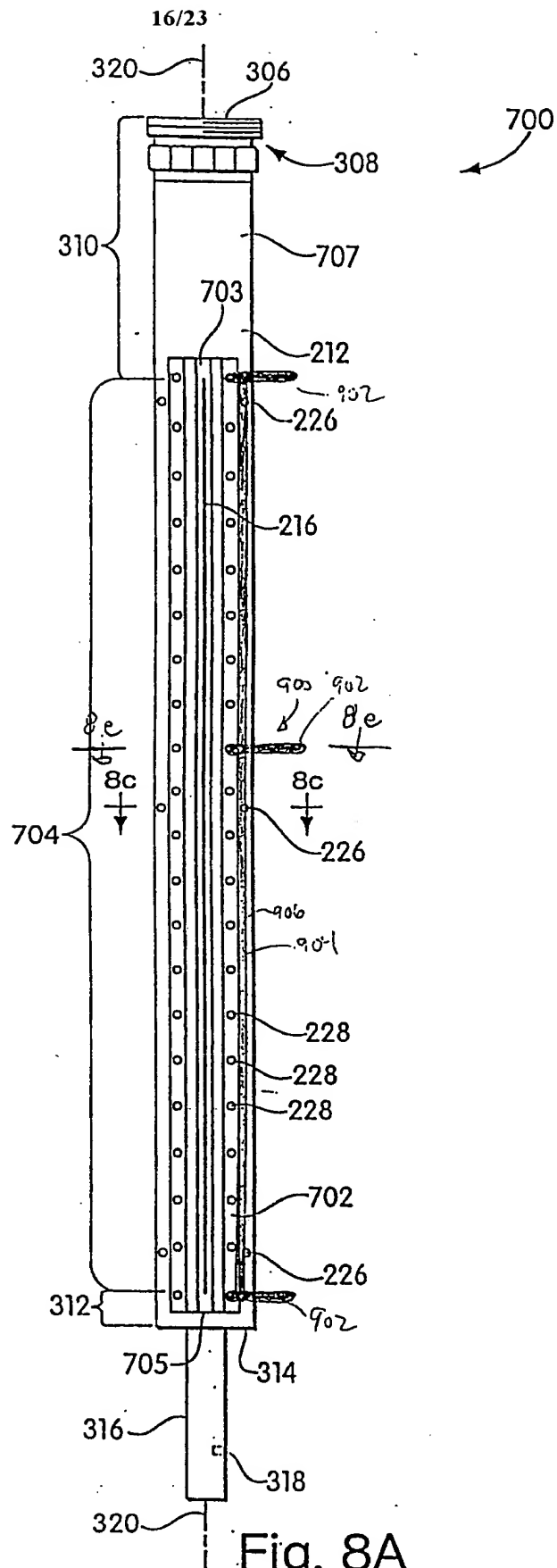


Fig. 8A

17/23

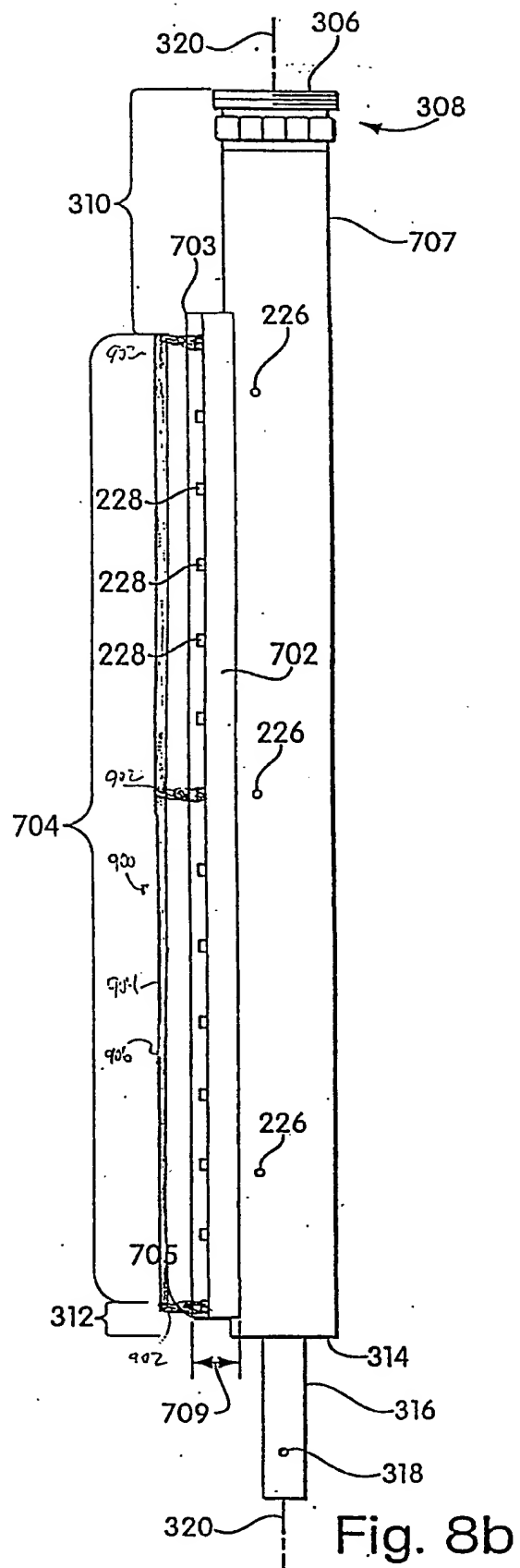


Fig. 8b

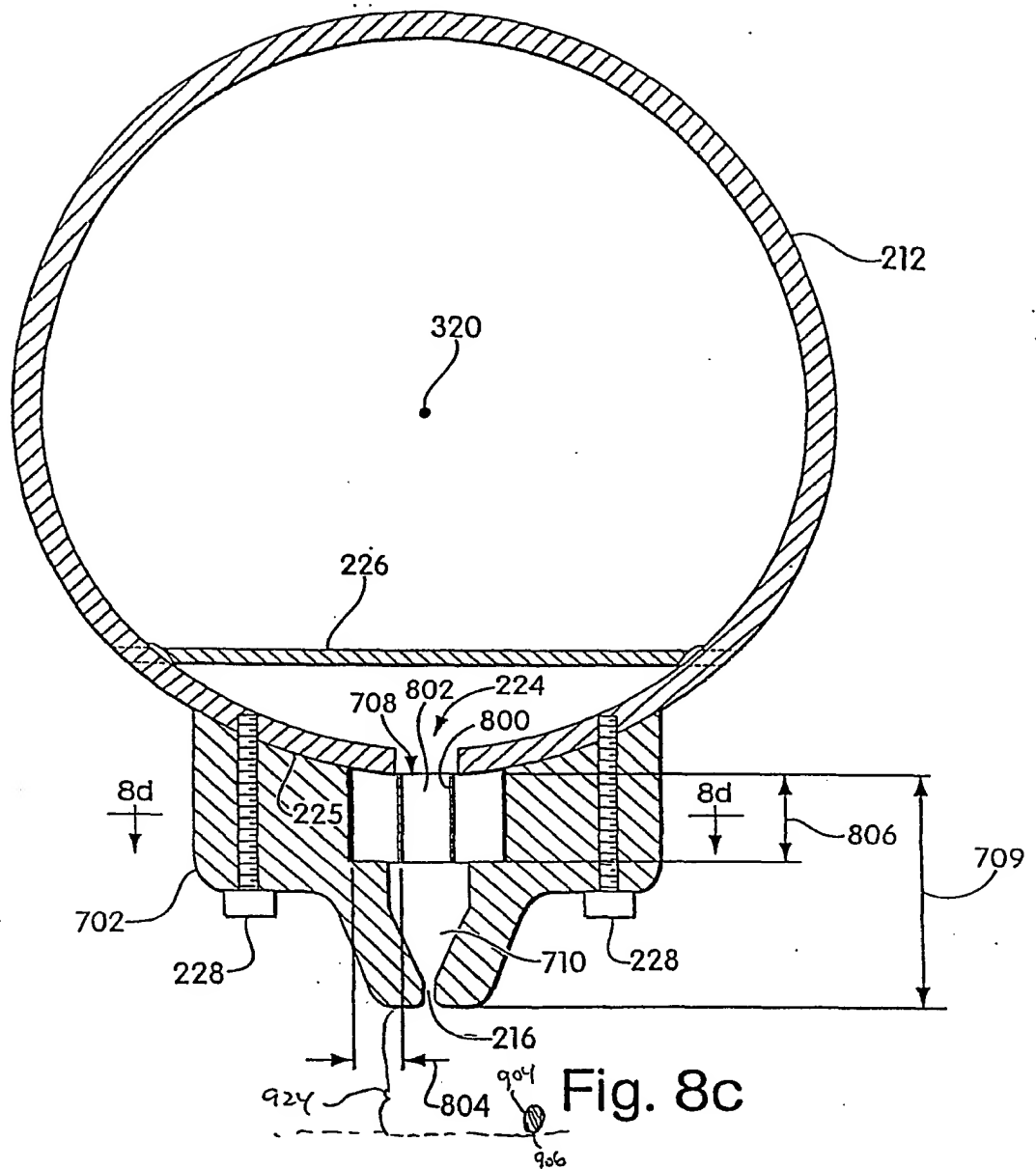


Fig. 8c

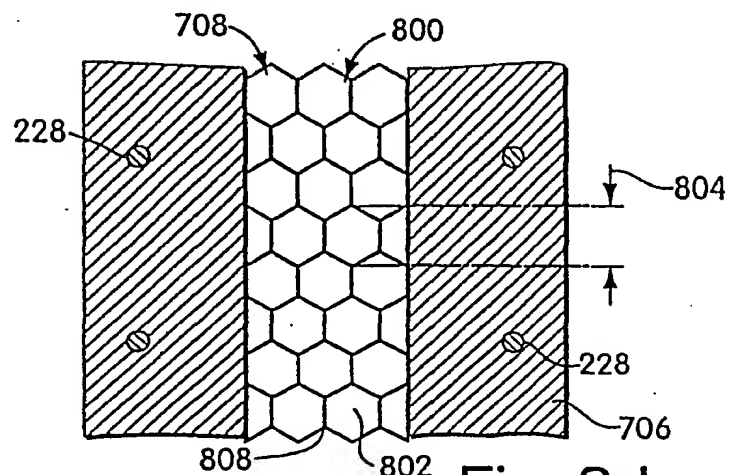
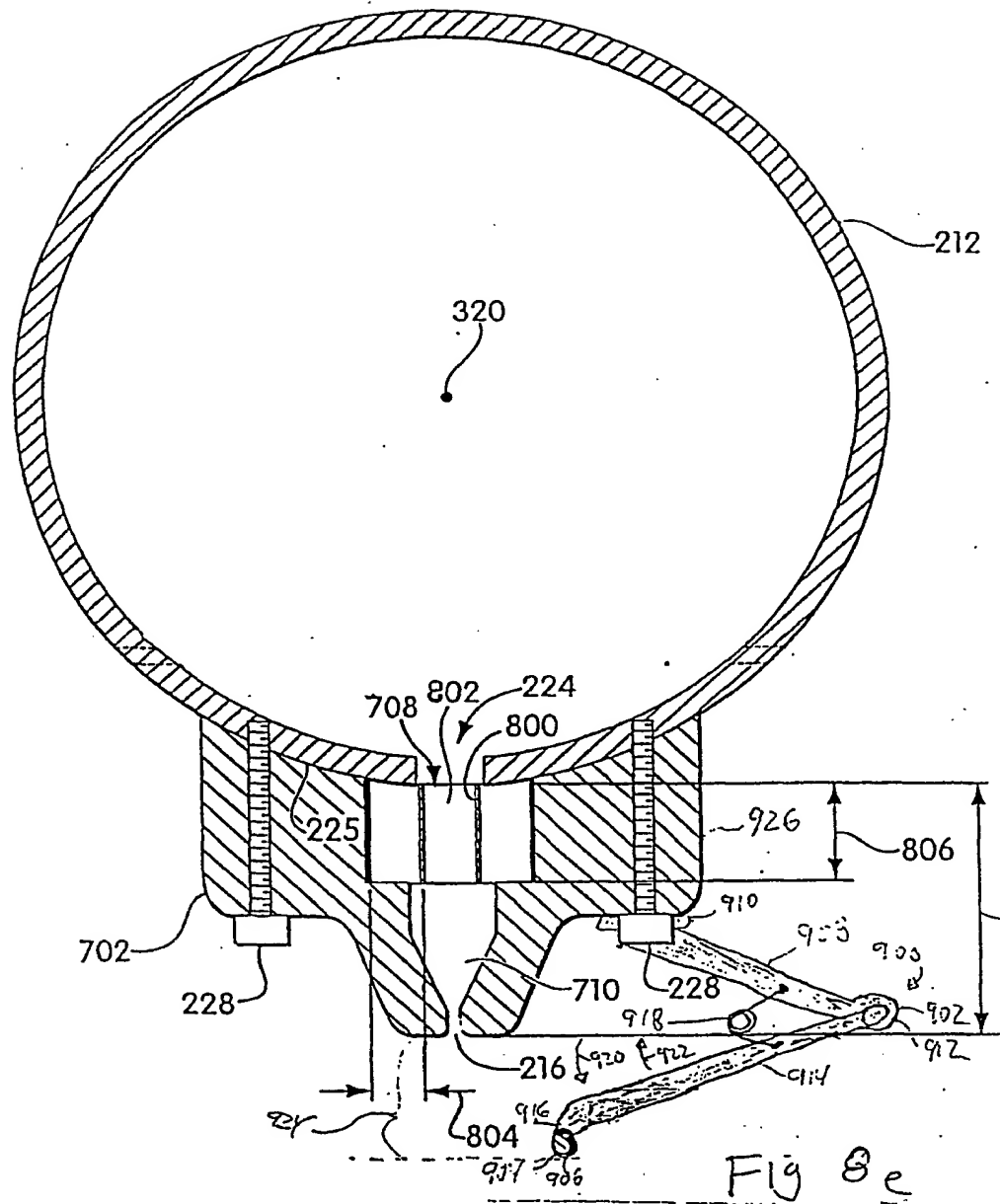


Fig. 8d



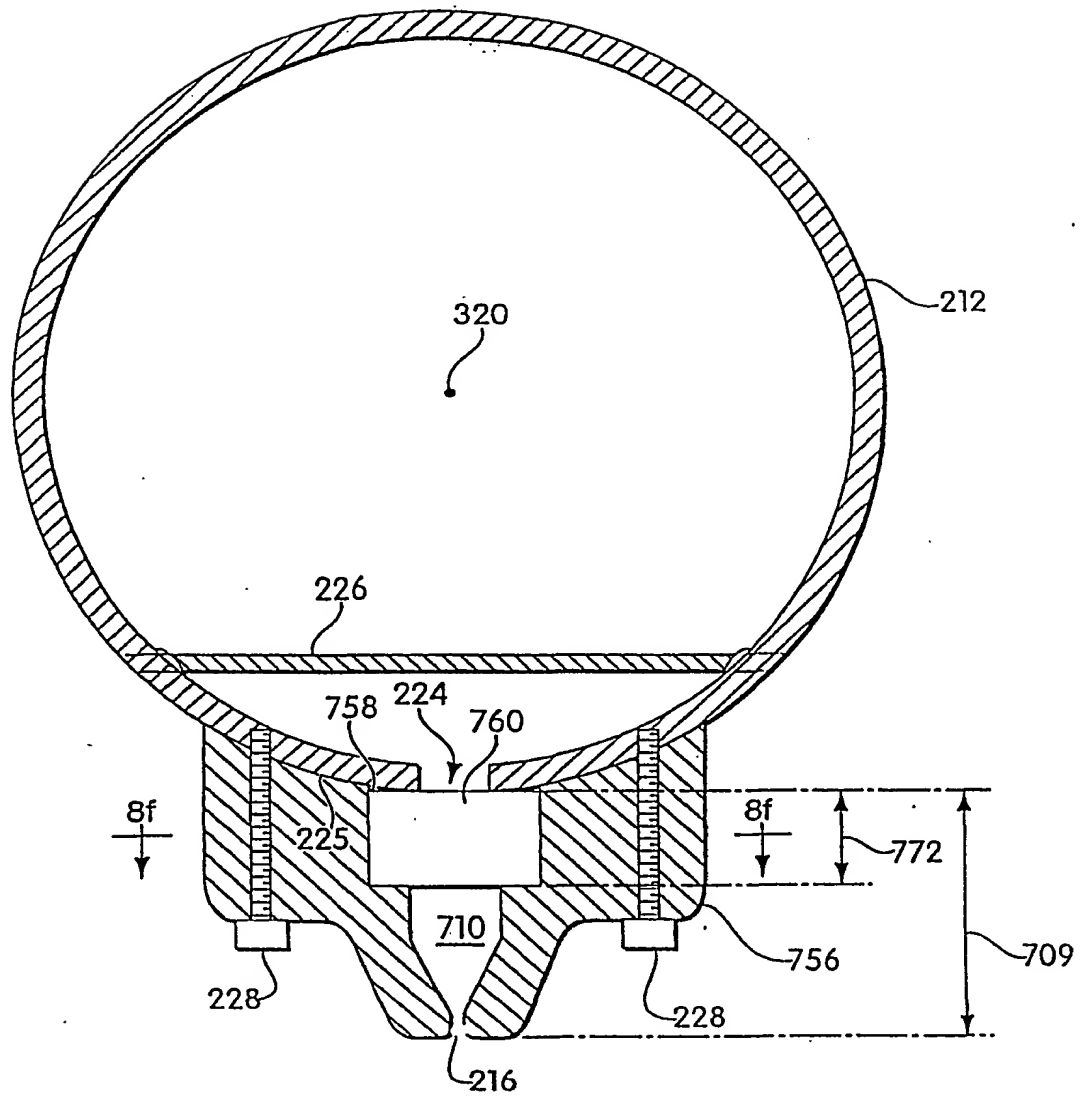


Fig. 8f

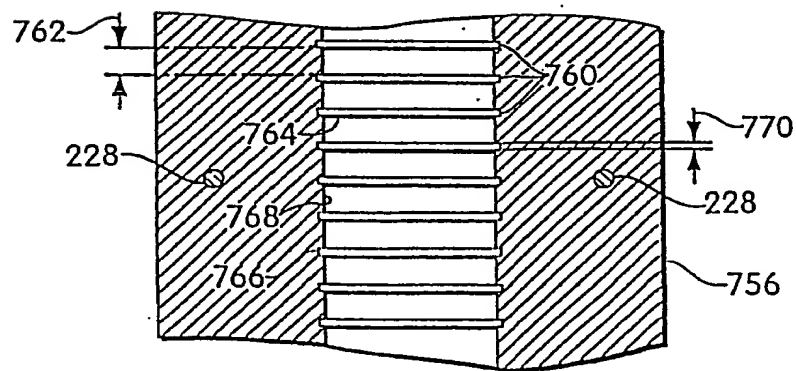


Fig. 8g

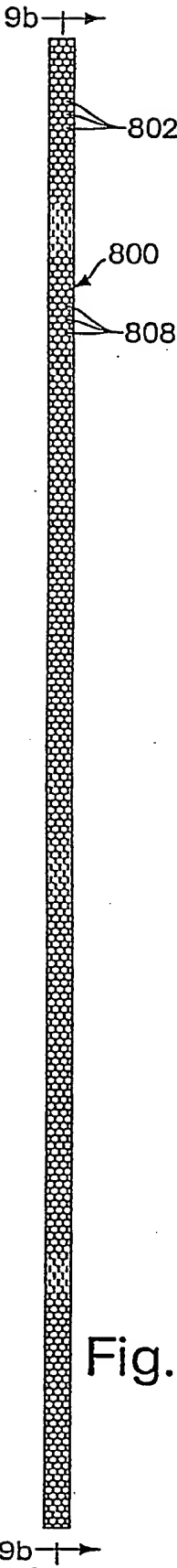


Fig. 9a

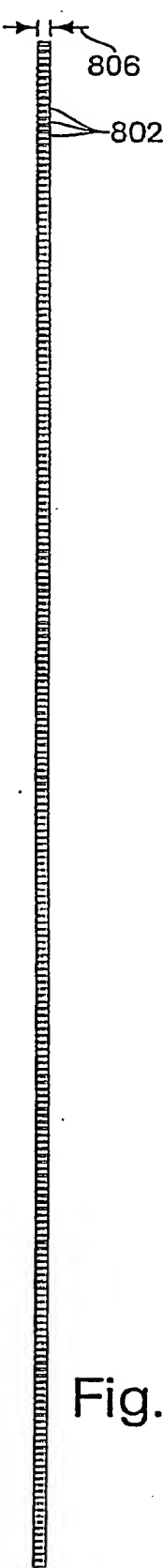


Fig. 9b

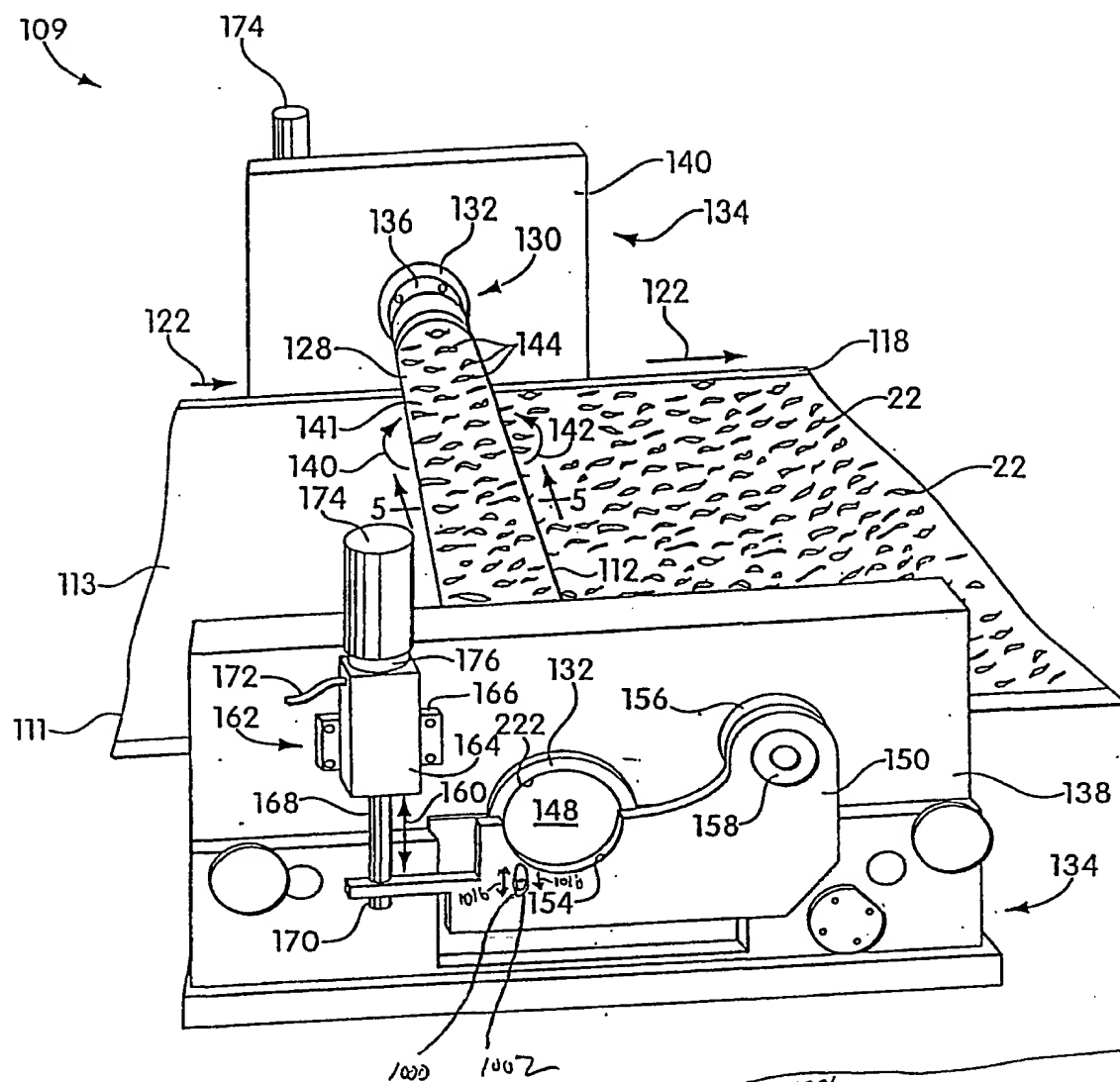


Fig. 10a

